

Ultrafast Electron Beam,

A Tool to Explore the Nanoscopic World of Materials



Young Uk JEONG (정 영 욱, 鄭 永 旭) 2022. 7. 13



COLLECTIVE INTELLIGENCE
**Radiation Center for
Ultrafast Science**

circus

*“Scientific advance is more often driven
by the development of
a new tool than a new concept”*

Freeman Dyson

*In a review of a biography
of the mathematician George Green*



I. Free Electrons

II. Spatial Confinement of Free Electrons

III. Temporal Confinement of Free Electrons

IV. Ultrafast Electron Diffraction



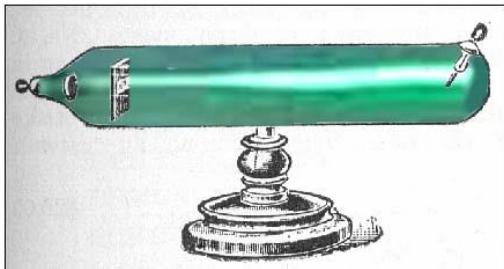
1. Free Electrons

Electron

1897, [자유] 전자의 발견

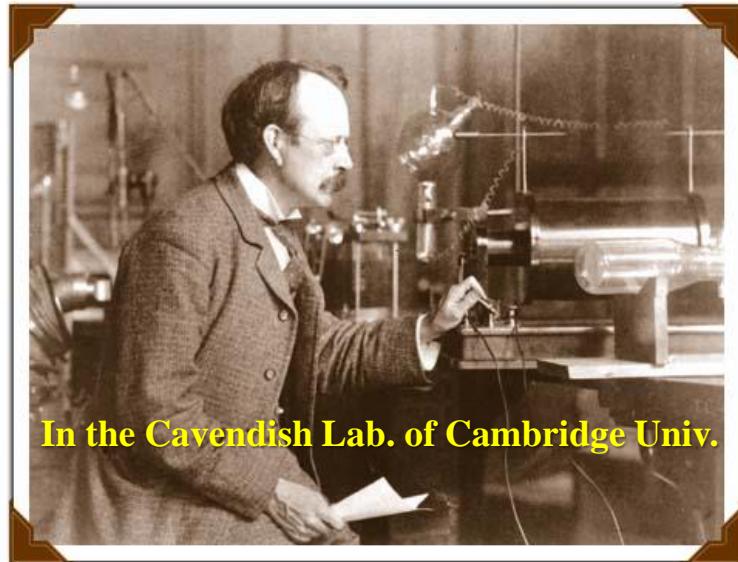


The Novel Prize in Physics 1906



Mysterious rays

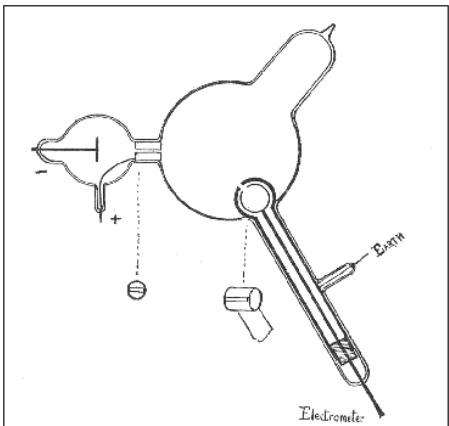
Sir Joseph J. Thomson
(1856.12.18 ~ 1940.8.30)



In the Cavendish Lab. of Cambridge Univ.

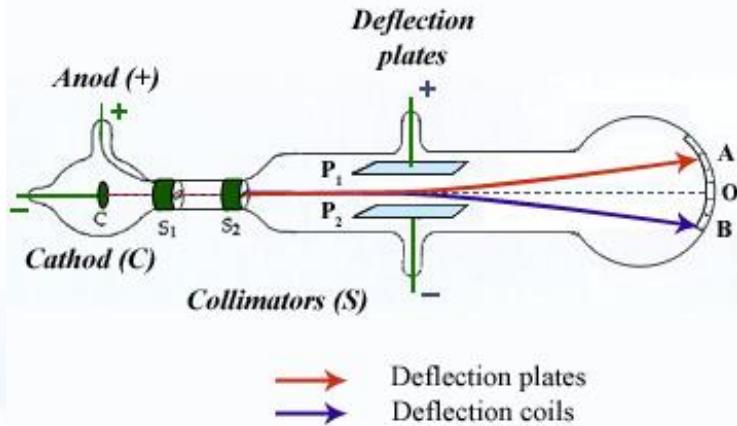
1st Exp.

Cathode rays : negative charge



2nd Exp.

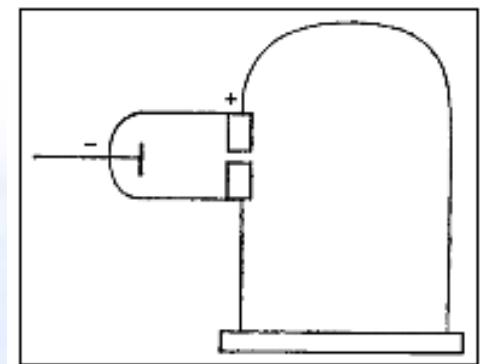
Cathode rays : deflected by E-field



Deflection plates
Deflection coils

3rd Exp.

Cathode rays m/e : < 1/1000 of H⁺





- Stable subatomic particle with a negative charge
Mean lifetime : $> 6.6 \times 10^{28}$ yr
- $e^- : -1.602 \times 10^{-19} C$
 $m_e : 9.10938 \times 10^{-31} kg$, 1/1836 the mass of a proton
Spin or intrinsic angular momentum : $\frac{1}{2}\hbar$
Radius : $< 10^{-22} m$
- Elecktron : the ancient Greek word for amber
Electron : first suggested by G. J. Stoney in 1891

Electron?

전자의 크기와 모양은?



THE SIZE AND SHAPE OF THE ELECTRON.¹

**“The size and shape of the electron”,
Arthur H. Compton, Phys. Rev. 14, 20
– Published 1 July 1919**

BY ARTHUR H. COMPTON.

SYNOPSIS.—Attention is called to two outstanding differences between experiment and the theory of scattering of high frequency radiation based upon the hypothesis of a sensibly point charge electron. In the first place, according to this theory the mass scattering coefficient should never fall below about .2, whereas the observed scattering coefficient for very hard X-rays and γ -rays falls as low as one fourth of this value. In the second place, if the electron is small compared with the wave-length of the incident rays, when a beam of γ -rays is passed through a thin plate of matter the intensity of the scattered rays on the two sides of the plate should be the same, whereas it is well known that the scattered radiation on the emergent side of the plate is more intense than that on the incident side.

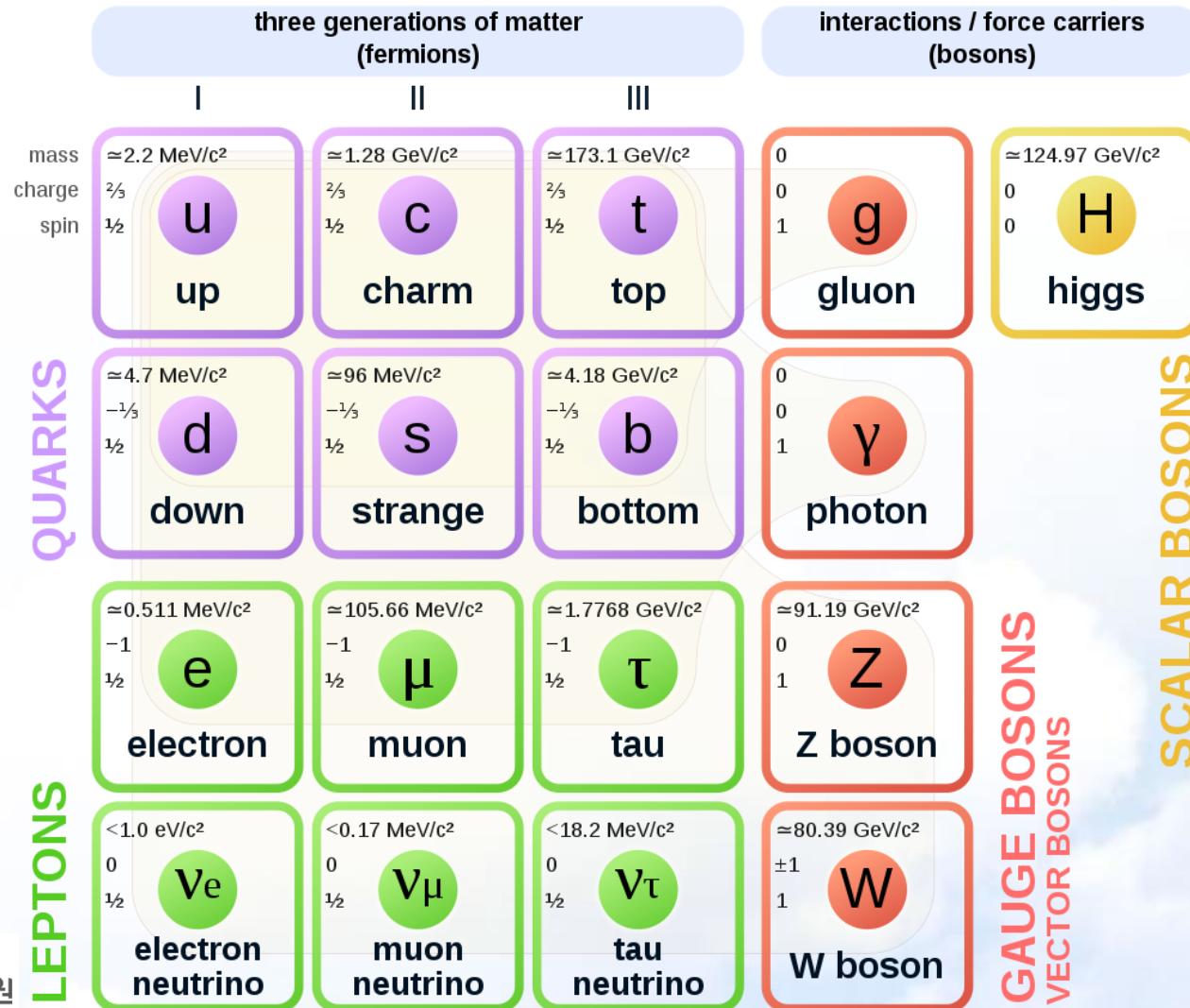
It is pointed out that the hypothesis that the electron has a diameter comparable with the wave-length of the hard γ -rays will account qualitatively for these differences, in virtue of the phase difference between rays scattered by different parts of the electron. The scattering coefficient for different wave-lengths is calculated on the basis of three types of electron: (1) A rigid spherical shell of electricity, incapable of rotation; (2) a flexible spherical shell of electricity; (3) a thin flexible ring of electricity. All three types are found to account satisfactorily for the meager available data on the magnitude of the scattering coefficient for various wave-lengths. The rigid spherical electron is incapable of accounting for the difference between the emergent and the incident scattered radiation, while the flexible ring electron accounts more accurately for this difference than does the flexible spherical shell electron.

It is concluded that the diameter of the electron is comparable in magnitude with the wave-length of the shortest γ -rays. Using the best available values for the wave-length and the scattering by matter of hard X-rays and γ -rays, the radius of the electron is estimated as about 2×10^{-10} cm. Evidence is also found that the radius of the electron is the same in the different elements. In order to explain the fact that the incident scattered radiation is less intense than the emergent radiation, the electron must be subject to rotations as well as translations.

Electron to them 그들에게 전자는?



Standard Model of Elementary Particles

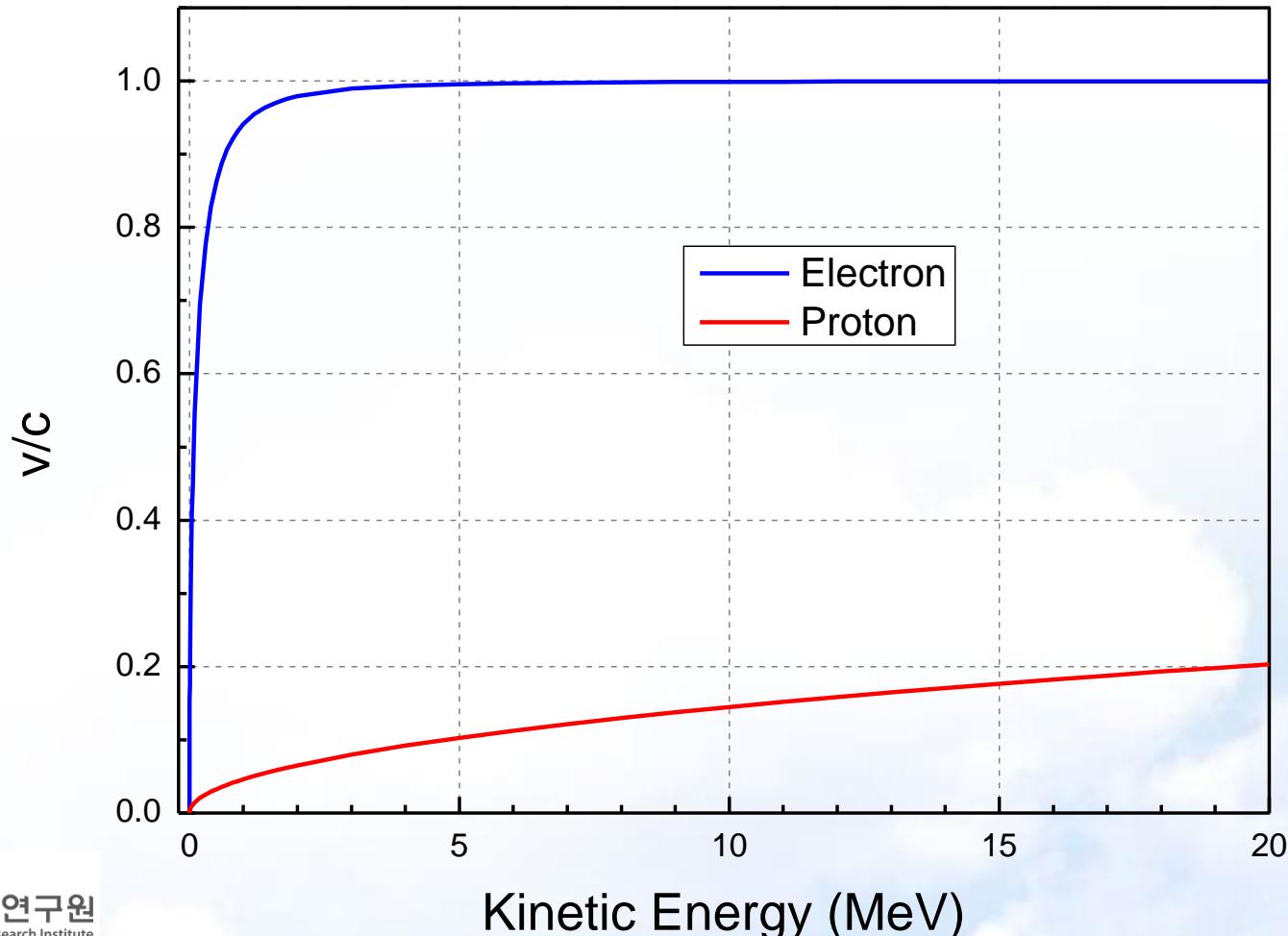


Electron

전자는?



- The most suitable particle to accelerate



Acceleration

가속원리



Charles-Augustin de Coulomb
(1736. 6. 14 – 1806. 8. 23)

$$\vec{F} = q\vec{E}$$



Hendrik Antoon Lorentz
(1853. 7. 18 – 1928. 2. 4)

$$\vec{F} = q\vec{E} = m_q \vec{a} \quad (\text{non-relativistic } v \ll c)$$

$$(\text{relativistic case } v \sim c) = \frac{d}{dt}(\vec{P}) = m_q \frac{d}{dt}(\gamma \vec{v})$$

Lorentz factor : $\gamma = \frac{1}{\sqrt{1 - \left(\frac{v}{c}\right)^2}}$

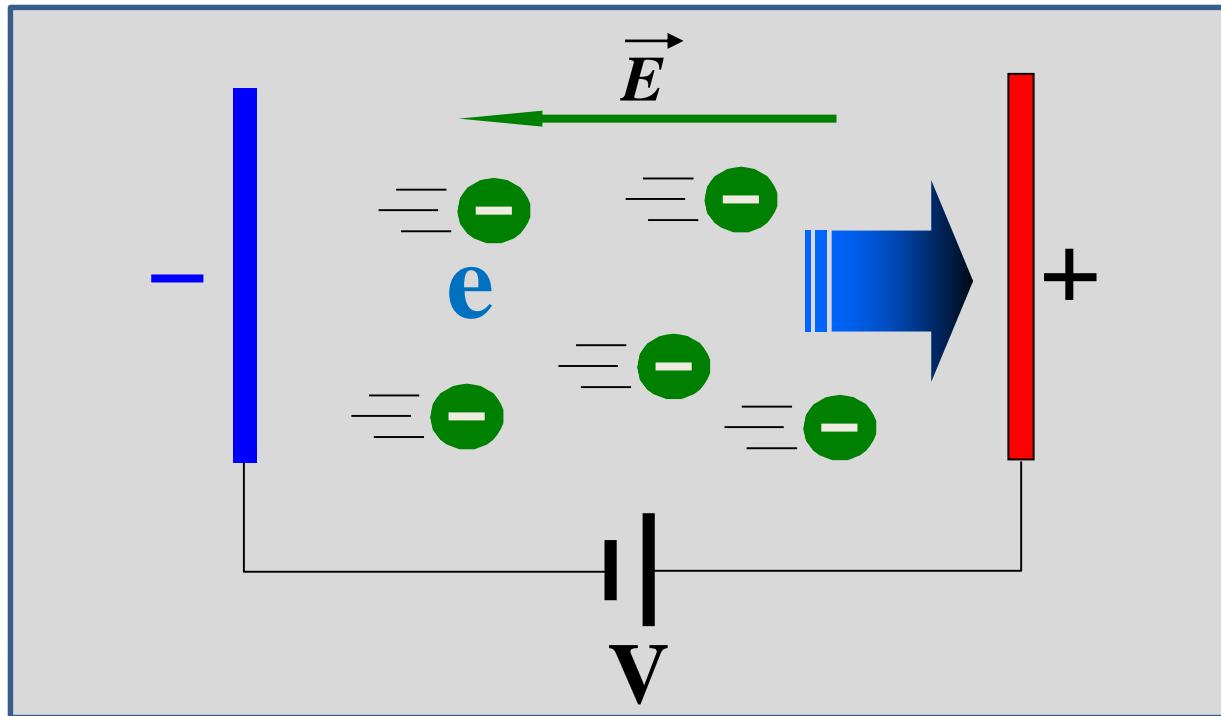
Electron Energy

전자 에너지



$$E = qV = eV$$

(1 eV = 1 electron volt = 1.6×10^{-19} J)

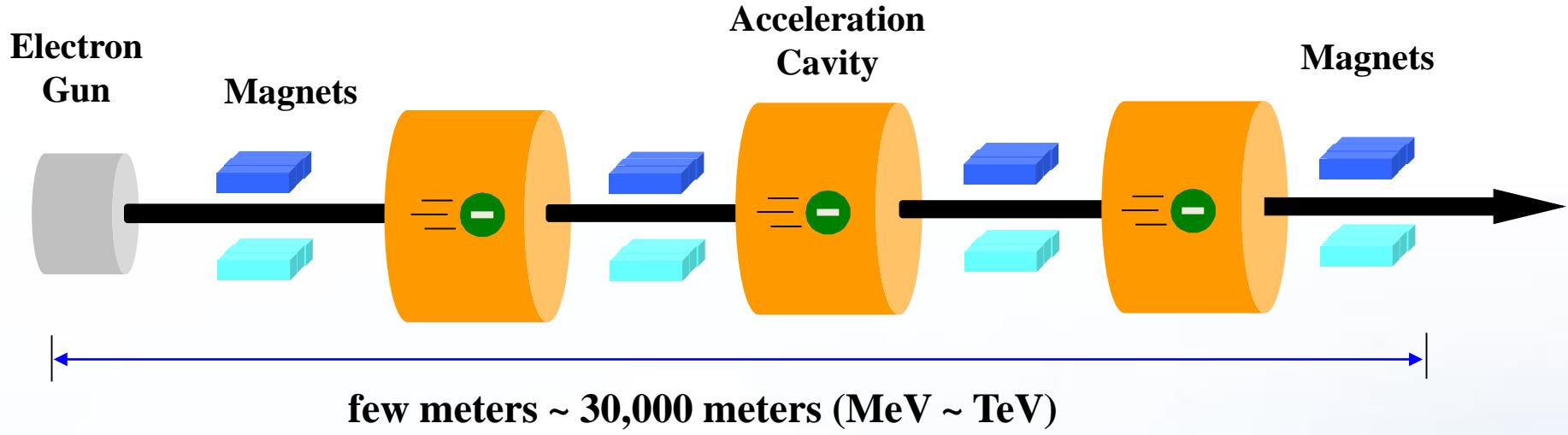


$$\text{Lorentz factor : } \gamma = (1 - v^2/c^2)^{-1/2} = 1 + \frac{E}{m_e c^2} = 1 + \frac{E \text{ [MeV]}}{0.511 \text{ [MeV]}}$$



- Particles : electron, proton, ion (heavy ion, hadron)
- Acceleration method :
 - 정전 가속기 (Electrostatic Accelerator)
 - 고주파 가속기 (Radio-Frequency/RF Accelerator)
 - 자기유도 가속기 (Induction Accelerator)
 - 플라즈마 가속기 (Plasma Accelerator)
- Depending on shape :
 - 선형 가속기 (Linear Accelerator, Linac)
 - 원형 가속기 (Circular/Cyclic Accelerator)
- Depending on usage :
 - 방사광 가속기 (Synchrotron Accelerator)
 - 의료용 가속기 (Medical Accelerator)
 - 산업용 가속기 (Industrial Accelerator)

Electron Accelerator 전자 가속기



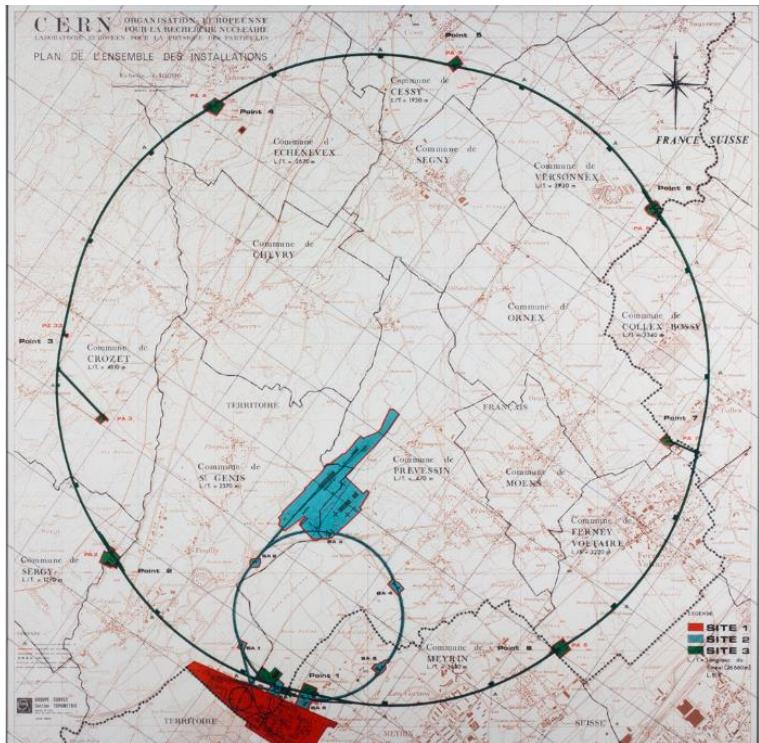
- Electron guns : thermionic, field emission, & photo-electron guns
- Electron optics : bending magnets, quadrupole magnets ...
- Acceleration cavity : normal conducting or superconducting

Biggest Electron Accelerator

가장 큰 전자 가속기는?



- The Large Electron-Positron Collider (LEP, 1989-2000), CERN
 - Energy : 209 GeV, circumference : 27 km



c.f. Linear Collider Program : electron/positron 500 GeV, 1 TeV
Large Hadron Collider (LHC) : 7 TeV proton beam

Synchrotron

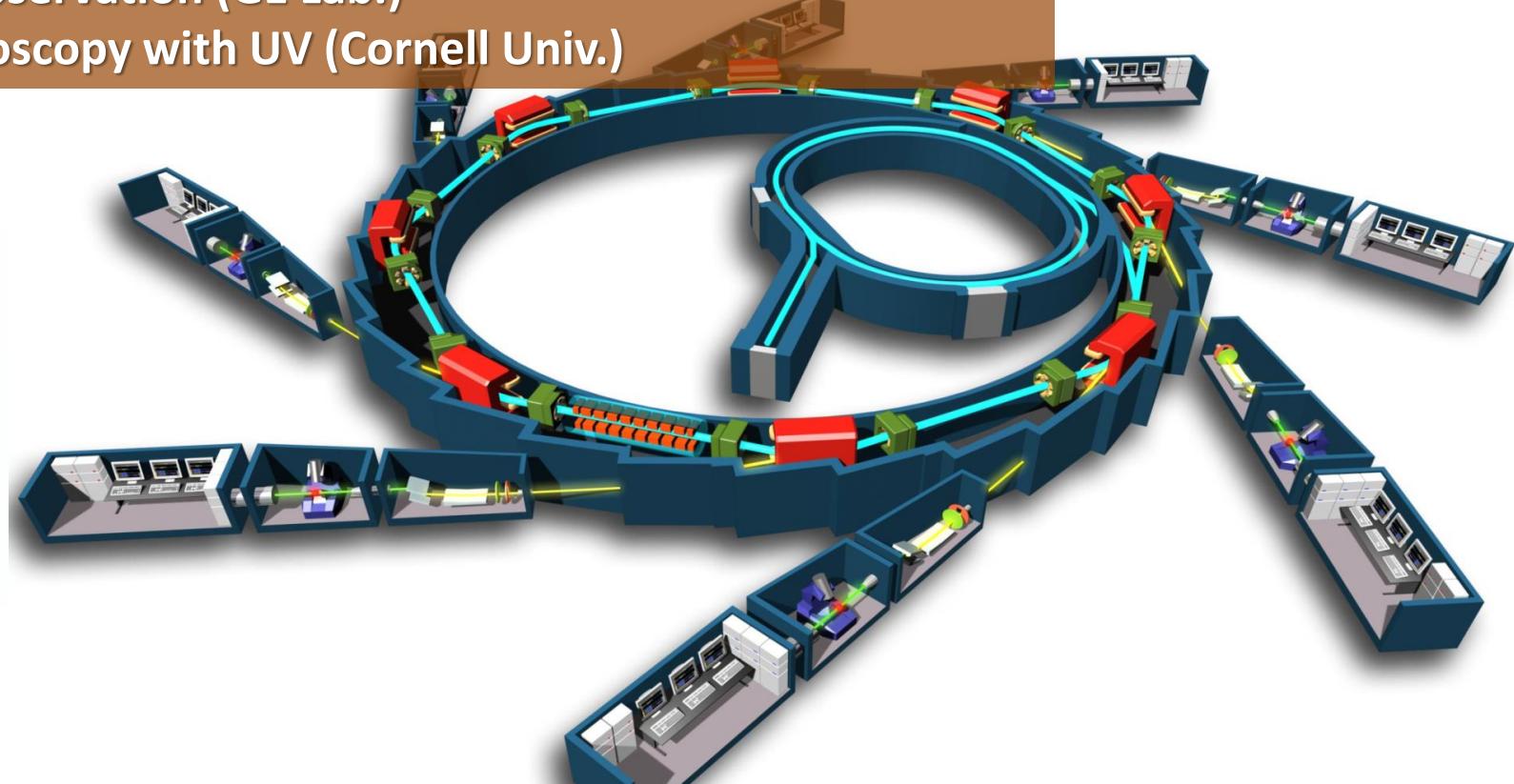
방사광 가속기



1944 : Theoretical prediction (D. Iwanenko, I. Pomeranchuk)

1947 : First observation (GE Lab.)

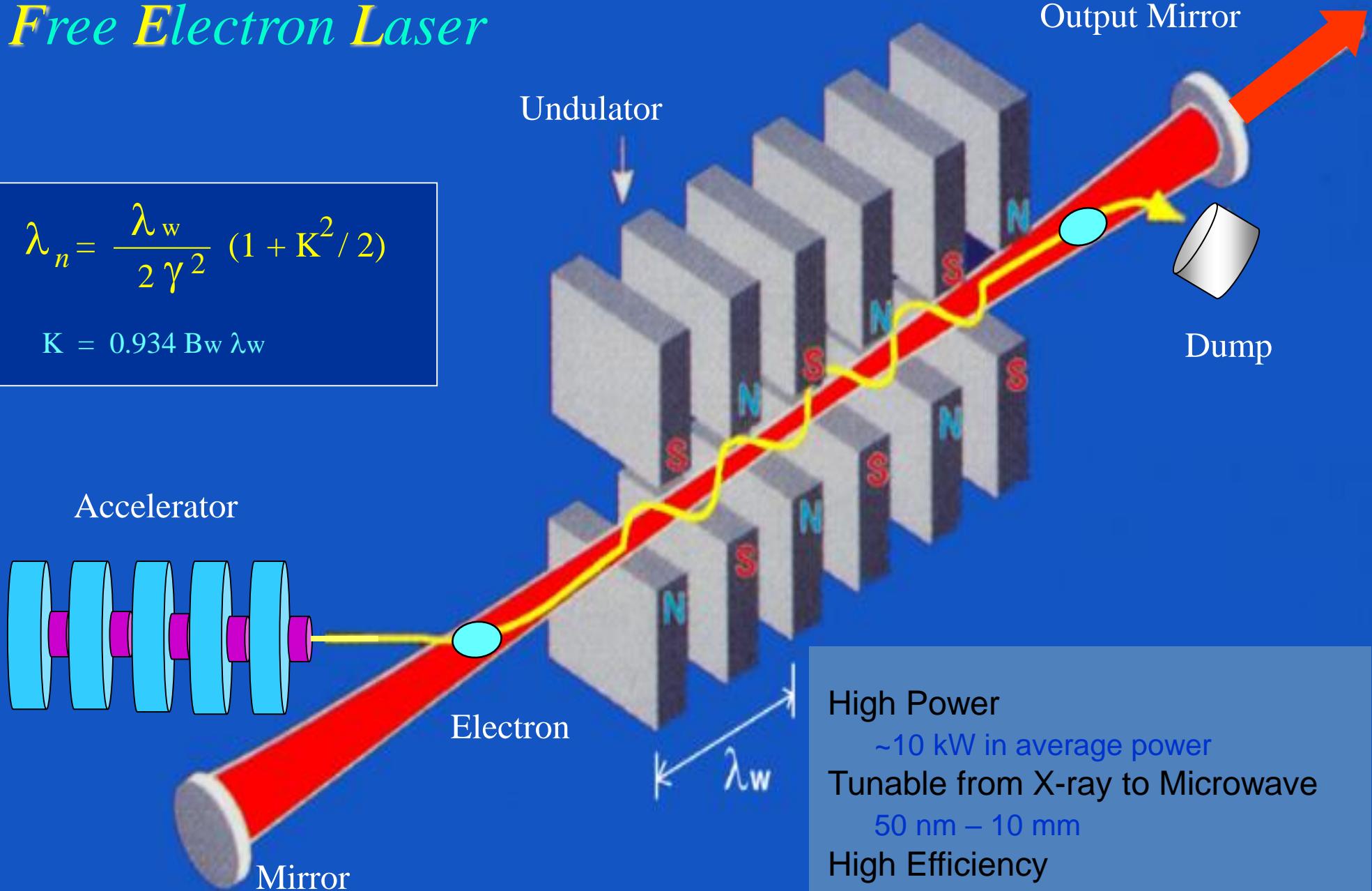
1956 : Spectroscopy with UV (Cornell Univ.)



- 1G (-70s): Study for high-energy physics
- 2G (70s-): Radiation from dipole magnet, userfacility
- 3G (90s-): Radiation from insertion devices (wiggler, undulator)
- 4G (00s-): X-ray free-electron laser, ultimate ring

Free Electron Laser

$$\lambda_n = \frac{\lambda_w}{2\gamma^2} (1 + K^2/2)$$
$$K = 0.934 B_w \lambda_w$$



High Power
~10 kW in average power
Tunable from X-ray to Microwave
50 nm – 10 mm
High Efficiency



II. Spatial Confinement of Free Electrons



지수와 SI 접두어

인자	접두어	인자	접두어
10^{24}	요타(Y)	10^{-1}	데시(d)
10^{21}	제타(Z)	10^{-2}	센티(c)
10^{18}	엑사(E)	10^{-3}	밀리(m)
10^{15}	페타(P)	10^{-6}	마이크로(m)
10^{12}	테라(T)	10^{-9}	나노(n)
10^9	기가(G)	10^{-12}	피코(p)
10^6	메가(M)	10^{-15}	펨토(f)
10^3	킬로(k)	10^{-18}	아토(a)
10^2	헥토(h)	10^{-21}	젭토(z)
10^1	데카(da)	10^{-24}	옥토(y)

사용빈도

자주



가끔



글쎄



전혀





우리가 보는 세상

$E=mc^2$

circus

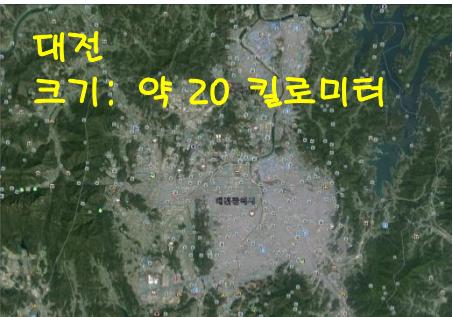
우주

크기: 약 160 억 광년
(10^{26} 미터 = 100 요타미터)



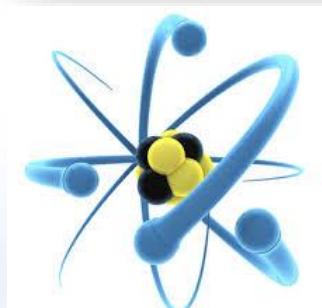
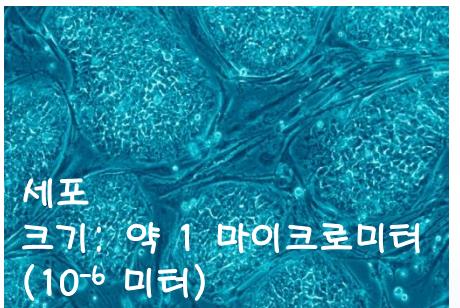
은하계

크기: 약 10 만 광년
(10^{21} 미터 = 1 제타미터)



사람

크기: 약 2 미터



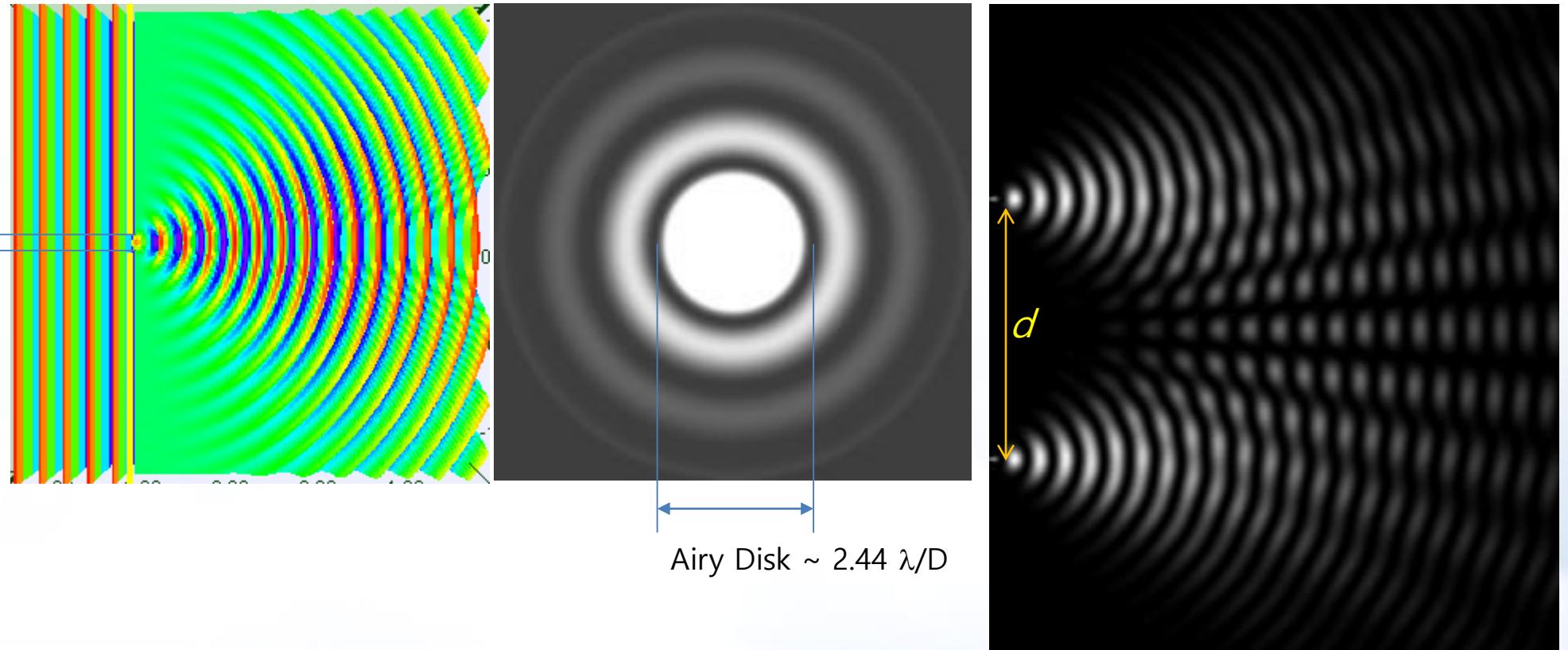
원자

크기: 약 0.1 나노미터
(10^{-10} 미터)

Diffraction & Interference



Diffraction by single hole

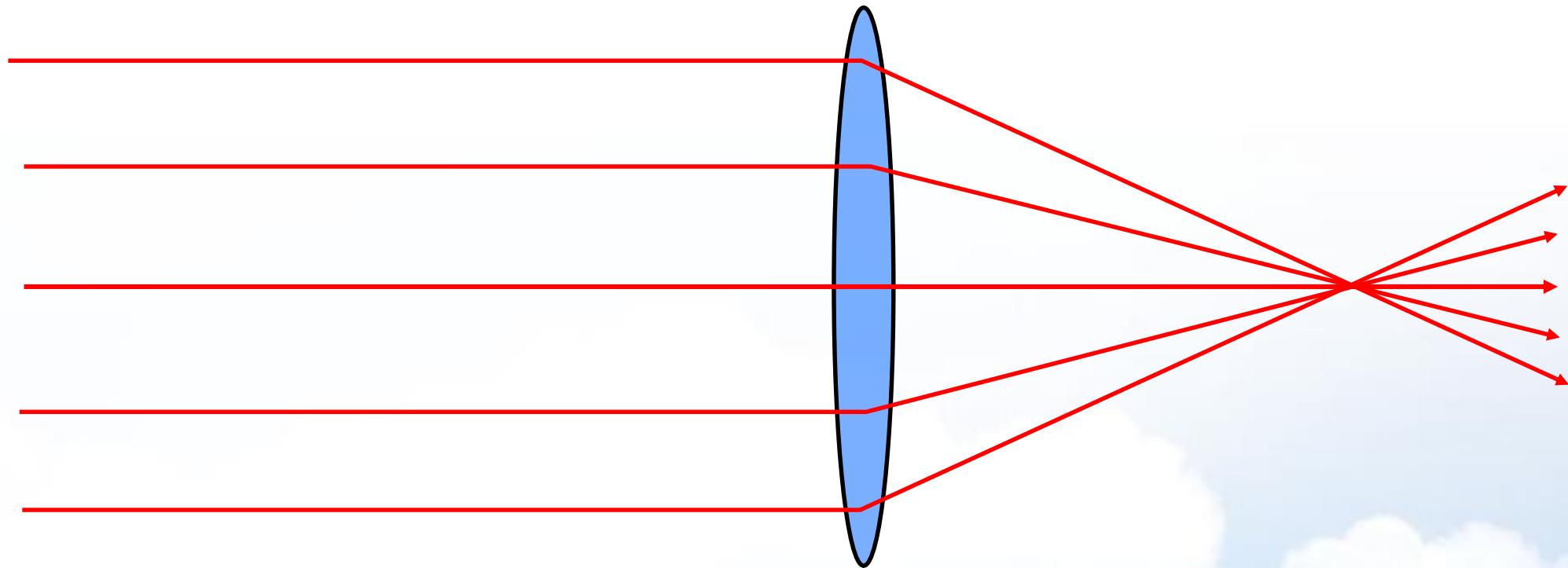


Interference by diffracted waves by two holes

$$n\lambda = d \sin\theta$$

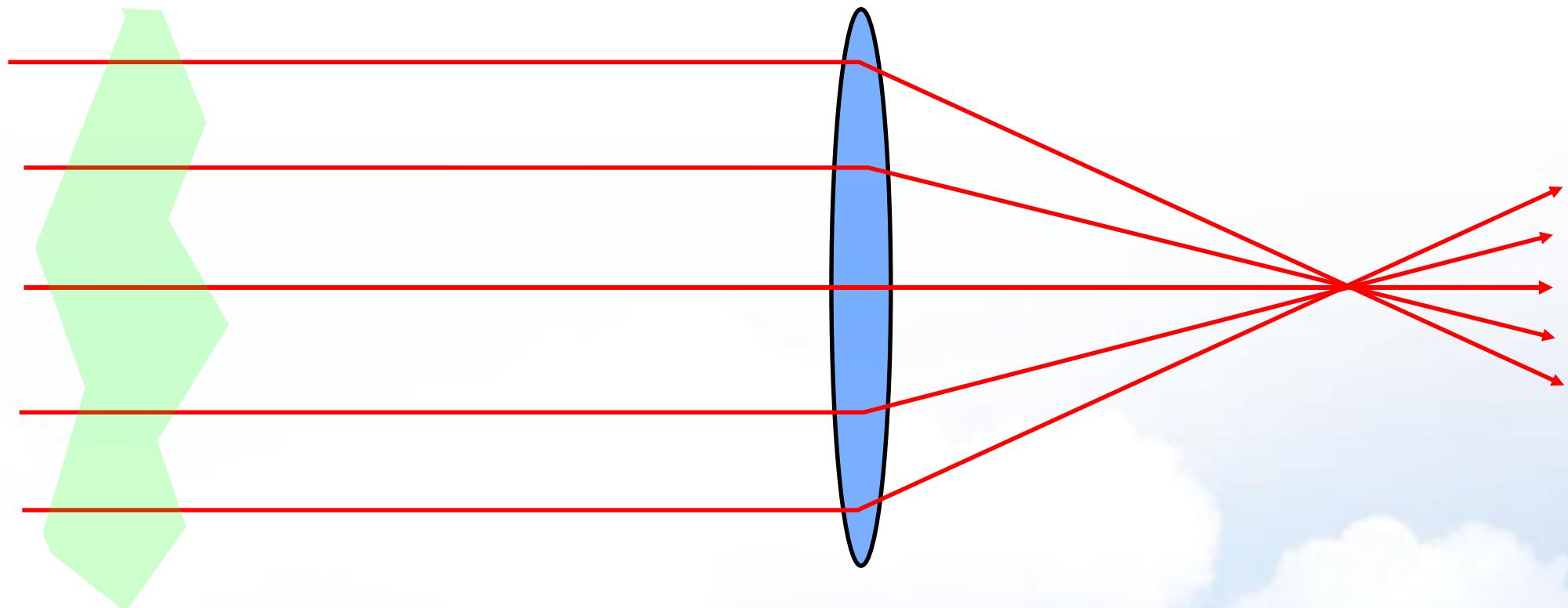


How are we able to see objects





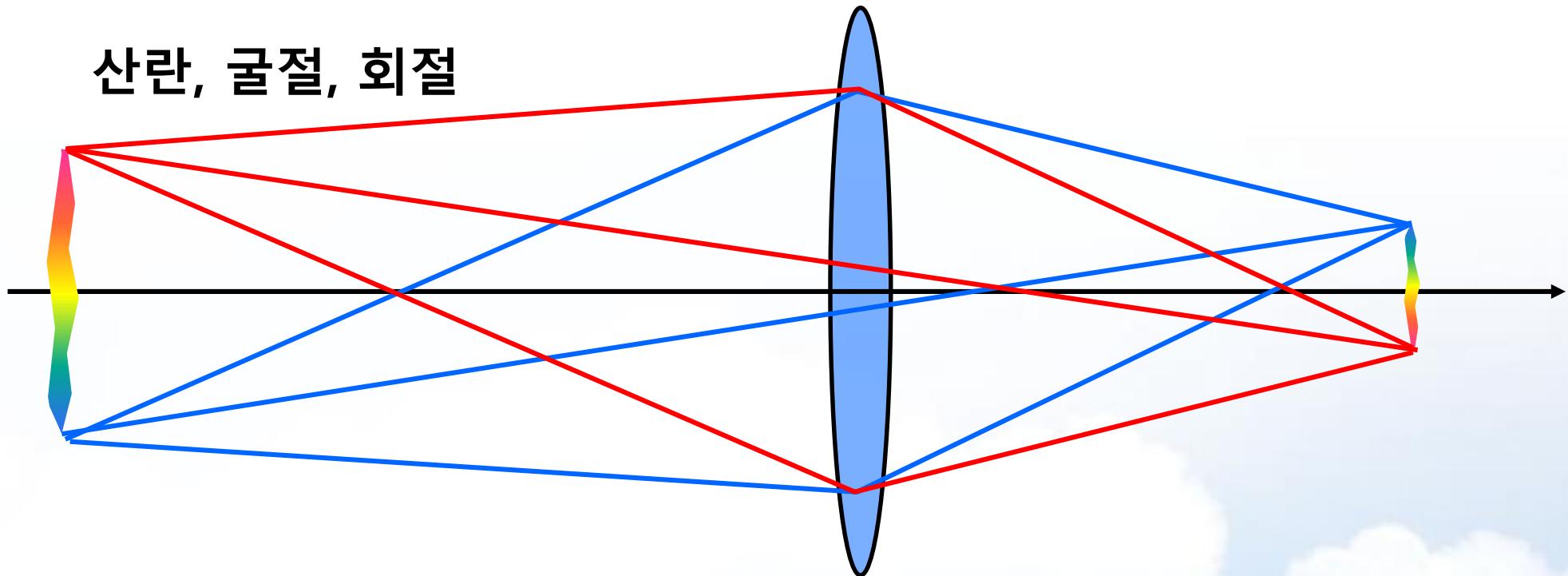
How are we able to see objects



How are we able to see objects



산란, 굴절, 회절

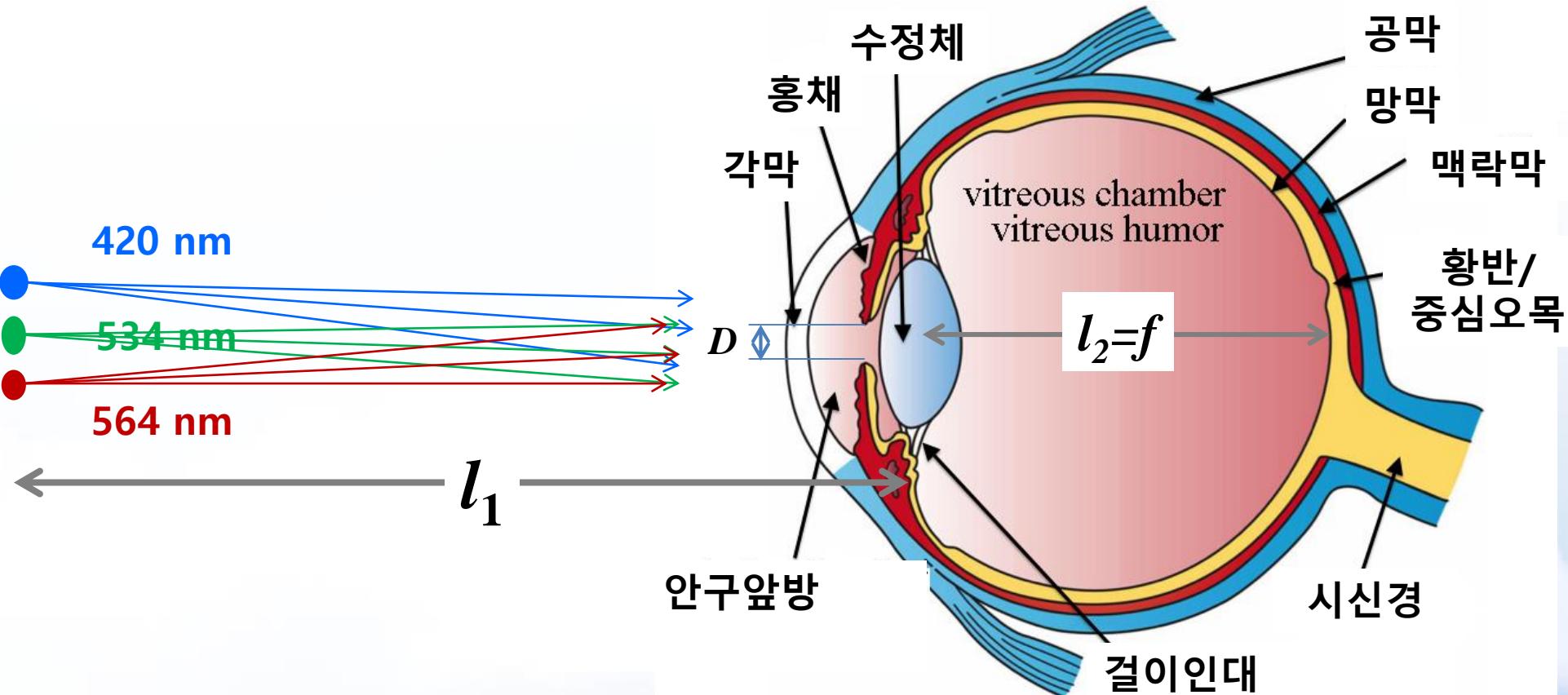


How are we able to see objects



$$f/2 \sim f/8$$

$$f/\# = f/D$$



$$\text{배율} = M = l_2/l_1$$

Spatial Resolution

공간분해능

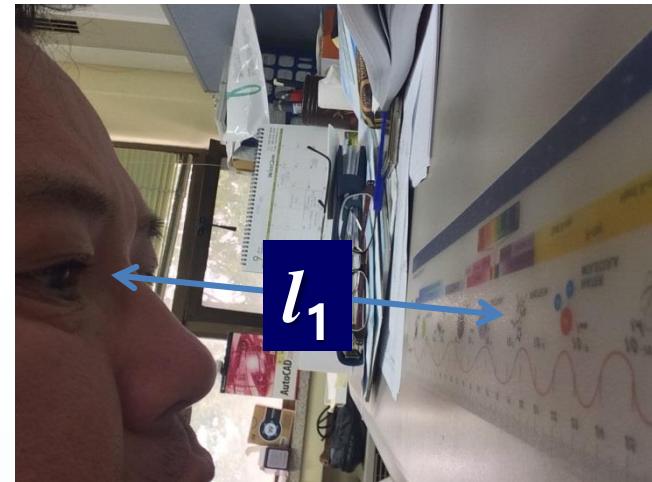


나의 눈

$$l_1 = 100 \text{ mm}, l_2 = f = 20 \text{ mm}$$

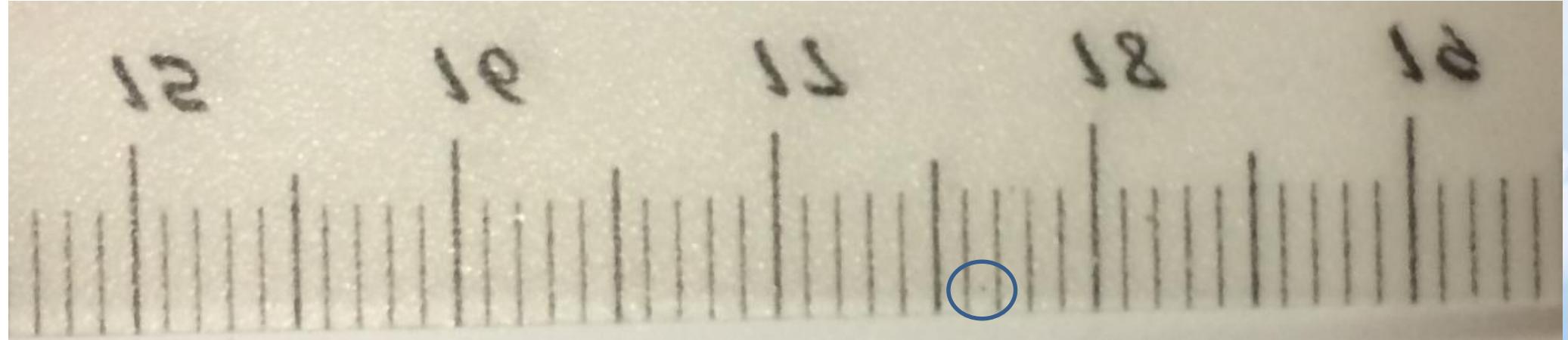
망막에서의 분해능 $\Delta l = 1.22f \frac{\lambda}{D} \approx 3 \mu\text{m}$

사물의 분해능 $= \Delta l \times \frac{l_1}{l_2} = 15 \mu\text{m}$



iPhone5S

iPhone 5S, 4.8X3.6 mm², $l_1 = 100 \text{ mm}$, $l_2 < 6 \text{ mm}$





How are we able to see objects

표면에서의 반사시 산란, 회절

16 More are we able to see objects
17 Diffraction & Interference
18 Specular reflection
19
20
21

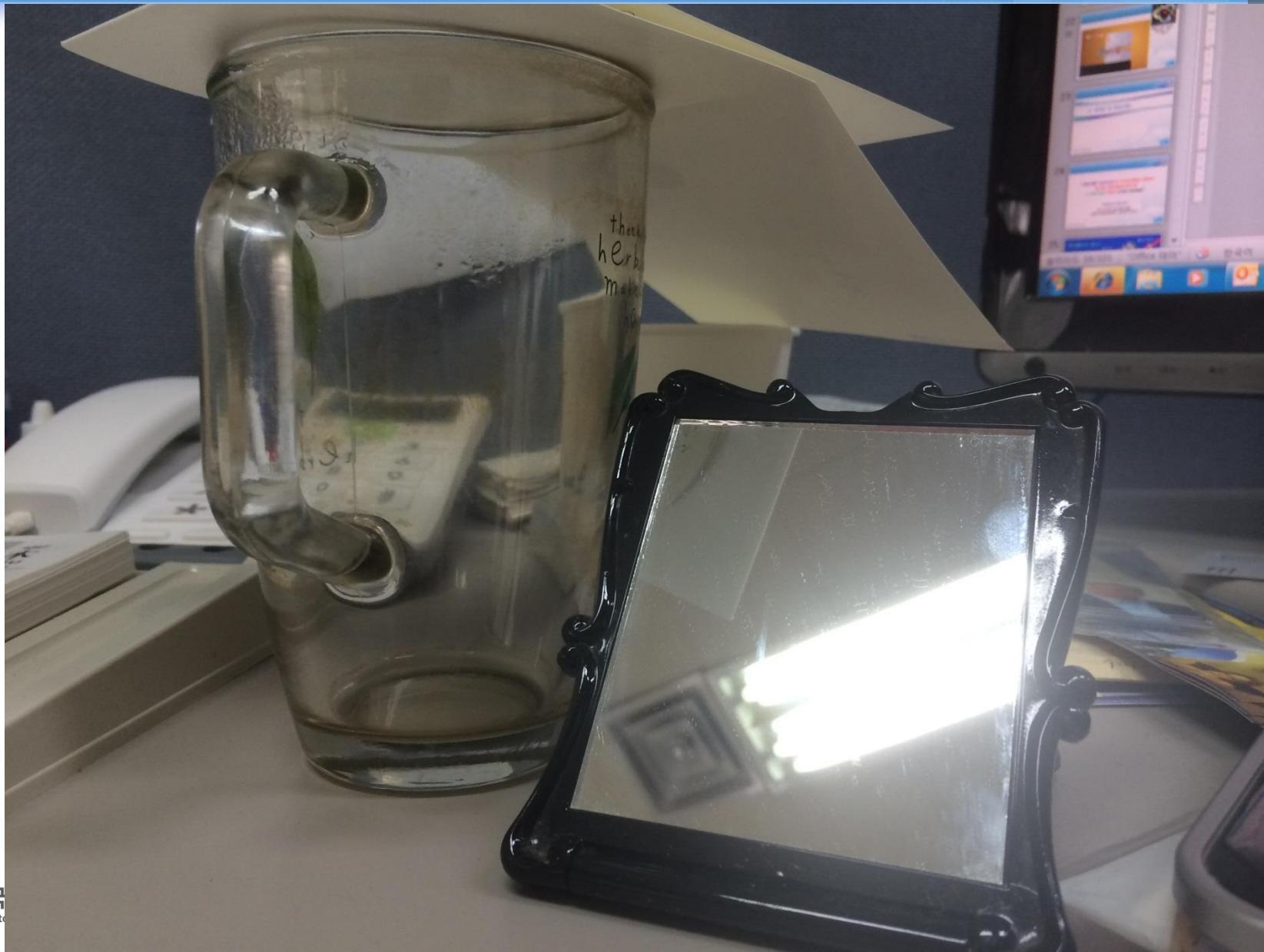
발광빛의 굴절, 회절

부서장	번호	전화번호
센터장	2913	010-7750-0032
부센터장	8342	010-3263-0277
책임연구원	8955	010-7672-3539
책임연구원	8932	010-2969-0549
책임연구원	2903	016-713-8055
책임연구원	8337	010-8028-5515
책임연구원	8337	010-5764-2111
	8932	010-6385-9538
	6108	010-4457-4112
	2723	010-8985-3130
	4595	010-5175-5660
	6108	010-9101-2018
	8337	010-5175-1128
	6108	010-2745-2051
	4596	010-4439-2450
	4595	010-4263-1989
	4596	010-3580-8372
	2903	010-5107-0908
	4825	010-2998-0135
	2913	010-3082-3802
	8337	010-9613-0052
	2723	010-4550-1052
	6108	010-7674-7118

한국
KAERI
Korea At

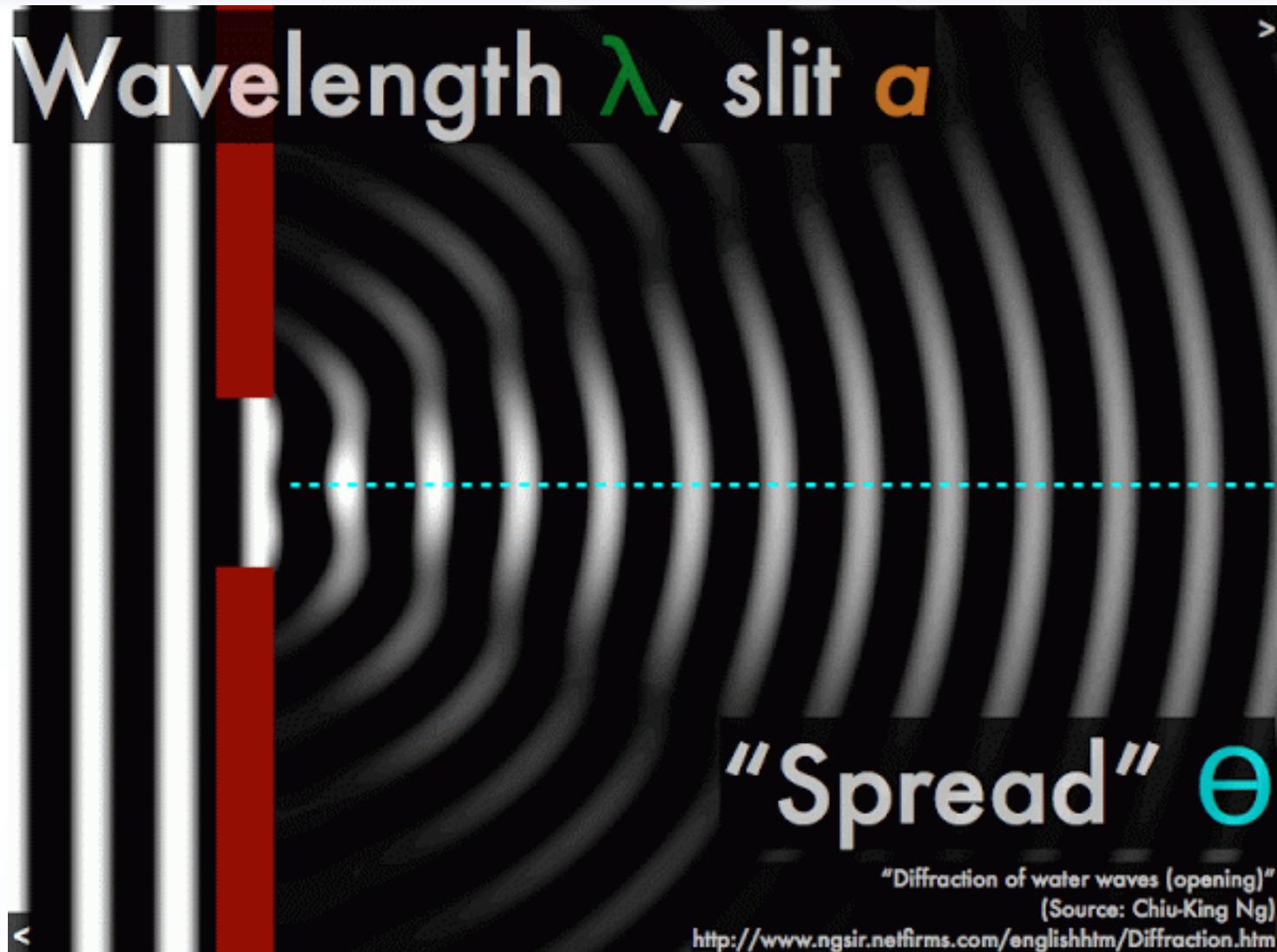


How are we able to see objects



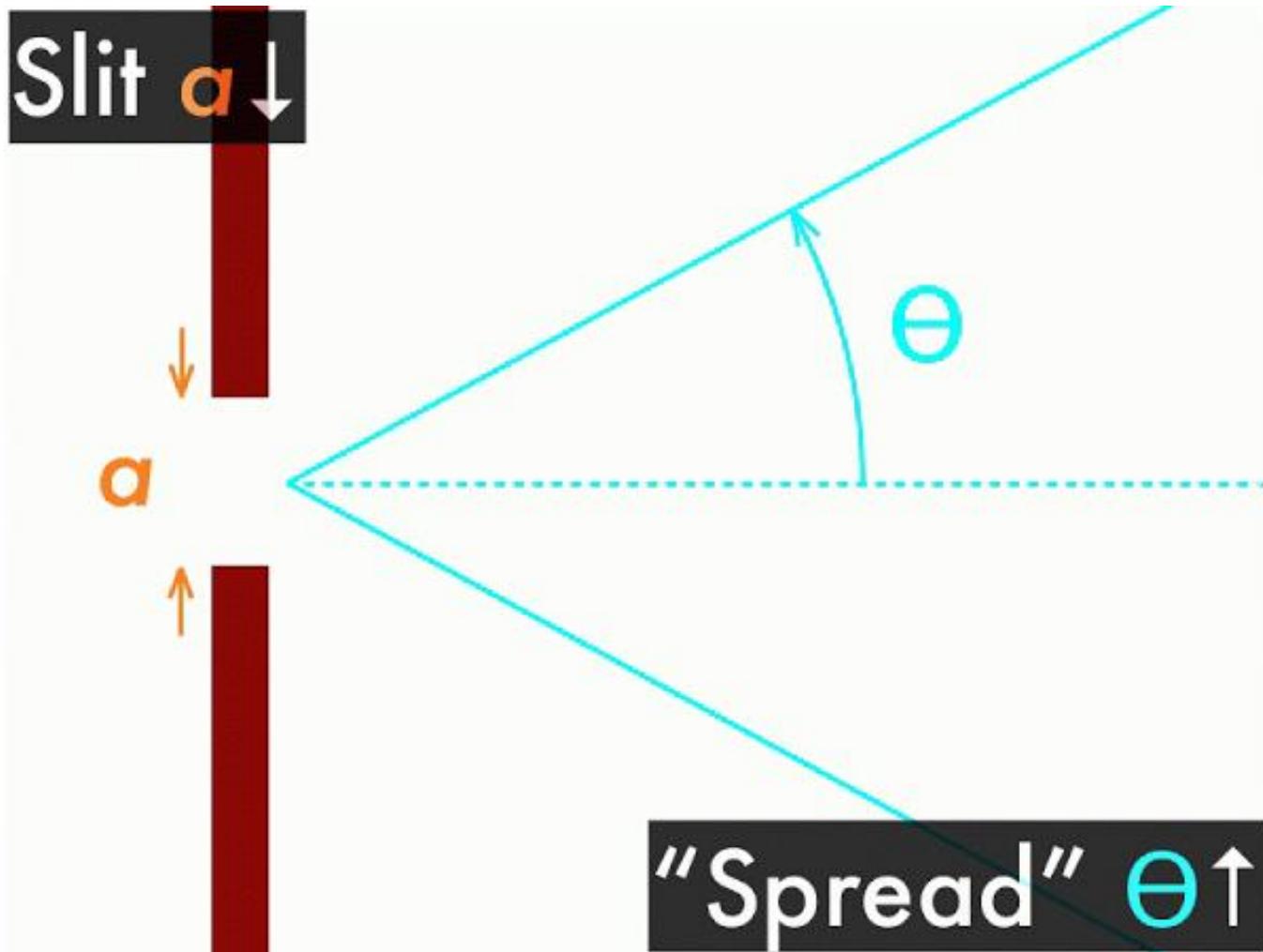
Diffraction

회절



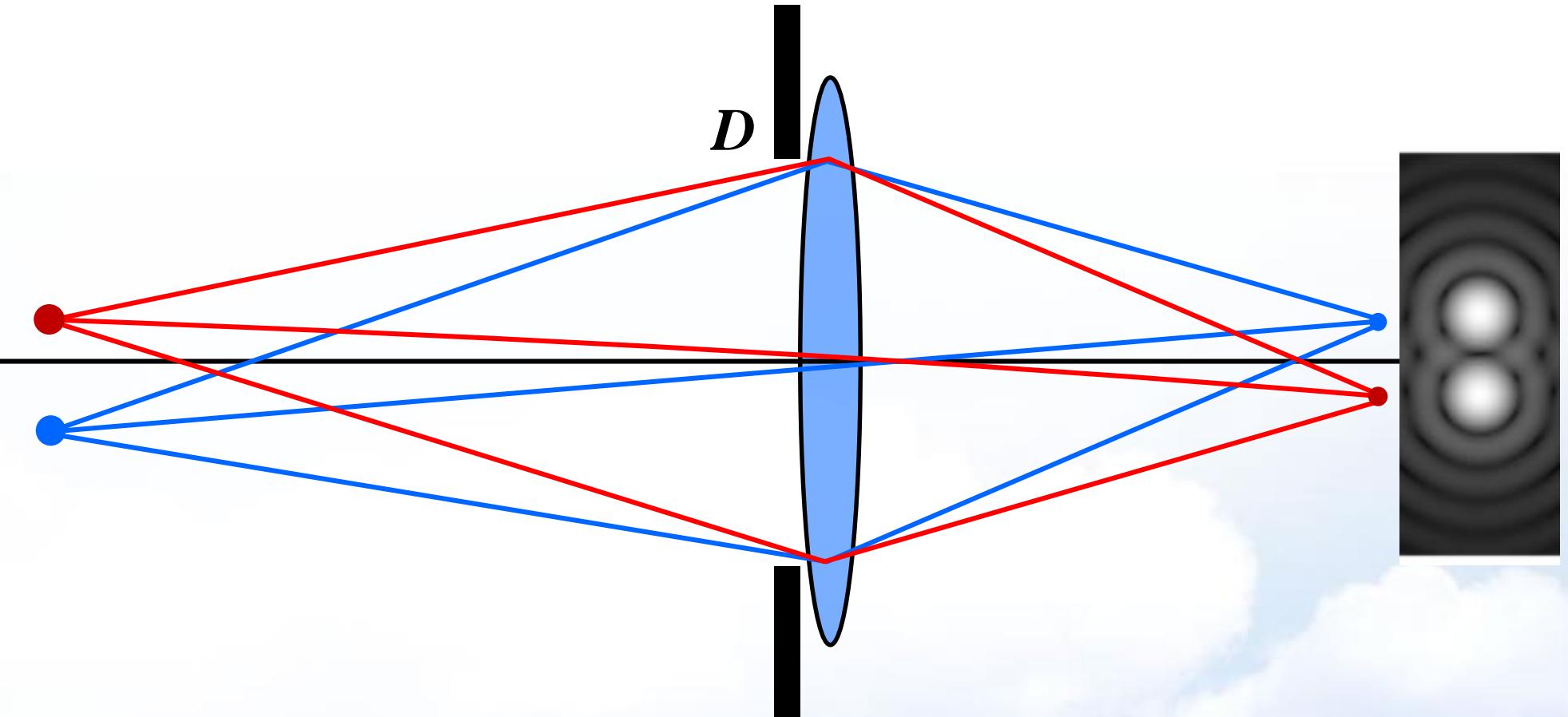
Diffraction

회절



Diffraction

회절



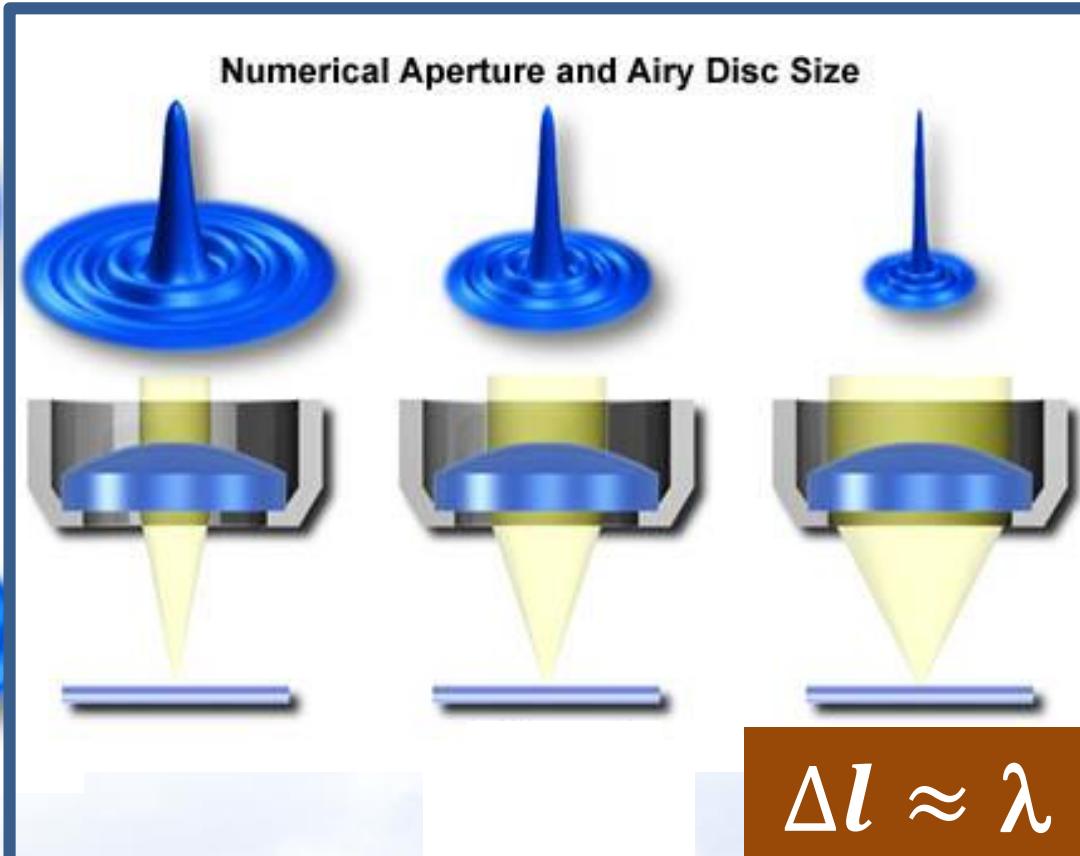
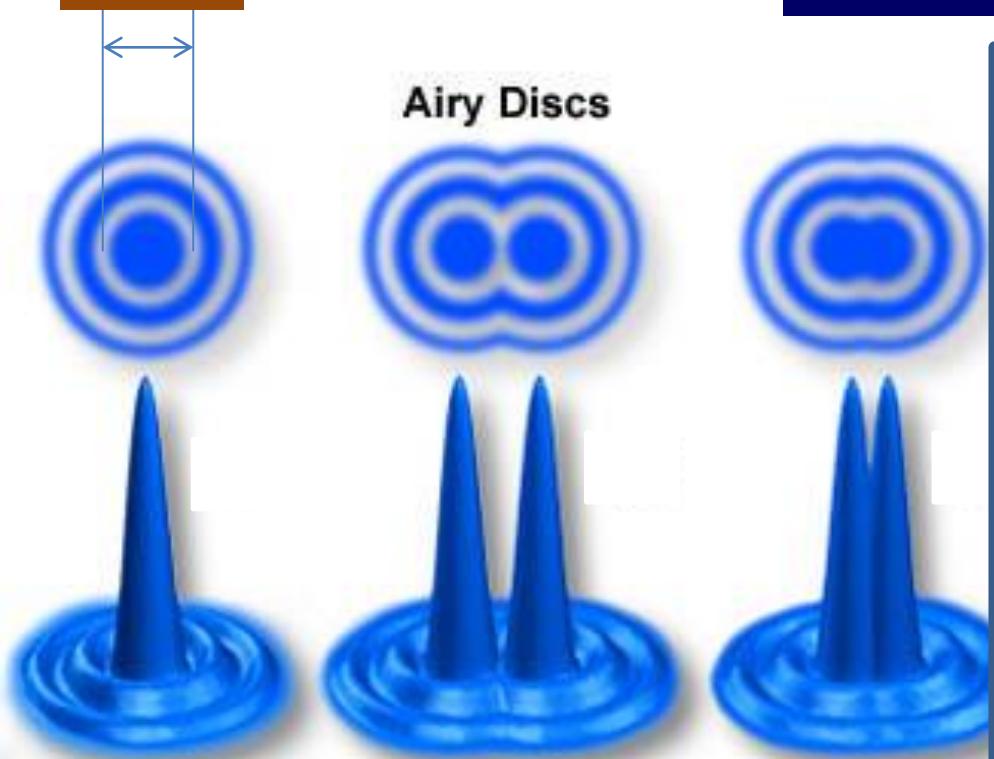
Resolving Power

분해능



$$2\Delta l$$

$$\Delta l = 1.22f \frac{\lambda}{D}$$



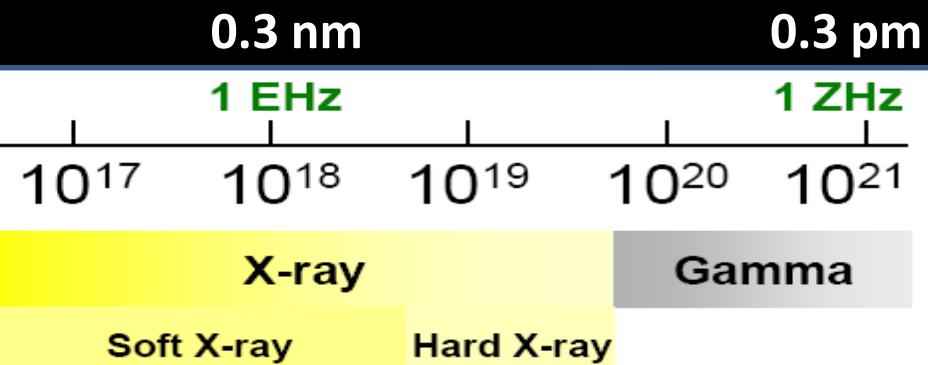
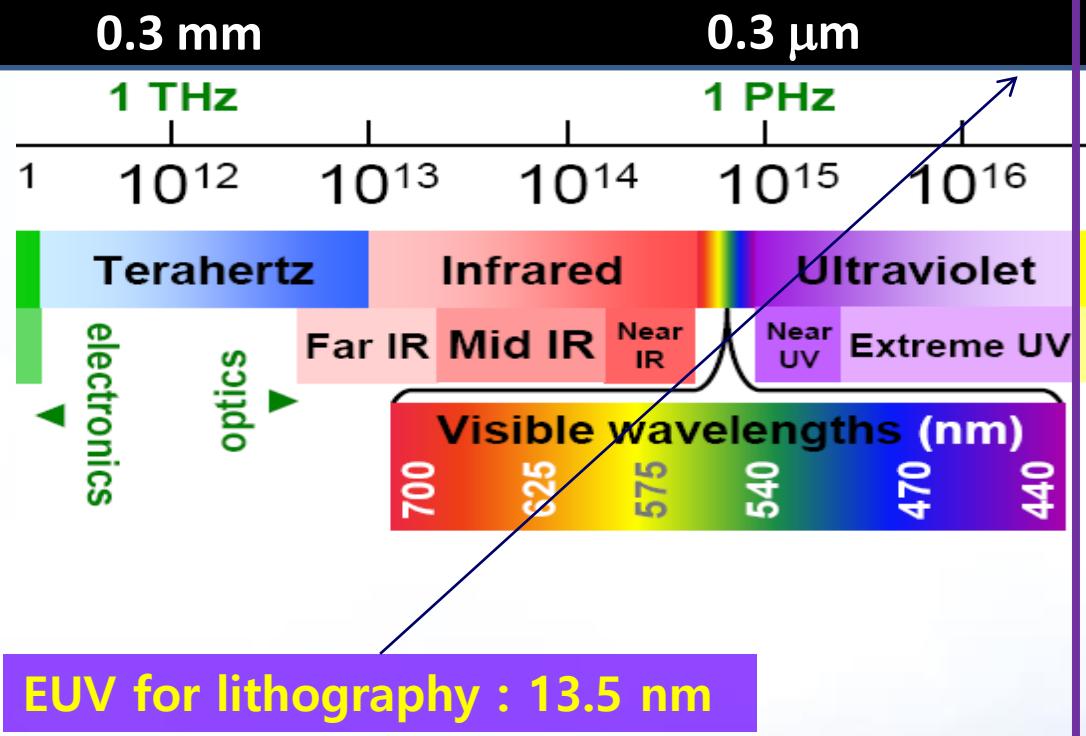
Resolving Power

분해능



$$\Delta l \approx \lambda$$

Size of molecules : 0.1 ~ 100 nm



Resolving Power

분해능



Louis de Broglie (1892~1987)
Y1929 Novel laureate

$$\Delta l \approx \lambda$$

Matter Wave, Wavelength

$$\lambda = \frac{h}{p}$$

h : Plank constant

p : Momentum

Electron Kinetic Energy [MeV]	0.1	0.3	1	3	10
λ	3.7 pm	1.97 pm	0.872 pm	0.357 pm	0.118 pm

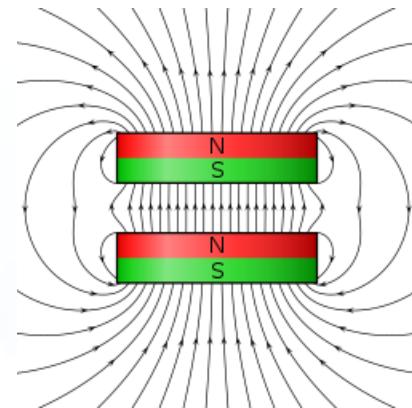
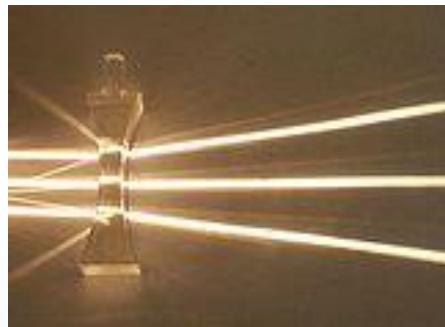
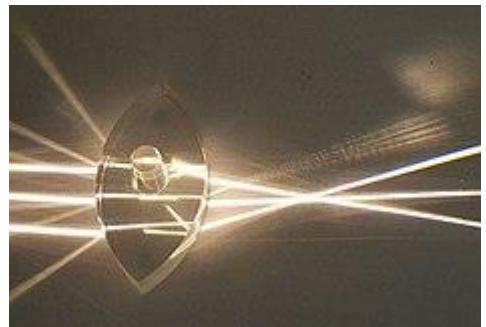
Size of molecules : 0.1 ~ 100 nm

Electron Optics

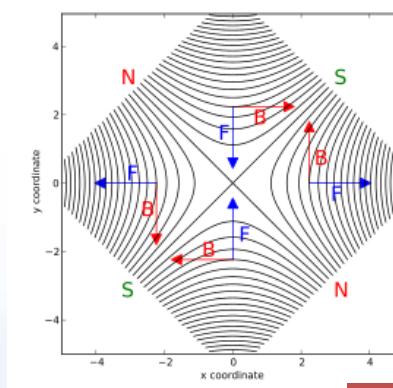
전자광학



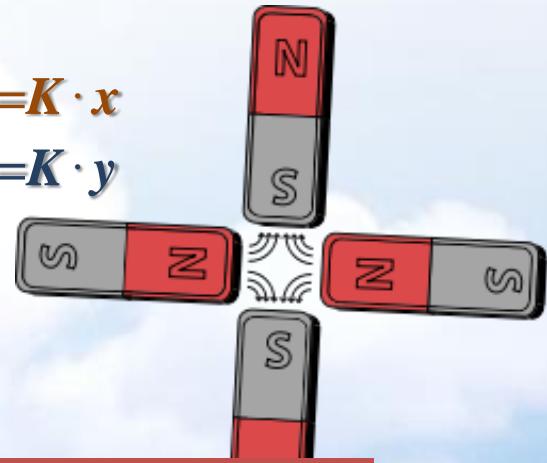
$$\vec{\mathbf{F}} = q(\vec{\mathbf{E}} + \vec{\mathbf{v}} \times \vec{\mathbf{B}})$$



Dipole magnet



$$B_x = K \cdot x$$
$$B_y = K \cdot y$$



Quadrupole magnet

Microscopes

광학현미경과 전자현미경



Light Microscopy

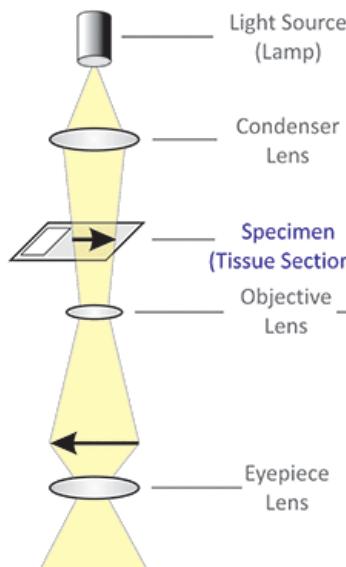


Image Viewed
Directly

500X~1500X

Transmission
Electron Microscopy

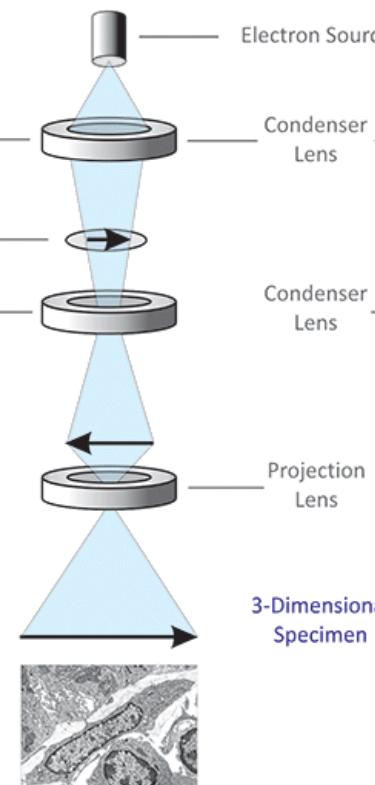


Image Viewed on
Fluorescent Screen

100,000X~300,000X

Scanning
Electron Microscopy

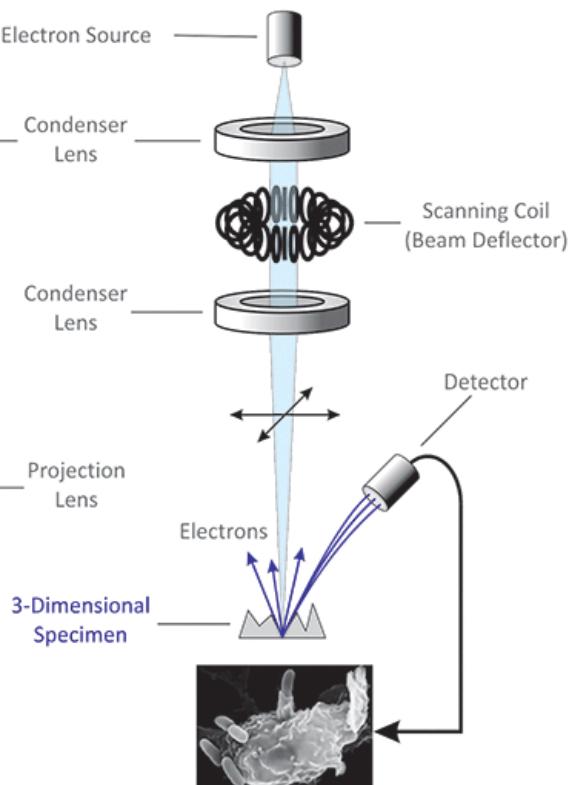


Image Viewed
on Monitor



출처 : microbiologyinfo.com

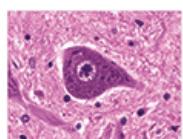


Image Viewed
Directly

500X~1500X

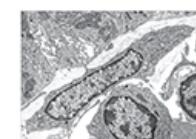
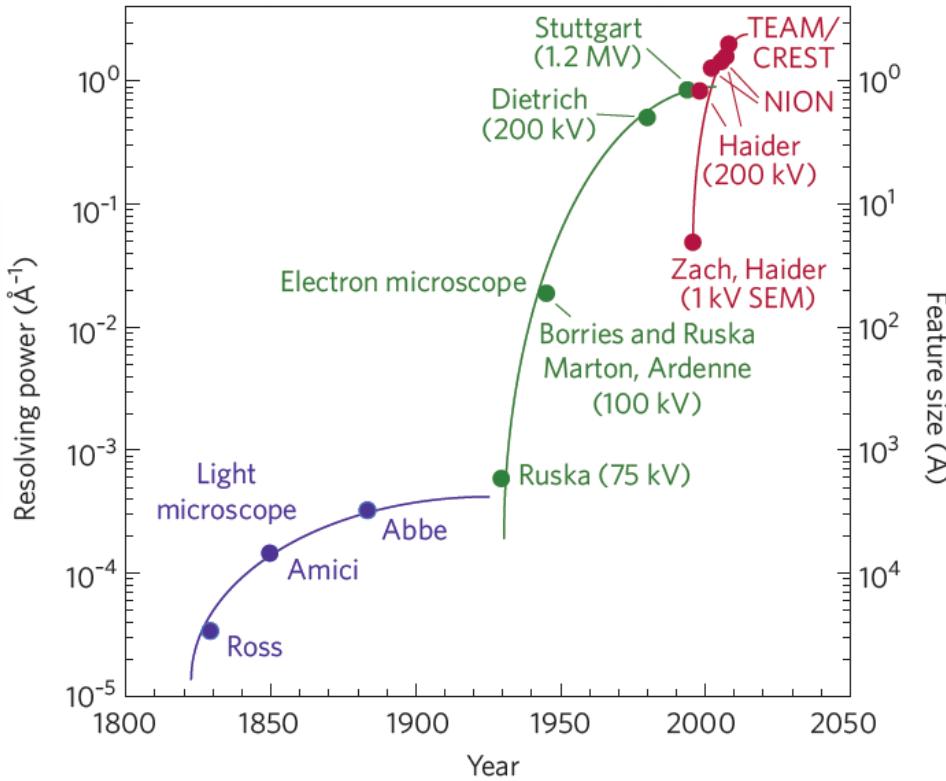


Image Viewed on
Fluorescent Screen

100,000X~300,000X

Resolving Power of Microscopes

현미경 공간분해능



D. A. Muller, *Nat. Mater.* **8**, 263 (2009).



Resolving Power of Microscopes

현미경 공간분해능



Spatial Resolution of 40.5 pm with a STEM

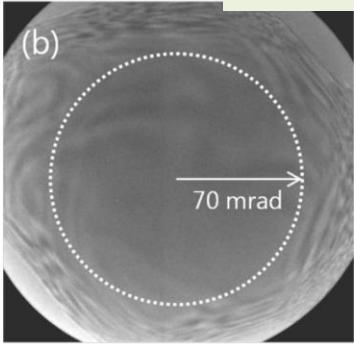
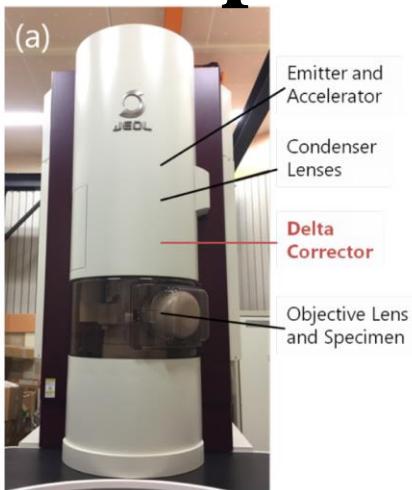


Figure 1. (a) 300 kV electron microscope (GRAND ARM) equipped with a delta corrector and a cold field emission gun for STEM. (b) Ronchigram at 300 kV after aberration correction with delta type corrector for probe forming system.

$$\Delta l = 1.22 f \frac{\lambda}{D} = 0.61 \frac{\lambda}{\alpha}$$

30.5 pm

$$\alpha = \frac{D}{2f} \quad \text{Convergence angle (Numerical Aperture)}$$

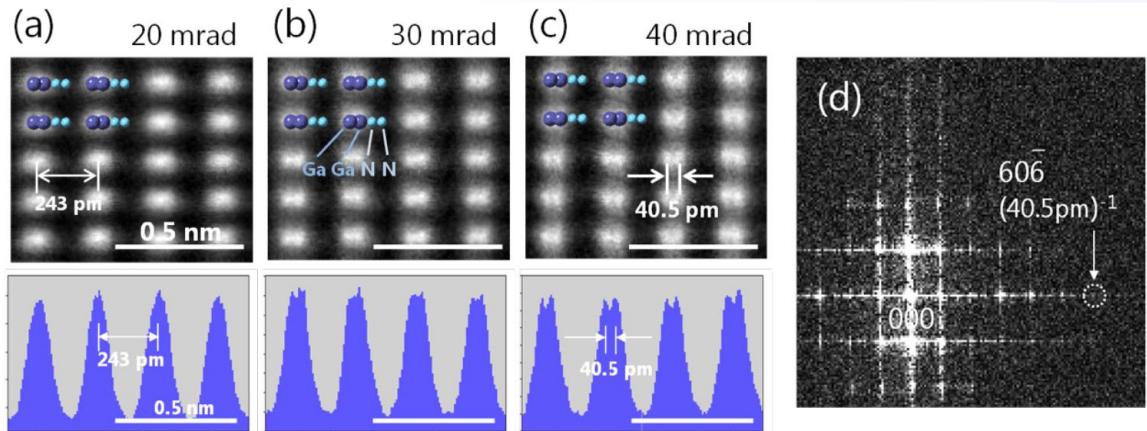
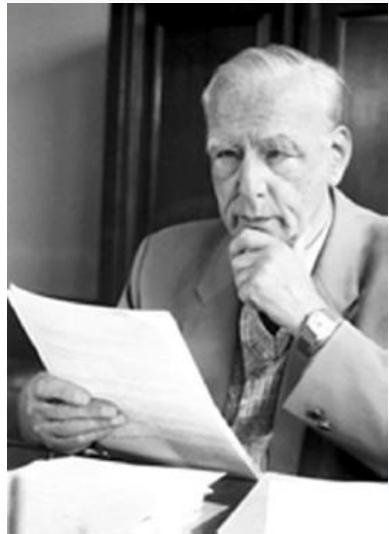


Figure 2. ADF STEM images of GaN [212] with convergence semi-angles of (a) 20 mard, (b) 30 mrad and (c) 40 mrad. Intensity profiles of these images are also shown below. (d) Modulus of the Fourier transform from the image obtained with the 40 mrad convergence angle.

Brightness

전자빔 밝기



Ernst Ruska,
1986 Nobel Prize
for the invention
of the electron microscope

$$B = \frac{I}{S\Omega}$$

Current

Beam cross-section

Beam solid angle

$B_{\text{microscope}} \sim 10^{13} \text{ A/m}^2/\text{sr}$

$$B = \eta \frac{I}{\epsilon_x \epsilon_y}$$

Transverse emittances

Coherence Length

결맞음 길이



$$l_{\text{longitudinal coherence}} \propto \frac{1}{\Delta E}$$

ΔE : Energy spread of e-beam

$$l_{\text{transverse coherence}} \propto \frac{1}{R_{\text{source}}}$$

R_{source} : Electron beam radius at the source

Emittance

에미턴스



Electrons moving through z-axis

$$\sigma_x = \sqrt{\frac{1}{N} \sum_{i=1}^N (x_i - \langle x \rangle)^2}$$

$$\sigma'_x = \sqrt{\frac{1}{N} \sum_{i=1}^N (x'_i - \langle x' \rangle)^2} \quad x' = \frac{dx}{dz}$$

$$\sigma_y = \sqrt{\frac{1}{N} \sum_{i=1}^N (y_i - \langle y \rangle)^2}$$

$$\sigma'_y = \sqrt{\frac{1}{N} \sum_{i=1}^N (y'_i - \langle y' \rangle)^2} \quad y' = \frac{dy}{dz}$$

Deviation of electron's position

Deviation of electron's angle

$$\epsilon_x = 4\sigma_x \sigma'_x$$

$$\epsilon_y = 4\sigma_y \sigma'_y$$

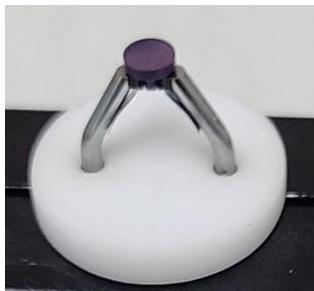
Conserved with linear optics (Liouville's theorem)

Electron Sources

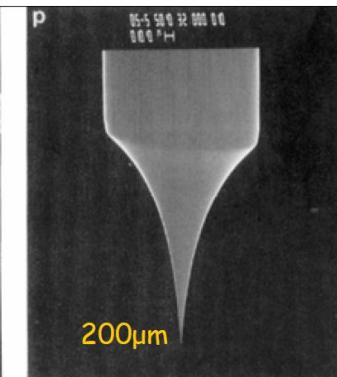
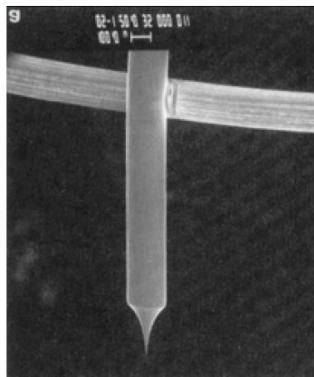
전자총



- Thermionic gun



- Field emission gun



- Photoelectron gun



Electron Sources

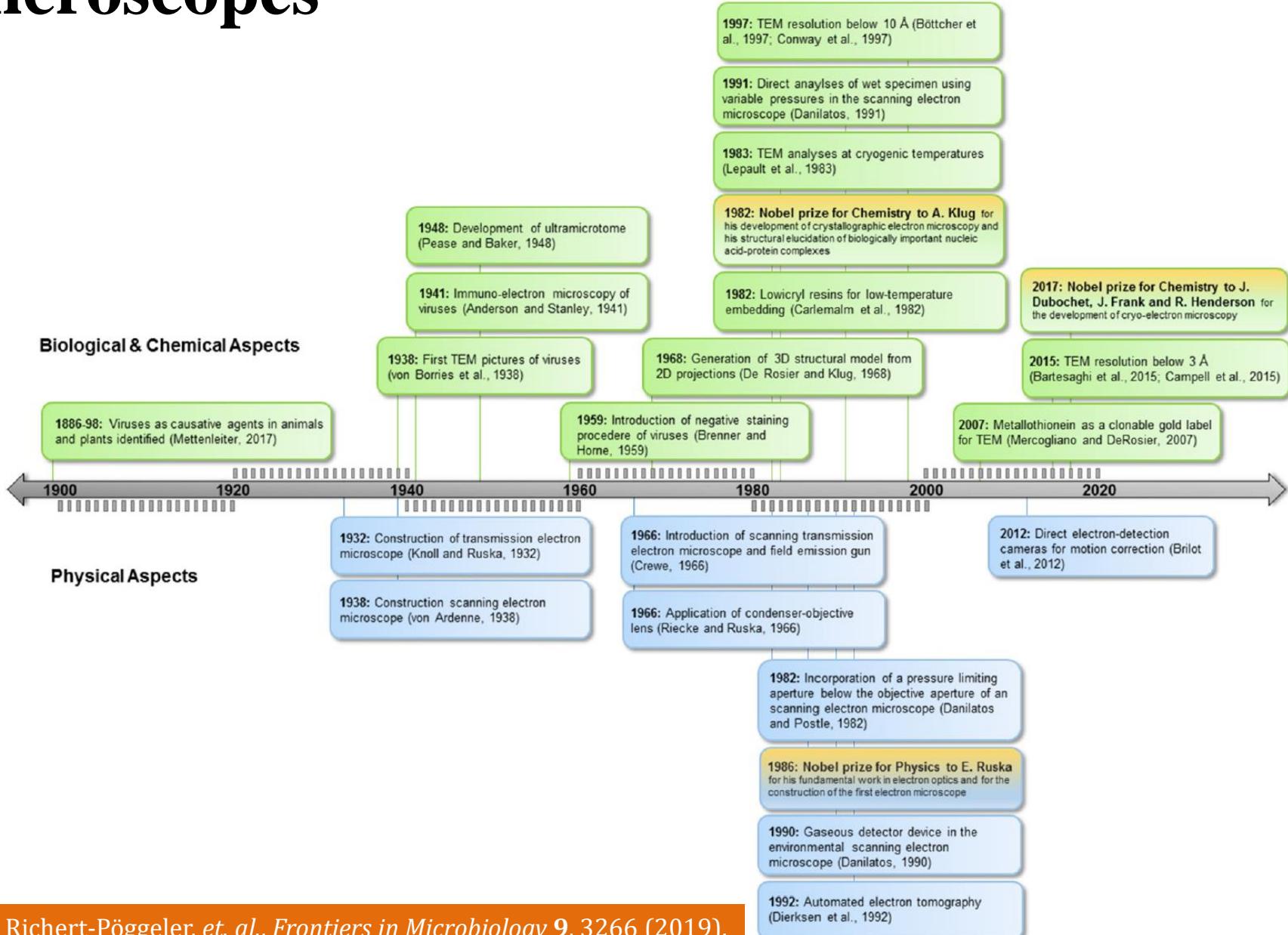


Characteristics of the 3 principal sources operating 100 kV

	Tungsten	LaB ₆	Field Emission
Operating temp. (K)	2700	2000	300
Current density (A/cm ²)	5	100	10 ⁶
Crossover size (μm)	50	10	< 0.01
Brightness (A/m ² /sr)	10 ⁹	5 × 10 ¹⁰	10 ¹³
Energy spread (eV)	3	1.5	0.3
Vacuum (Pa)	10 ⁻²	10 ⁻⁴	10 ⁻⁸
Lifetime (hr)	100	500	> 1000
Emission current stability (%/hr)	< 1	< 1	5

History of Electron Microscopes

전자현미경의 역사





III. Temporal Confinement of Free Electrons

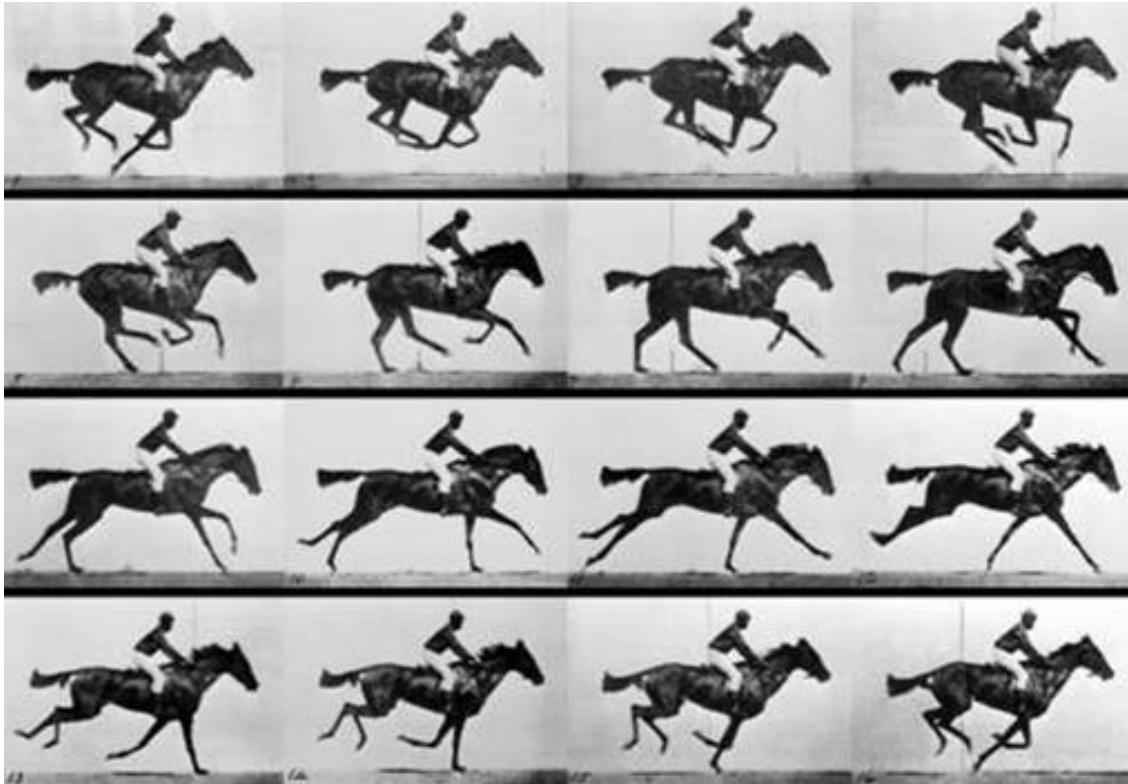


고구려 무용총 수렵도

Le derby d'Epsom, painting
by [Théodore Géricault](#), 1821



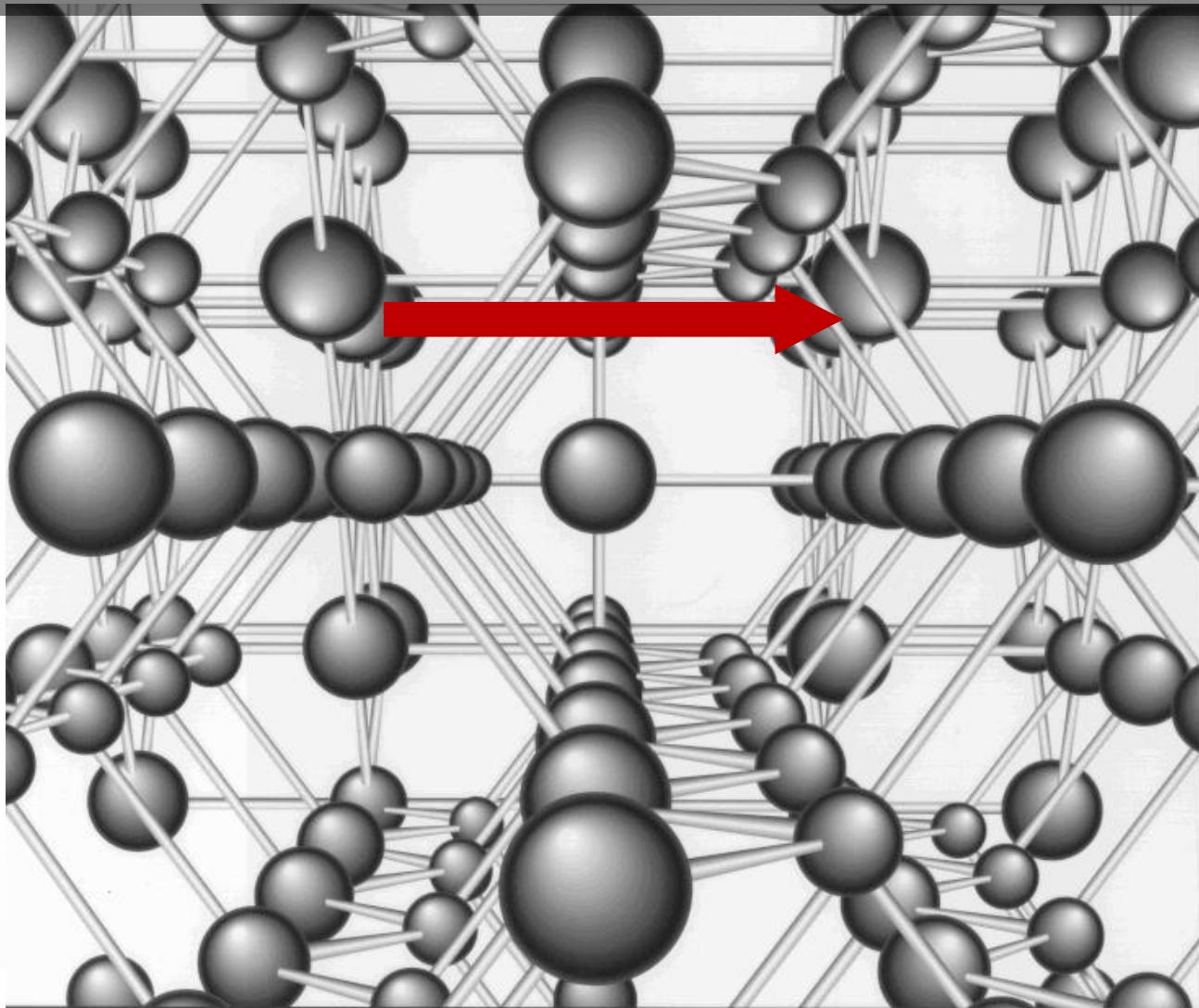




Eadweard Muybridge (1830. 4. 9 ~ 1904. 5. 8)



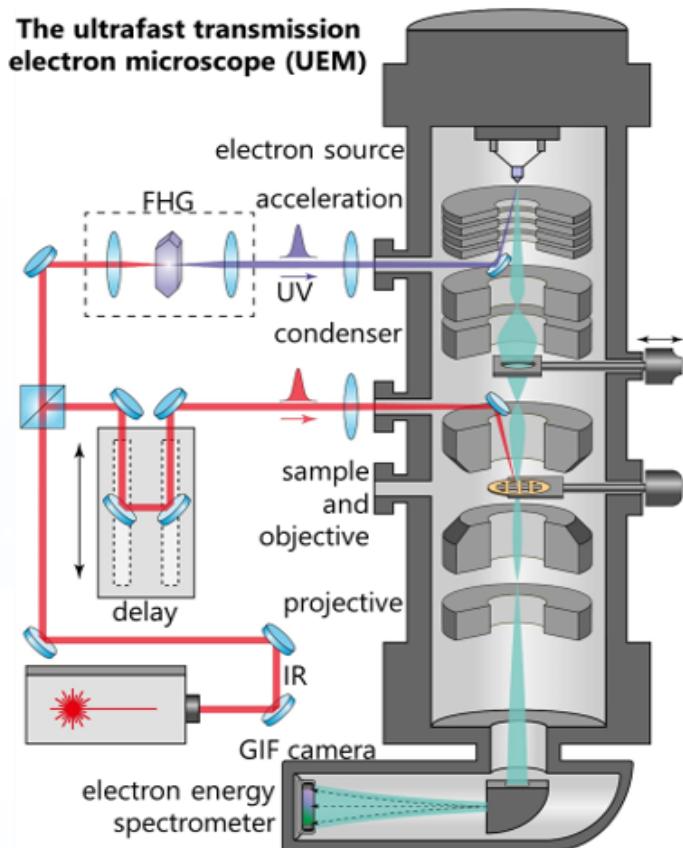
Time for sonic wave passing through a molecule 10~1000 fs



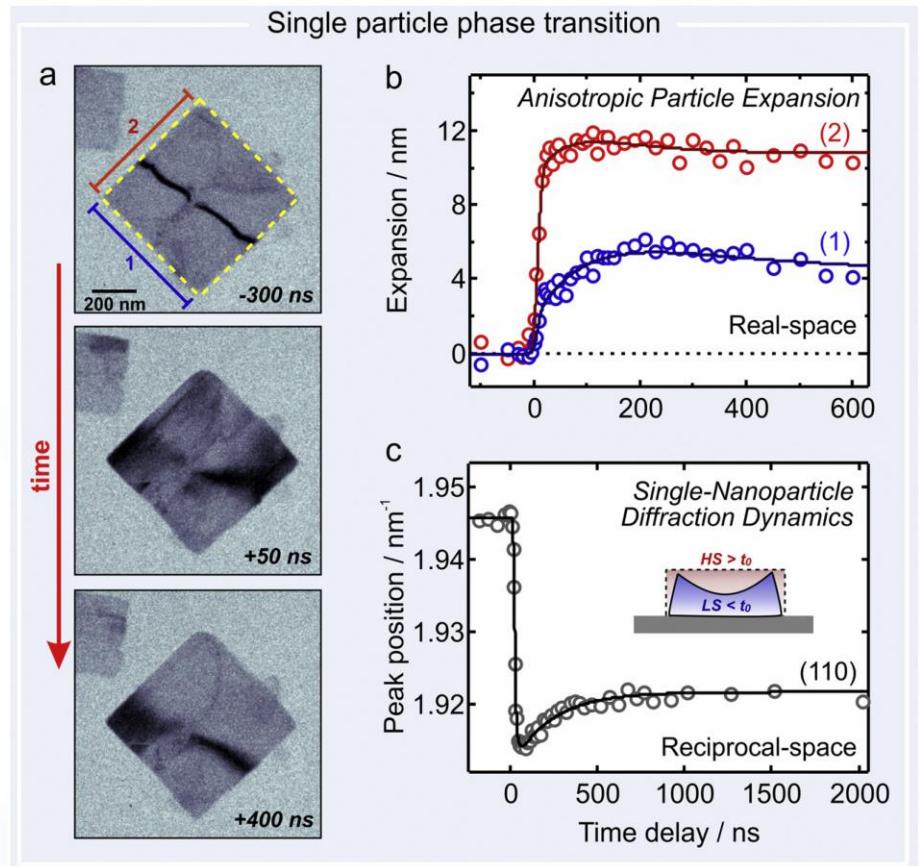
시분해 전자현미경



Time-resolved TEM (UEM or UED)



Referred from website of Kaminer group @ TECHNION

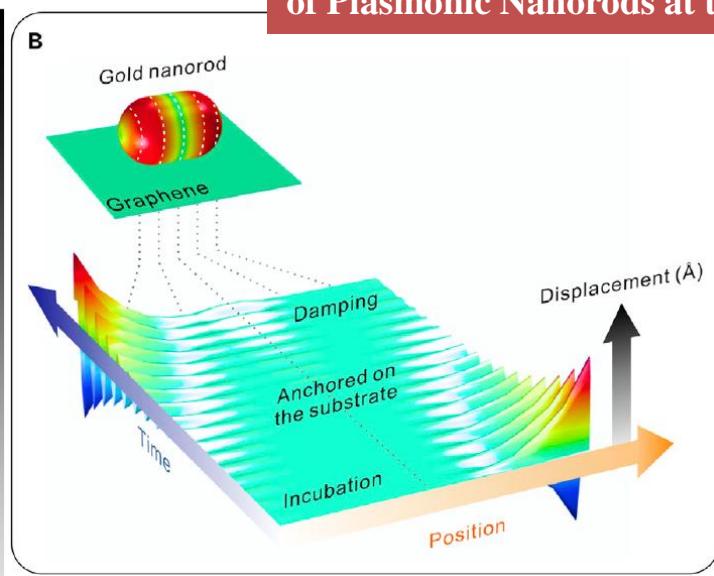
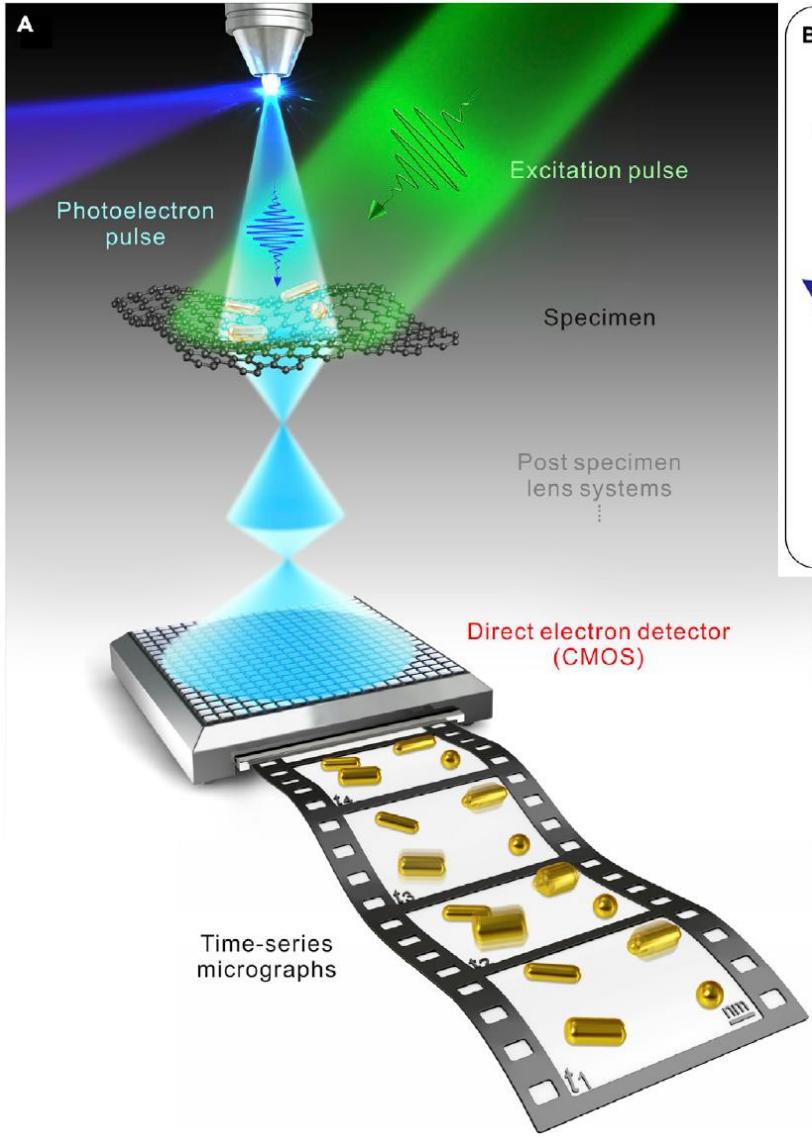


R.M. van der Veen *et al.*, *Nat. Chem.* **5**, 395-402 (2013).

시분해 전자현미경



Time-resolved TEM (UEM)



Ultrafast Electron Microscopy Visualizes Acoustic Vibrations of Plasmonic Nanorods at the Interfaces, Matter 1, 481, 2019

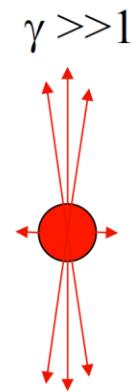
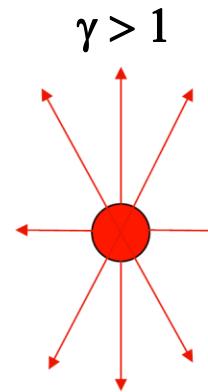
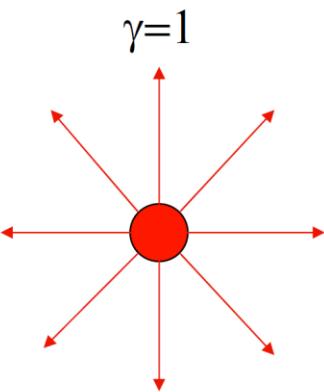
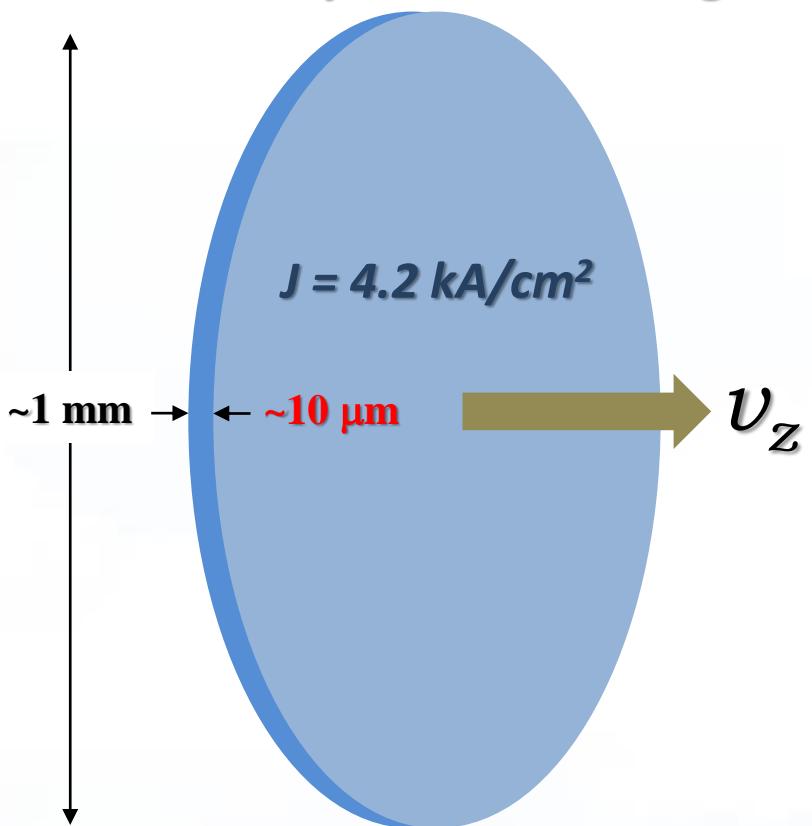


Electron Flash

초고속 전자빔



*Compressed electron beam of
30 fs bunch duration
and 1 pC bunch charge*



$$E_r(z=0) = \frac{q}{4\pi\epsilon_0} \frac{\gamma}{r^2},$$

$$B_\varphi(z=0) = \frac{q\beta}{4\pi\epsilon_0 c} \frac{\gamma}{r^2},$$

$$E_z(r=0) = \frac{q}{4\pi\epsilon_0} \frac{1}{\gamma^2 z^2}$$

$$F_r = q(E_r - \beta c B_\varphi) = \frac{qq\gamma}{4\pi\epsilon_0 r^2} (1 - \beta^2) = \frac{q^2}{4\pi\epsilon_0 \gamma} \frac{1}{r^2}$$



Chirped Pulse Amplification

$E = mc^2$

circus

Volume 56, number 3

OPTICS COMMUNICATIONS

1 December 1985

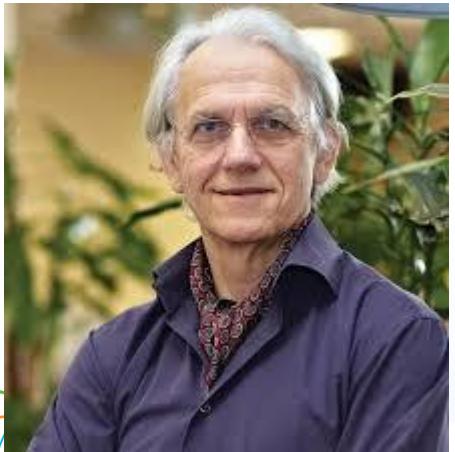
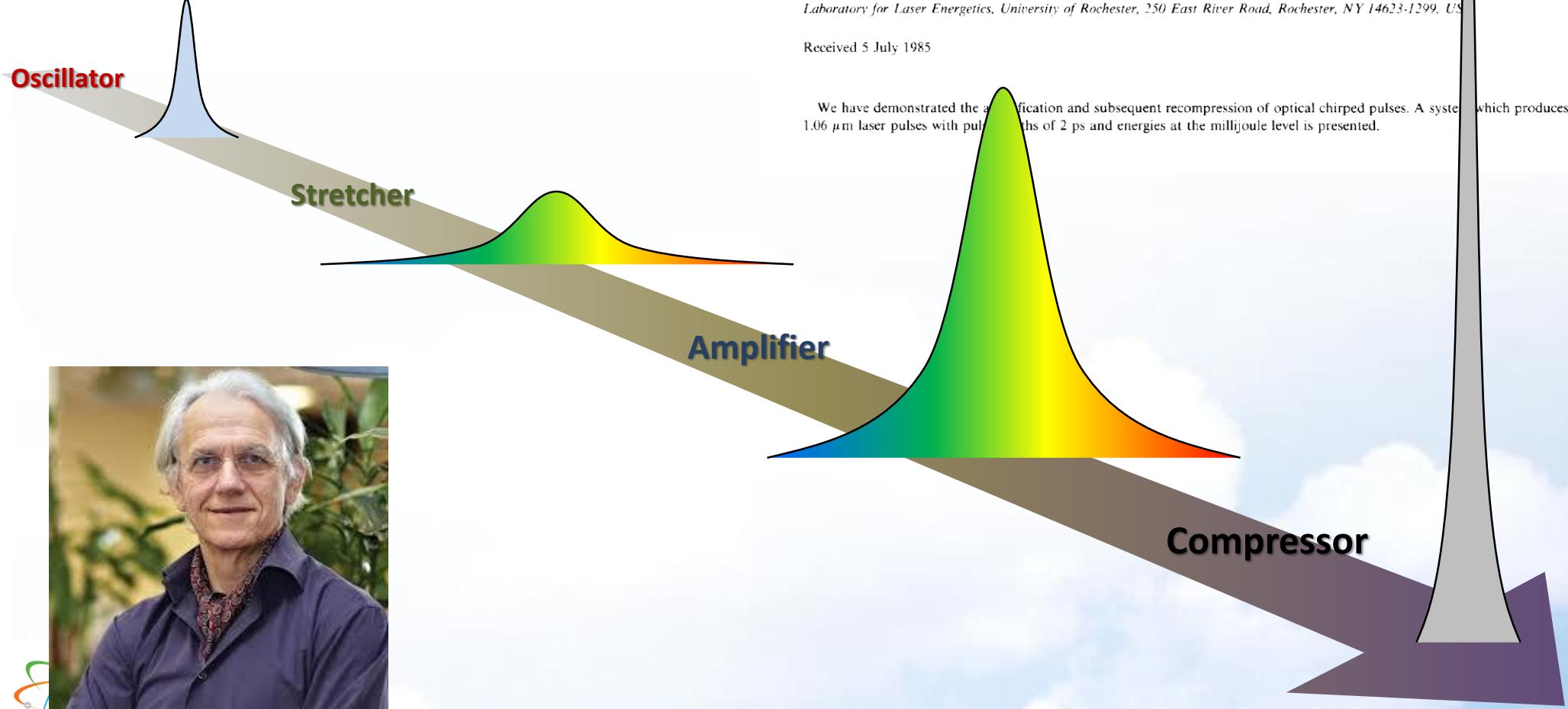
COMPRESSION OF AMPLIFIED CHIRPED OPTICAL PULSES *

Donna STRICKLAND and Gerard MOUROU

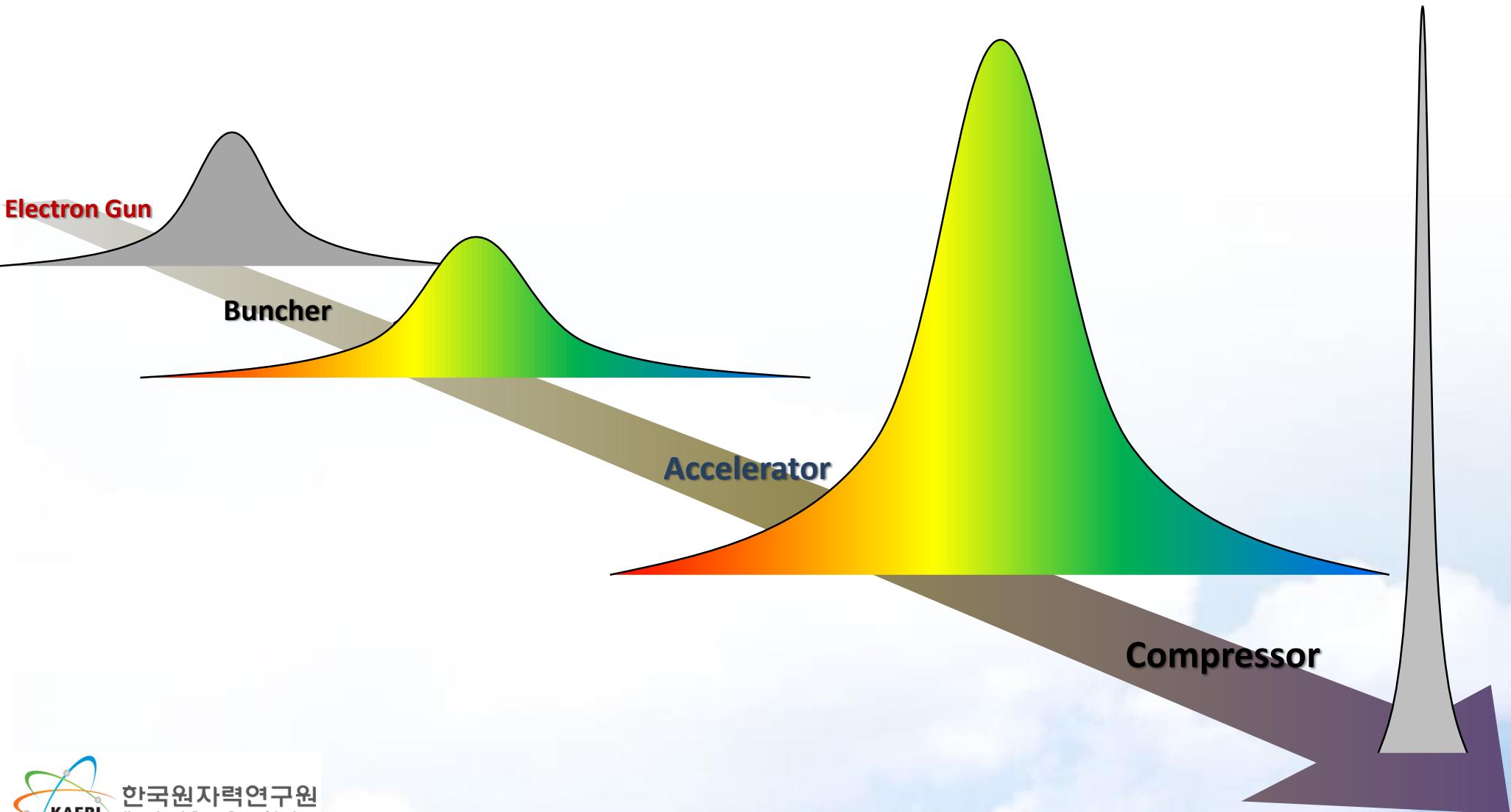
Laboratory for Laser Energetics, University of Rochester, 250 East River Road, Rochester, NY 14623-1299, US

Received 5 July 1985

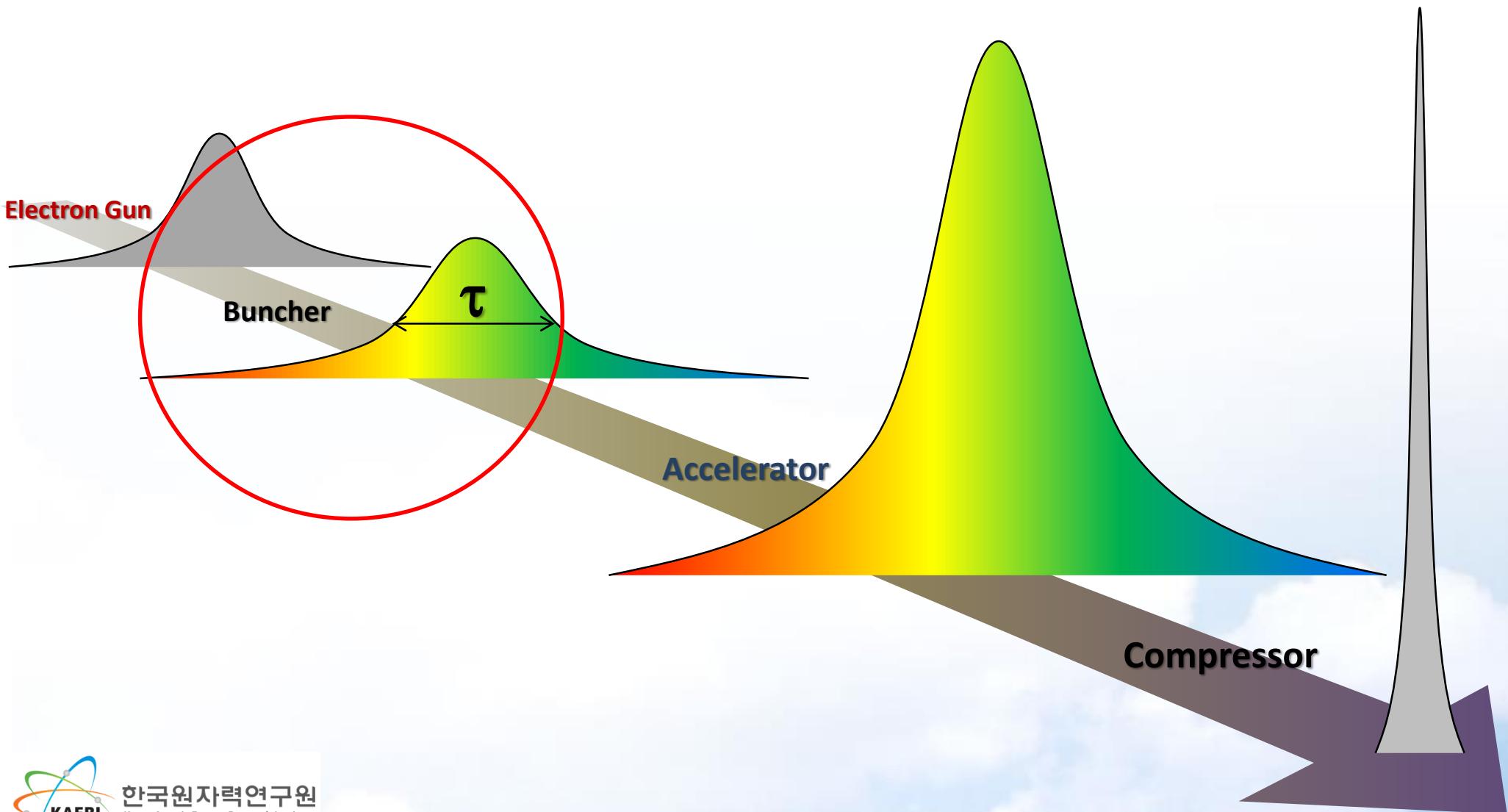
We have demonstrated the amplification and subsequent recompression of optical chirped pulses. A system which produces 1.06 μm laser pulses with pulse lengths of 2 ps and energies at the millijoule level is presented.



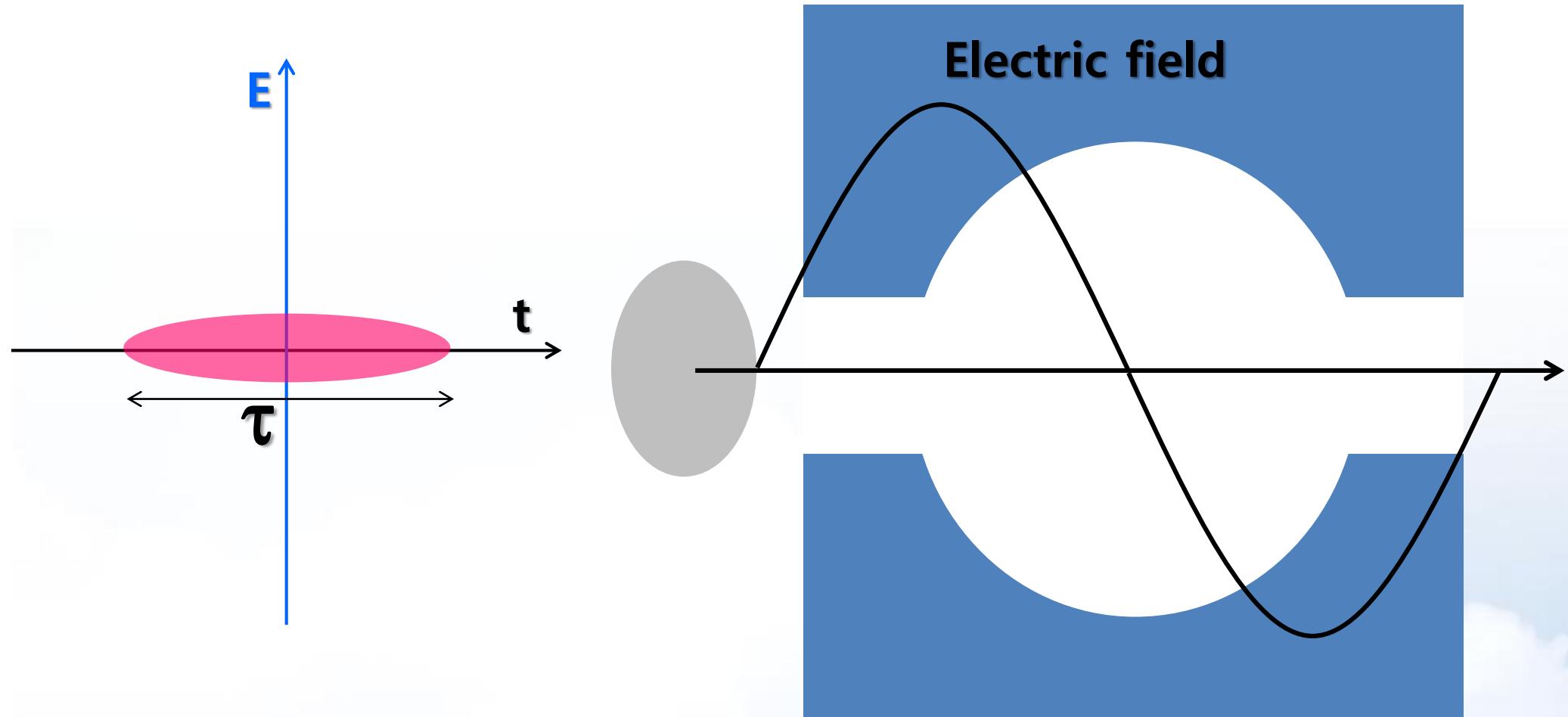
Electron Bunch Compression



Electron Bunch Compression

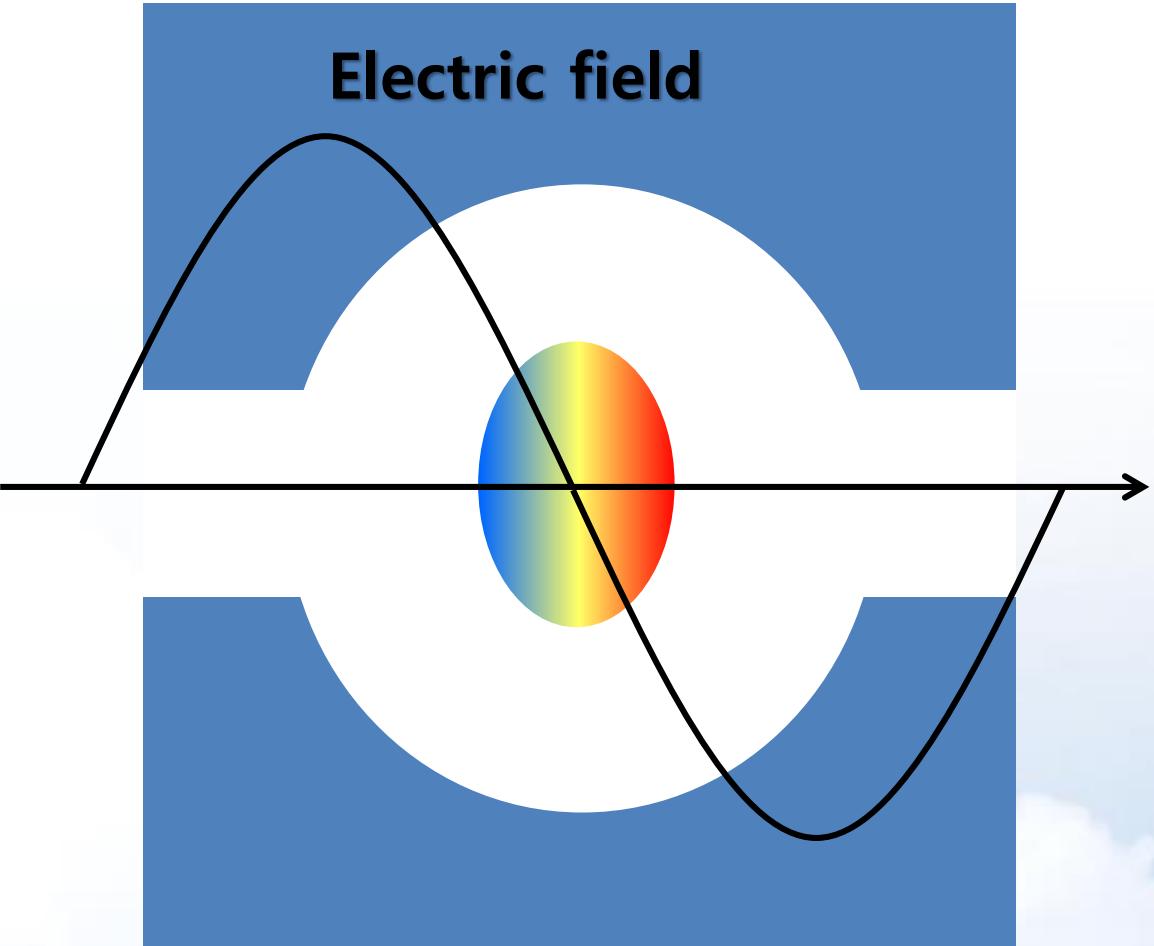
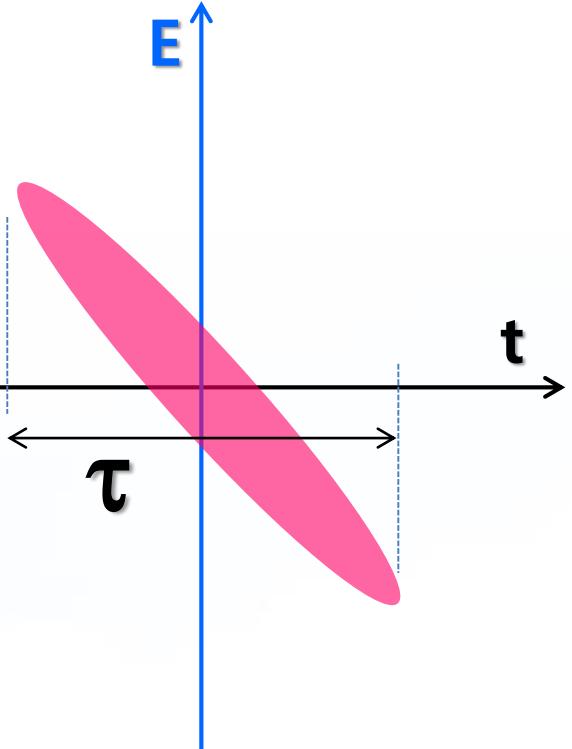


Electron Bunch Compression



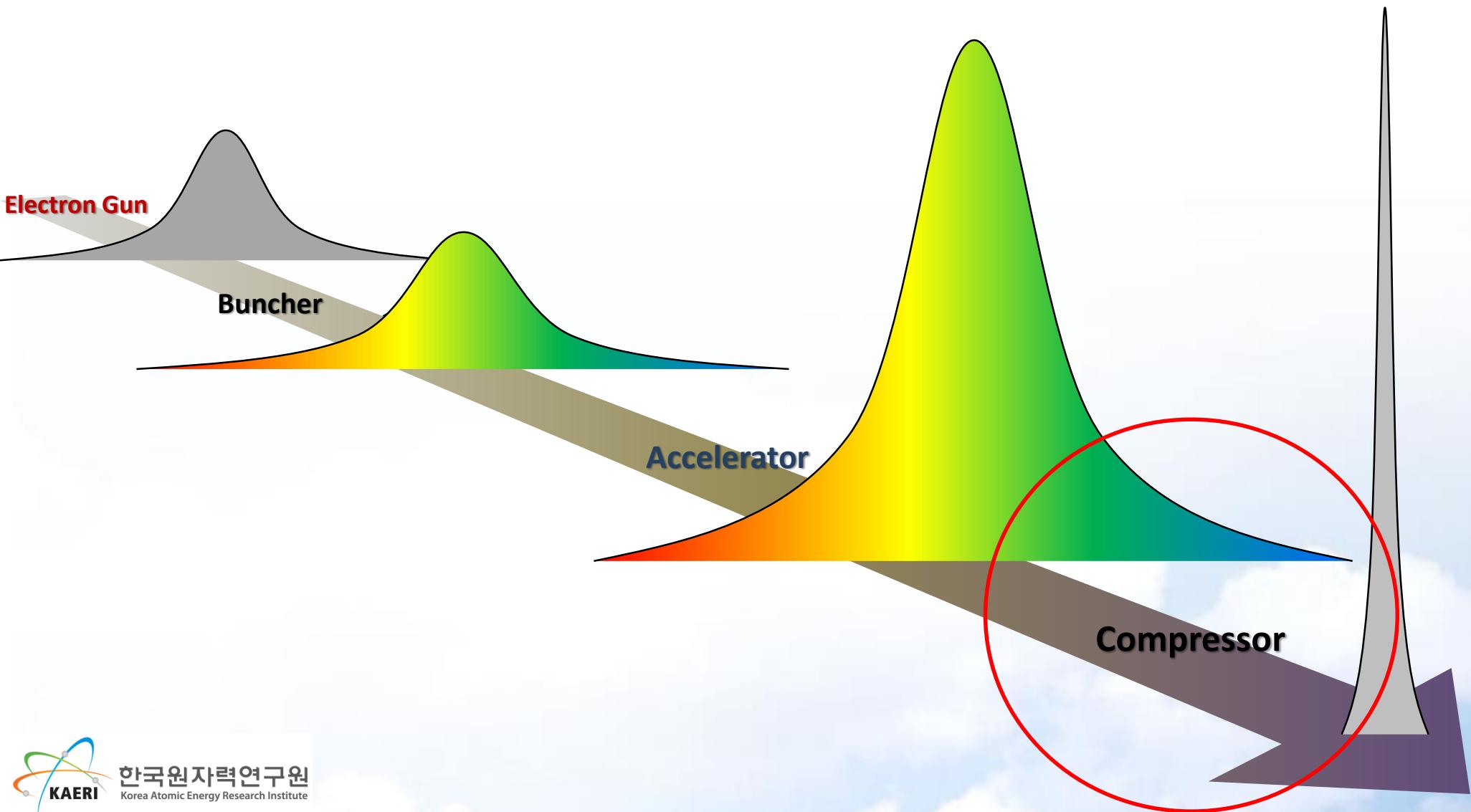
Buncher Cavity

Electron Bunch Compression

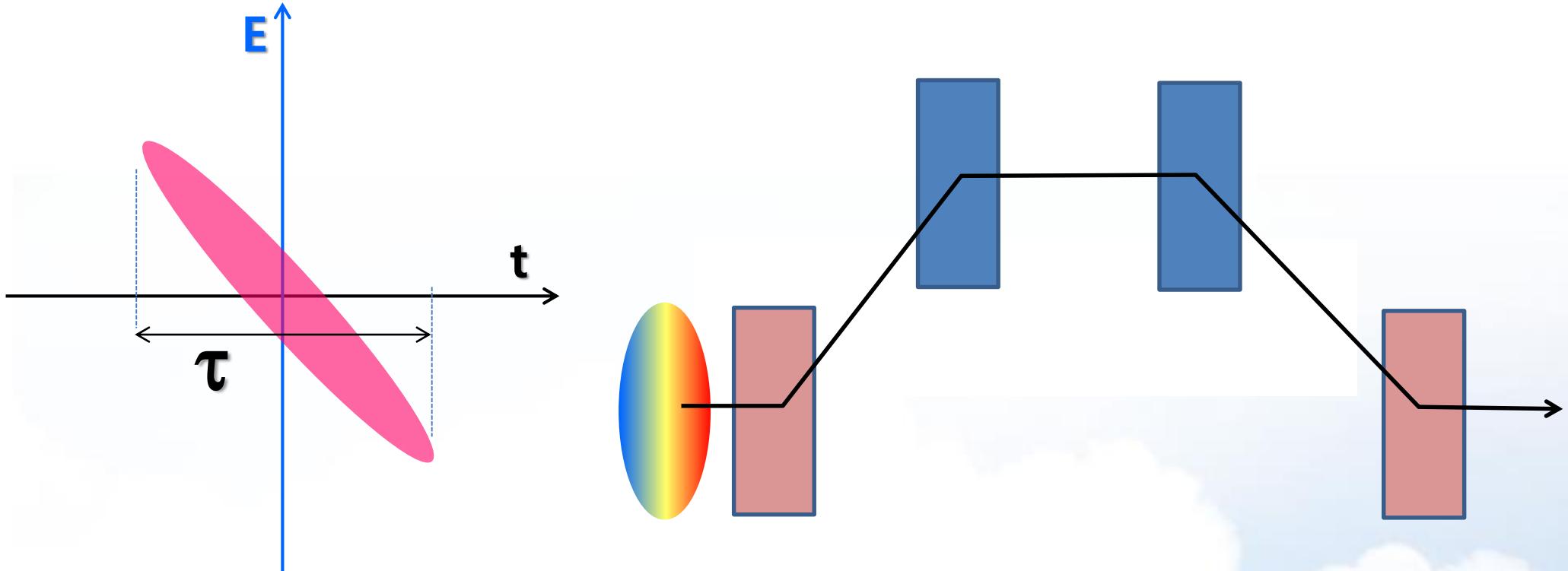


Buncher Cavity

Electron Bunch Compression

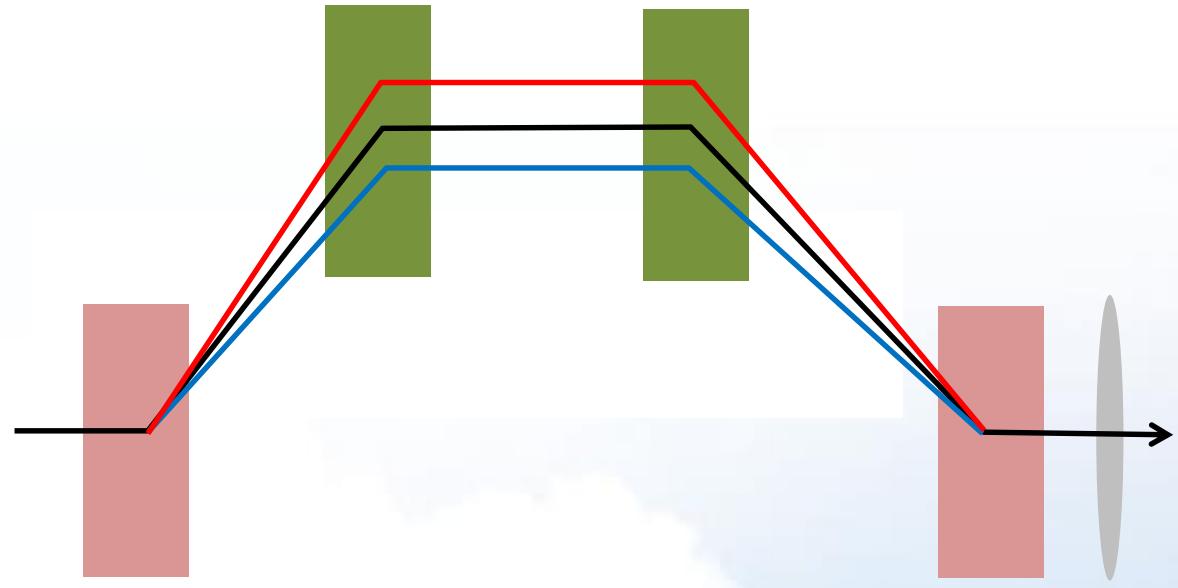
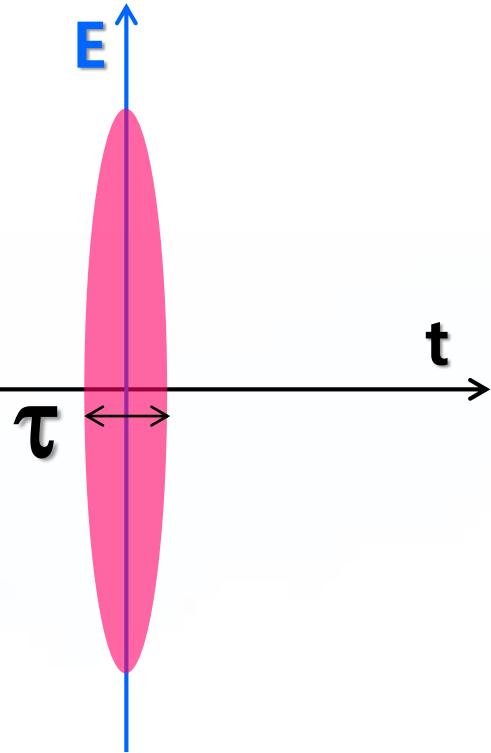


Electron Bunch Compression



Chicane Compressor

Electron Bunch Compression



Chicane Compressor



$E = mc^2$

circus

IV. Ultrafast Electron Diffraction

Tools for Exploring Dynamics of Molecules



● Nano structure ($< 1 \text{ nm}$)

- EM wave : X-ray선 ($\lambda < 1 \text{ nm}$)
- Matter wave : electron ($E > 10 \text{ keV}$)

&

● Ultrafast dynamics ($< 1 \text{ ps}$)

- EM wave : X-선 자유전자레이저 (X-ray Free Electron Laser)
- Matter wave : 초고속전자회절장치 (Ultrafast Electron Diffraction)

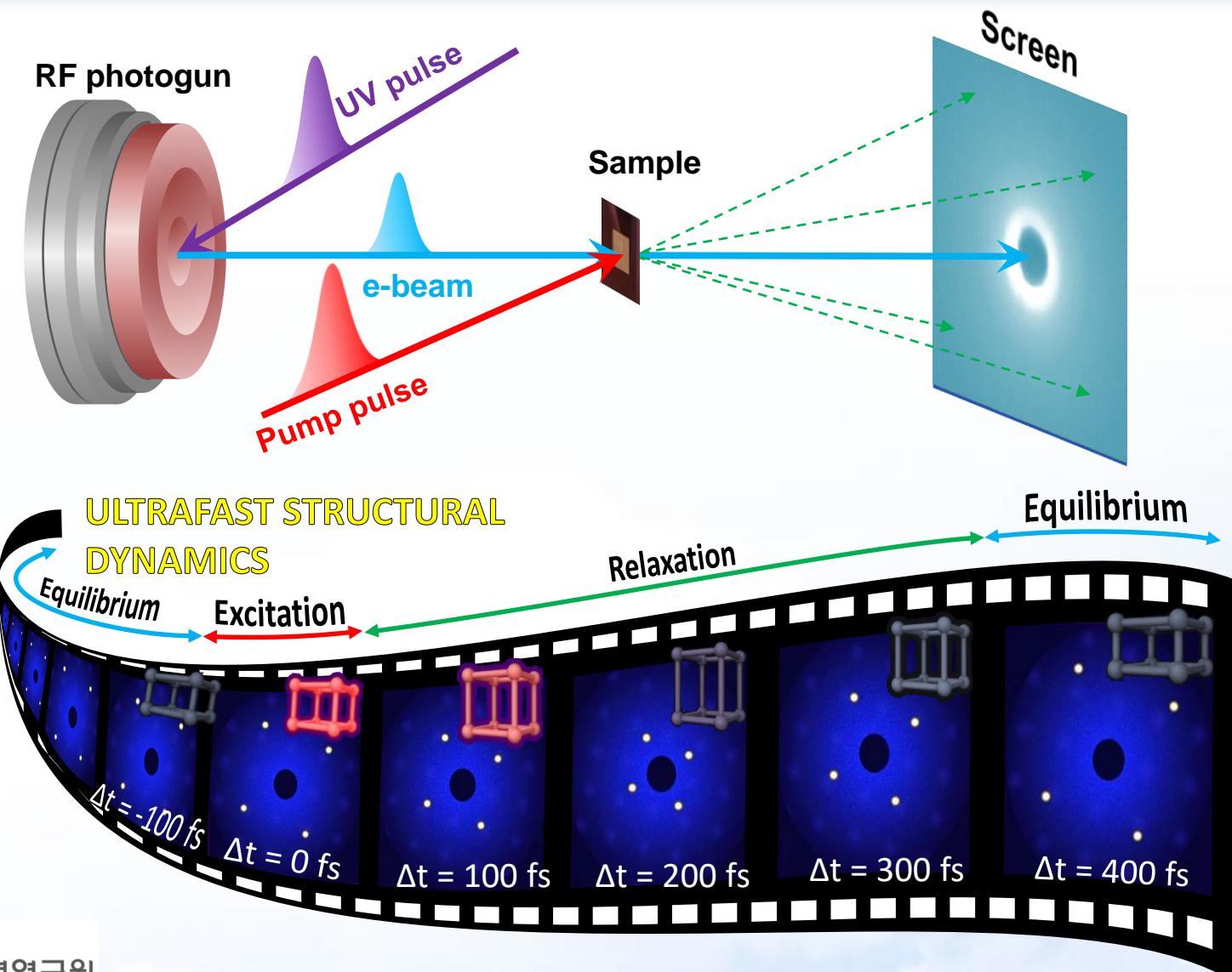
X-FEL v.s. UED

엑스선과 전자 비교

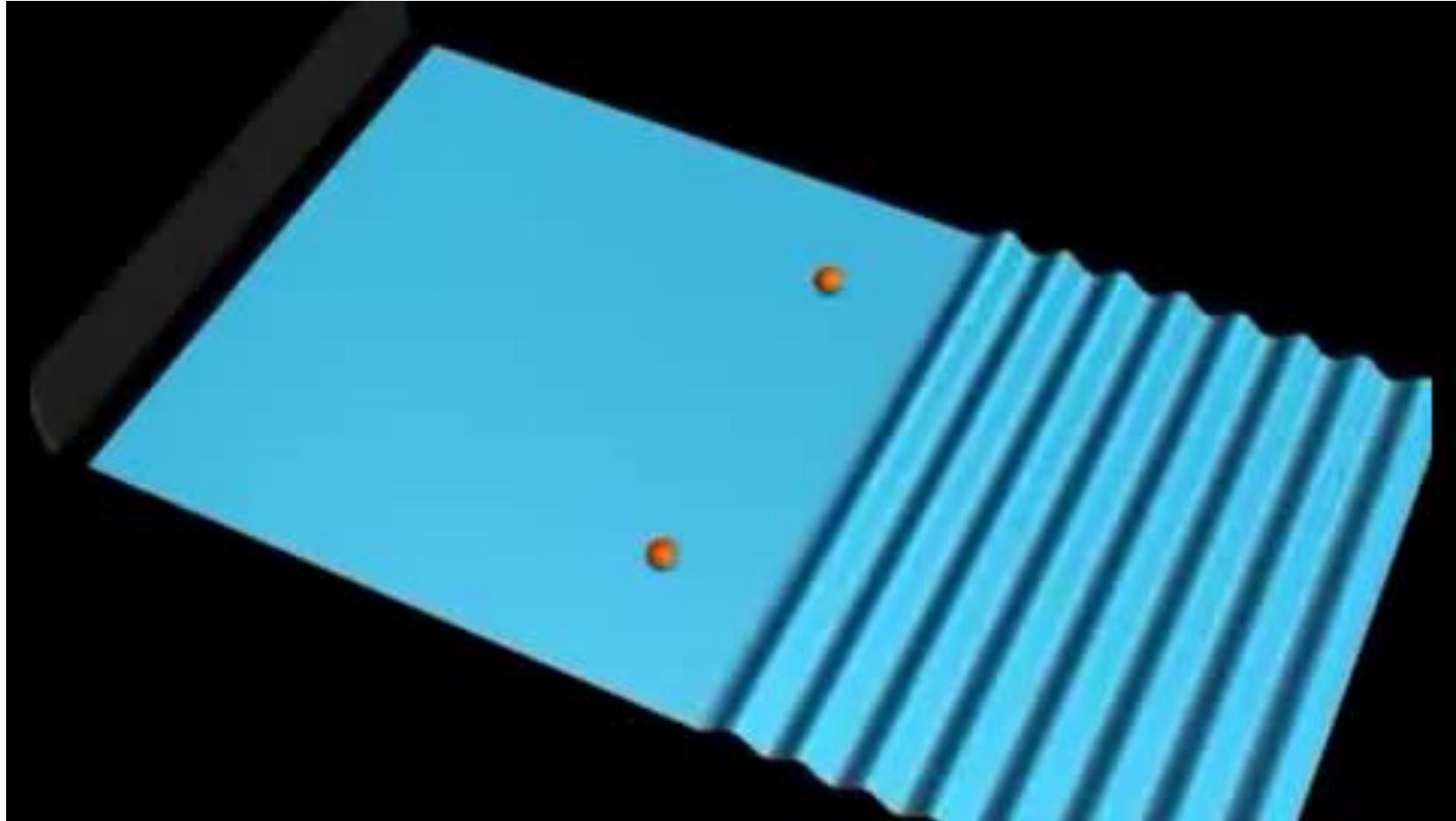


	X-FEL	UED
Source	X-ray	Electron
Wavelength	10-0.1 nm	0.1-0.001 nm
Interaction with	Electrons	Nuclei & Electrons
Scattering Power	Low	High
Penetration Depth	High	Low
Minimum Photon/Particle Numbers for Single-shot Measurement	10^{12} photons	10^6 electrons
Facility Size	Huge (~ km)	Compact (~ m)
Coherence Length	A few mm	A few nm

Ultrafast Electron Diffraction (UED)

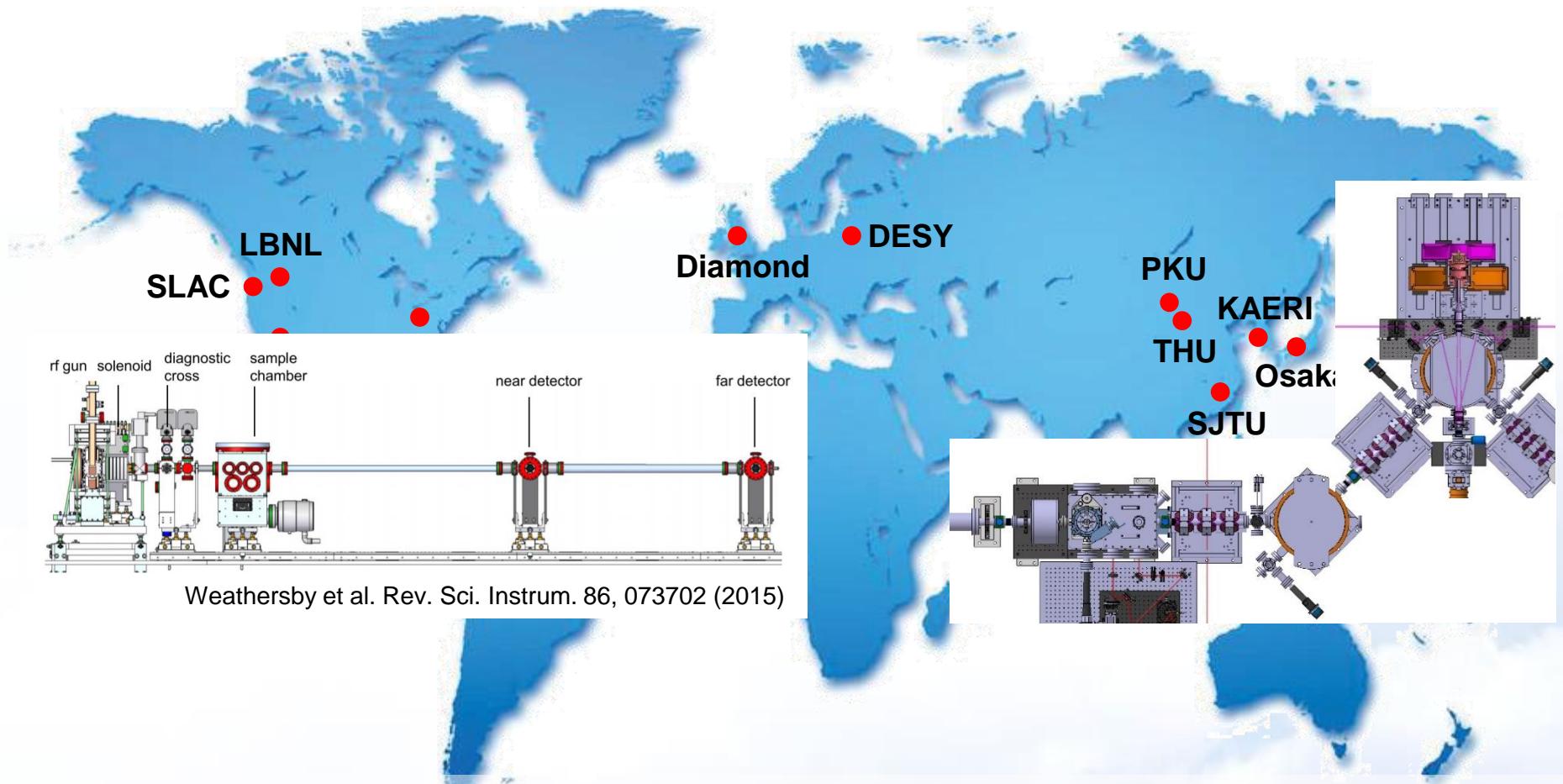


Interference by Diffraction 회절/간섭



$$\Delta l \approx \lambda L/d$$

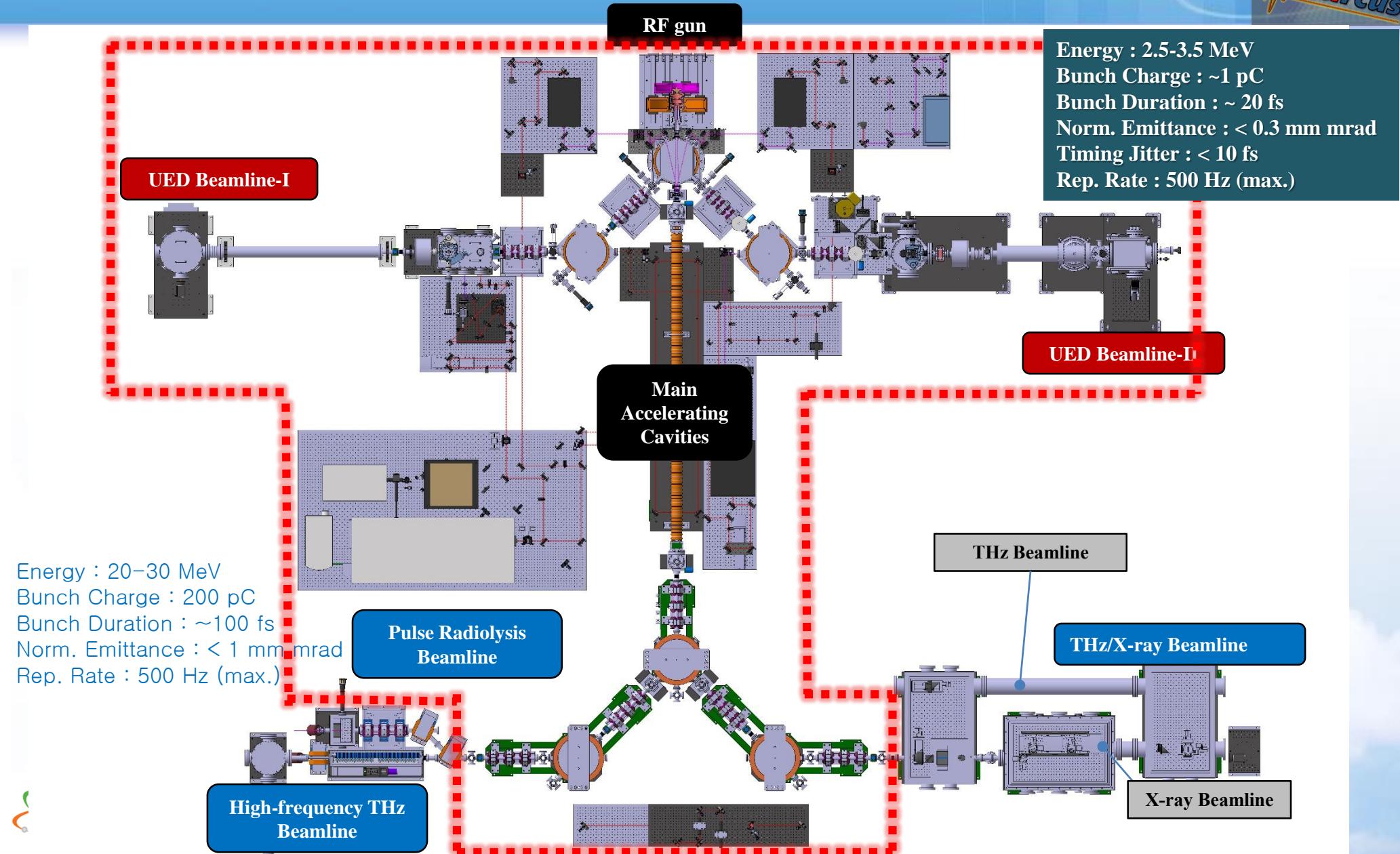
World-wide efforts for MeV UED



Instrumental temporal resolution of UEDs is still limited >100 fs.

Facility Bird-eye View

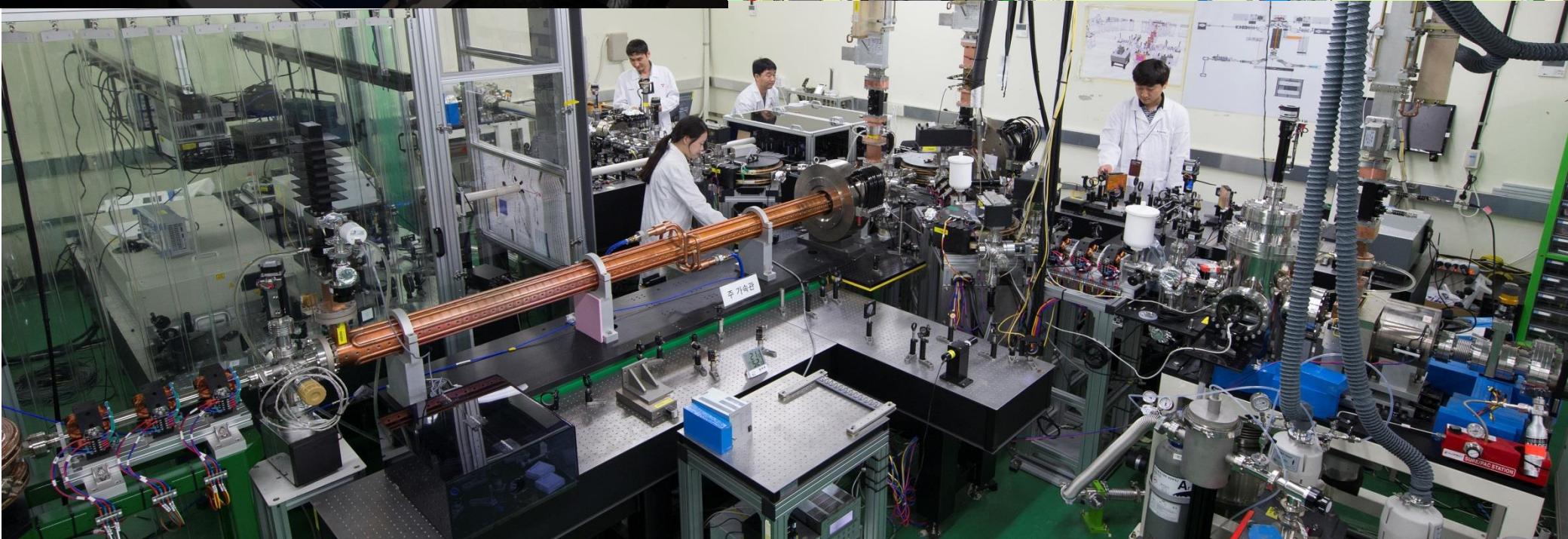
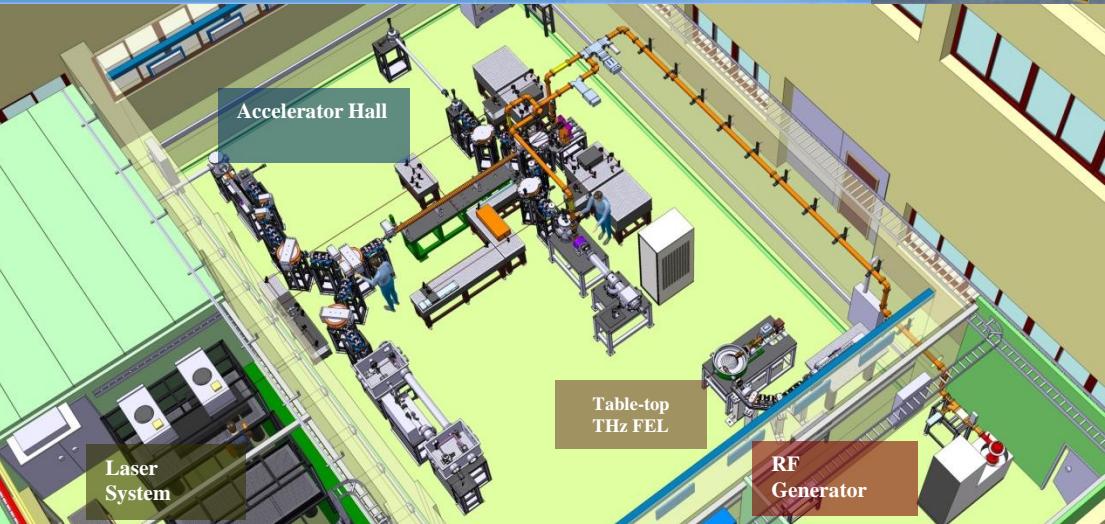
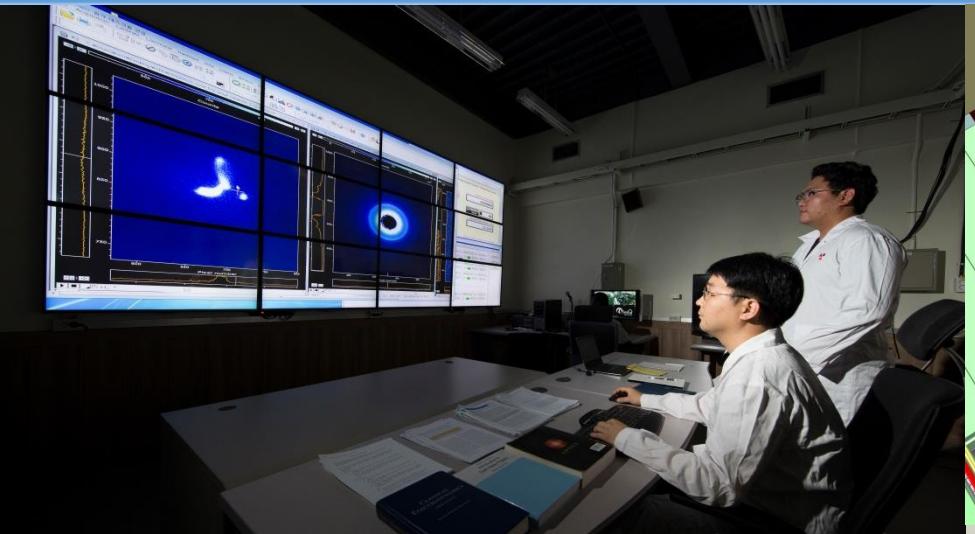
시설 개관



Facility Appearance

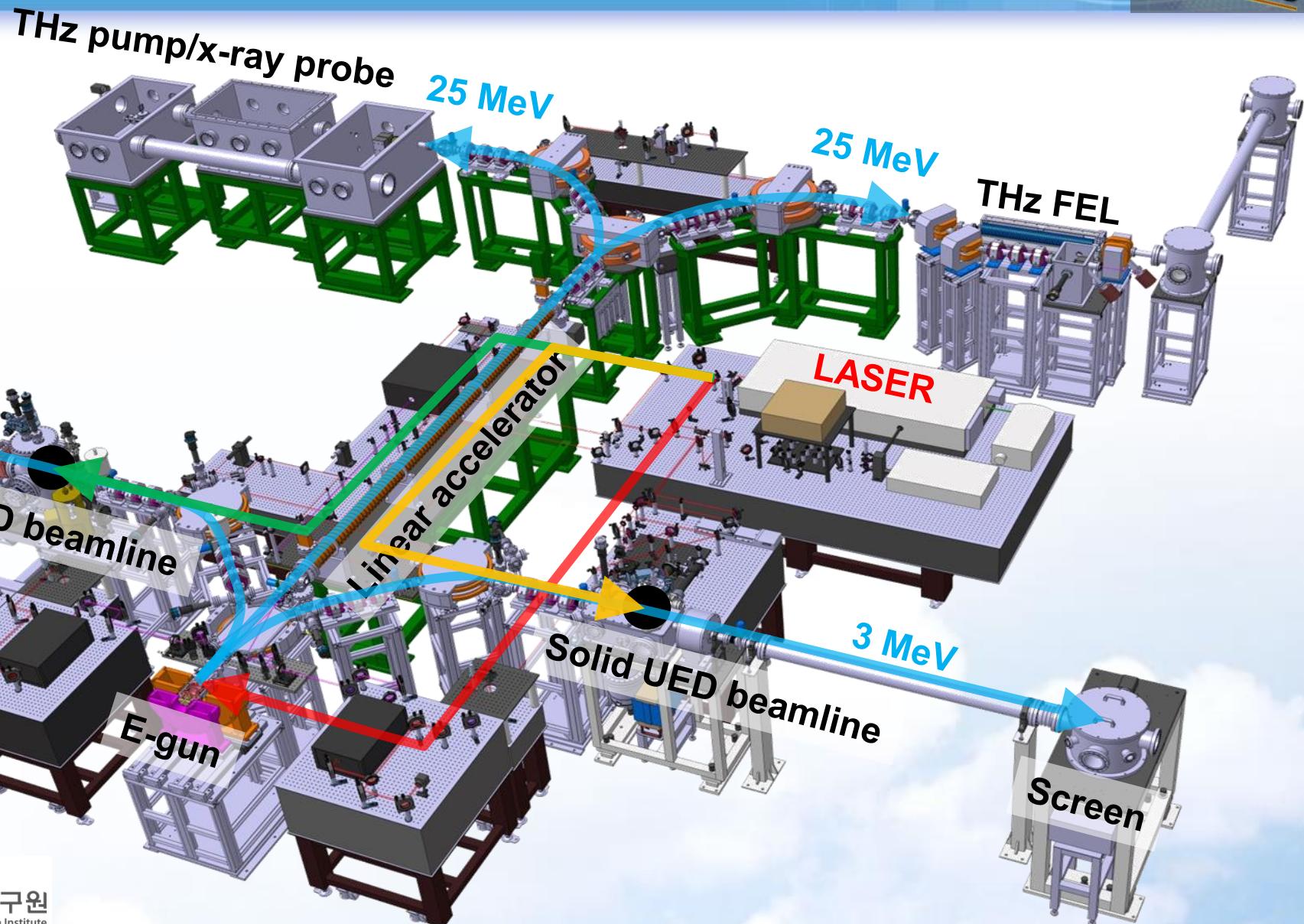
시설 개관

$E=mc^2$



Facility Overview

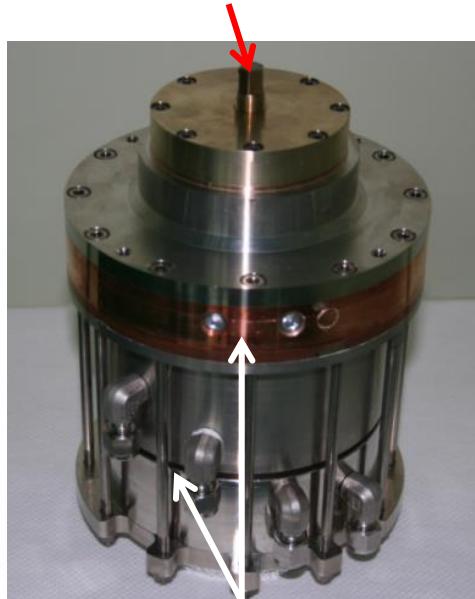
시설 개관



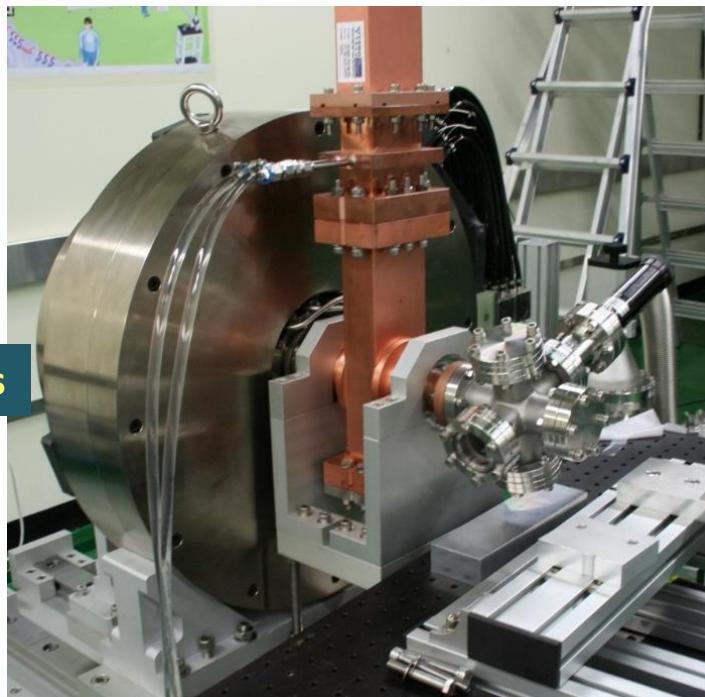


Coaxial-type Indium-sealed RF Photogun

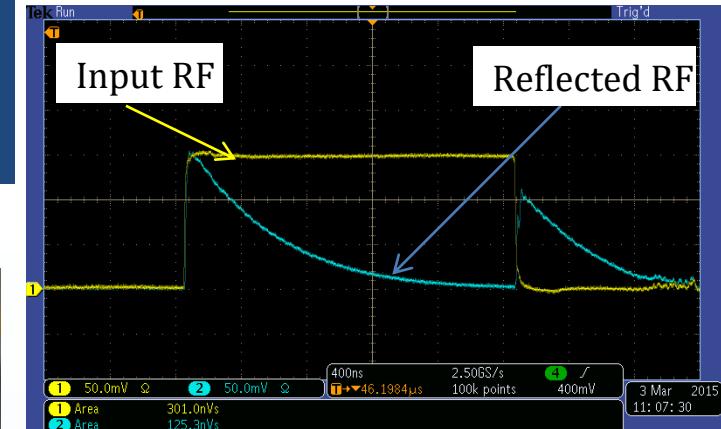
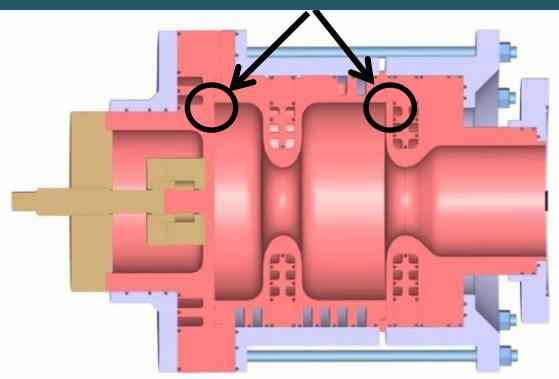
Frequency Tuning Mechanics



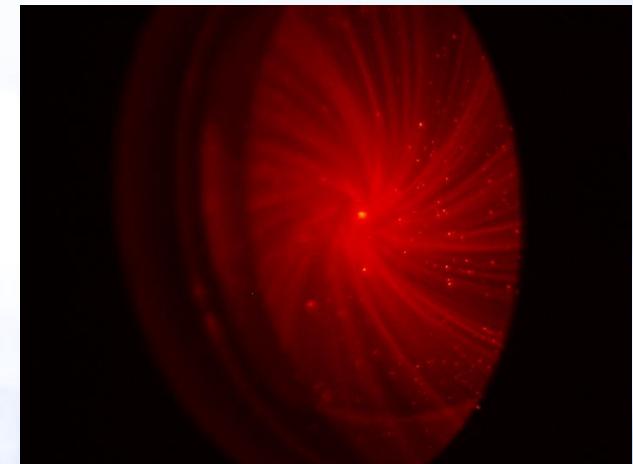
Frequency : 2.856 GHz
Repetition Rate : 1-500 Hz
Axial Symmetry with a Coaxial Coupler



Vacuum sealed with Indium wires



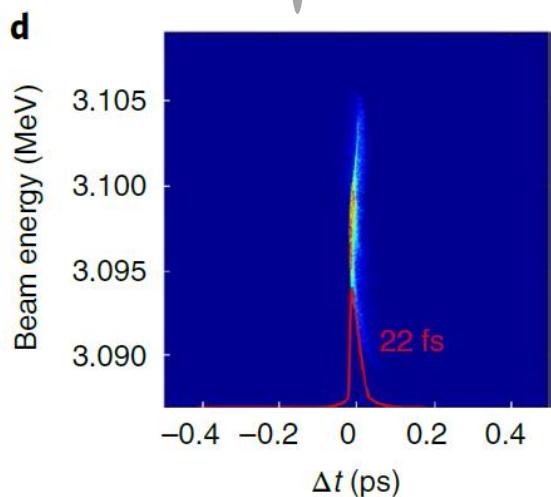
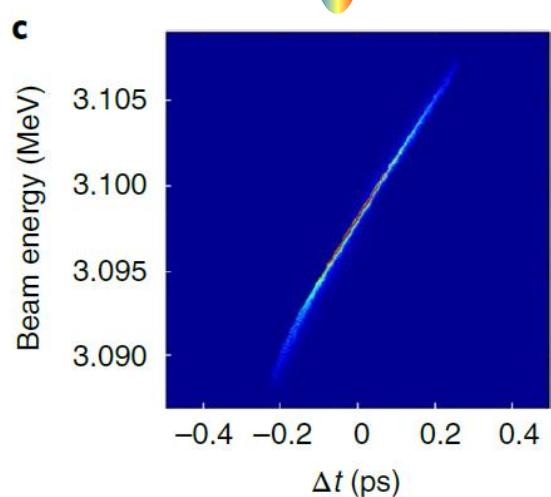
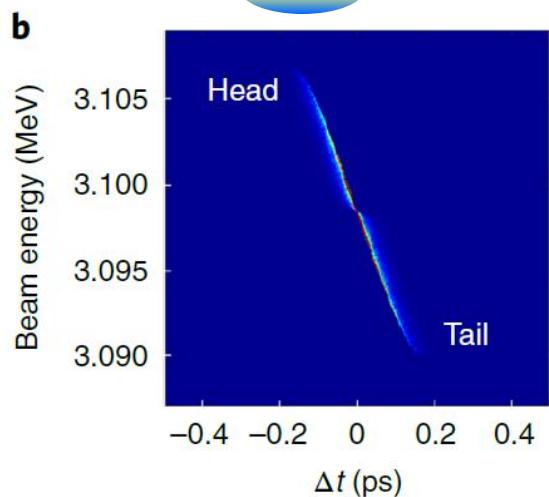
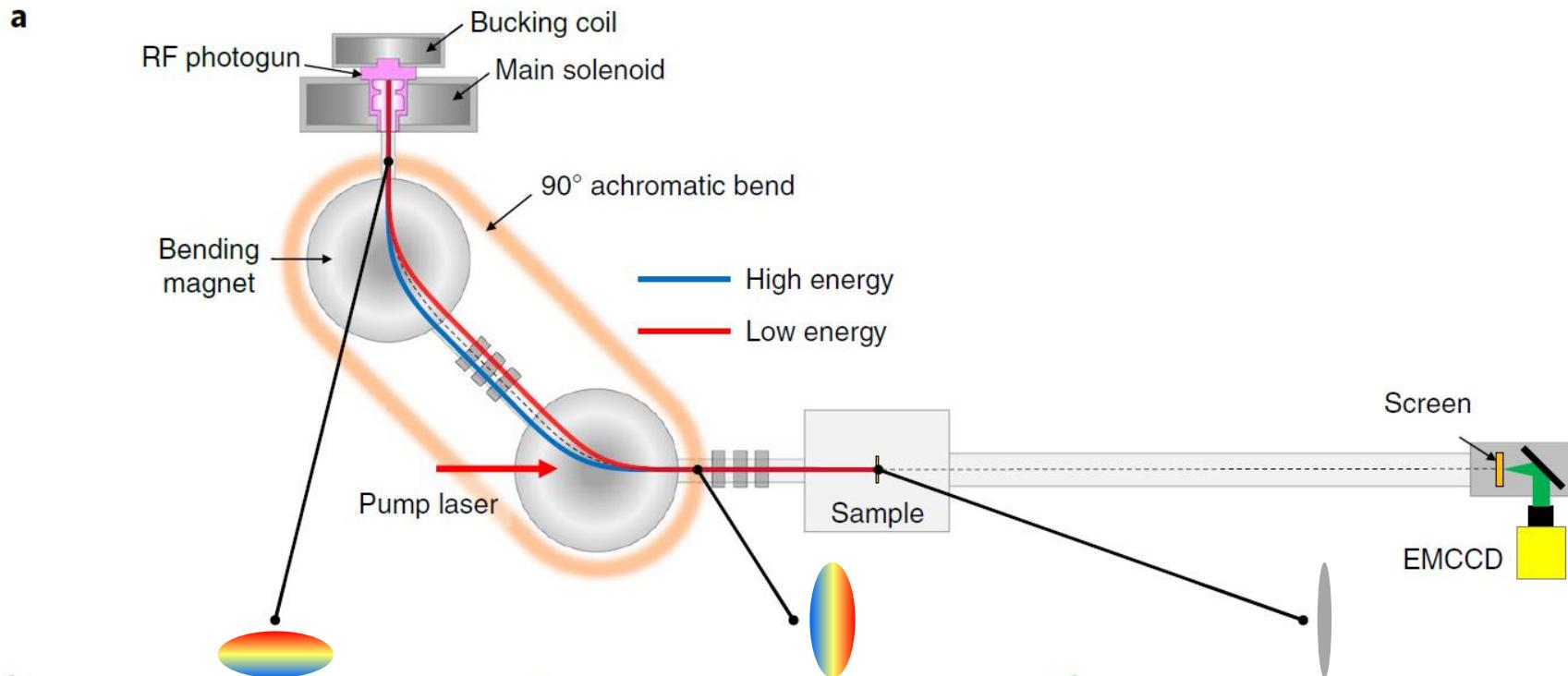
High power test



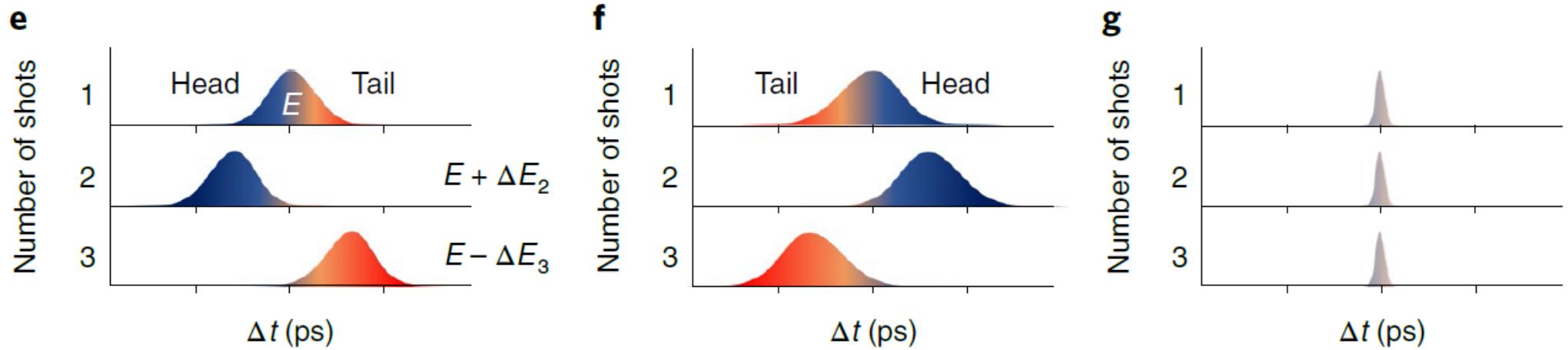
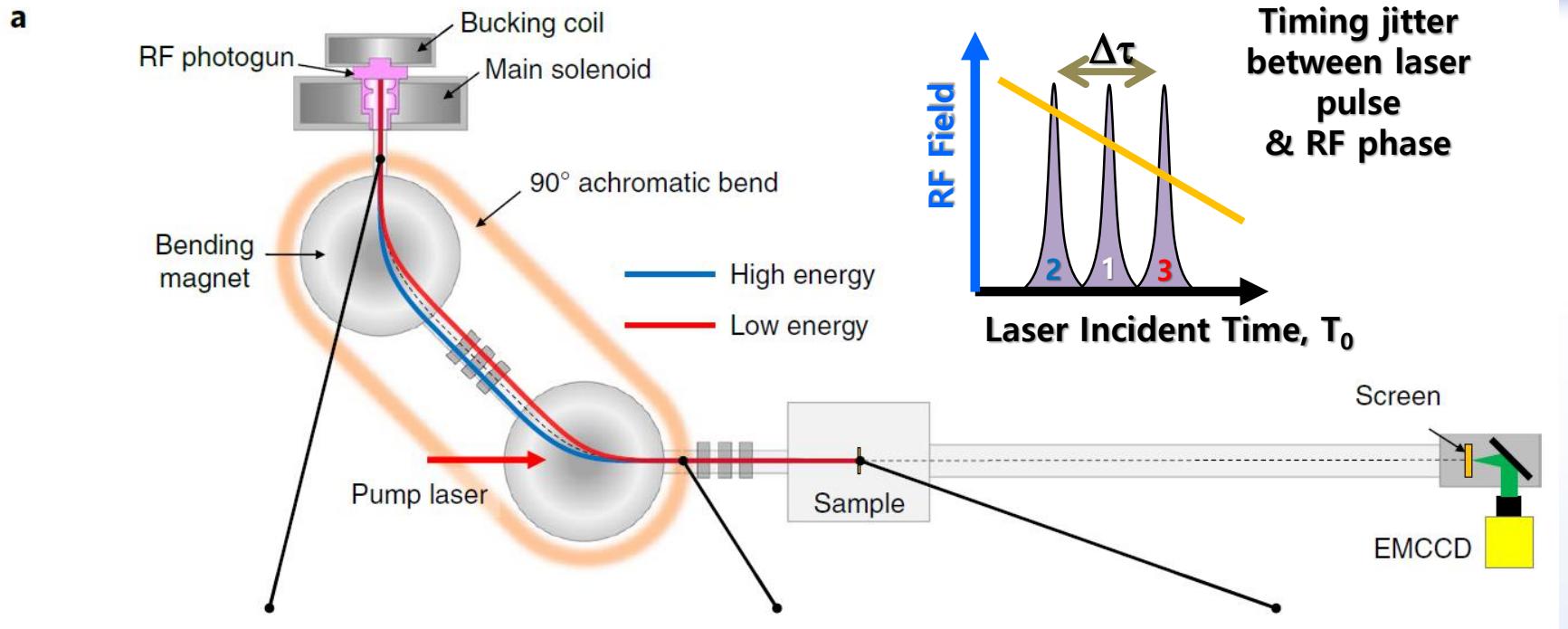
Dark current



KAERI UED: Bunch Compression



KAERI UED: Jitter Compression

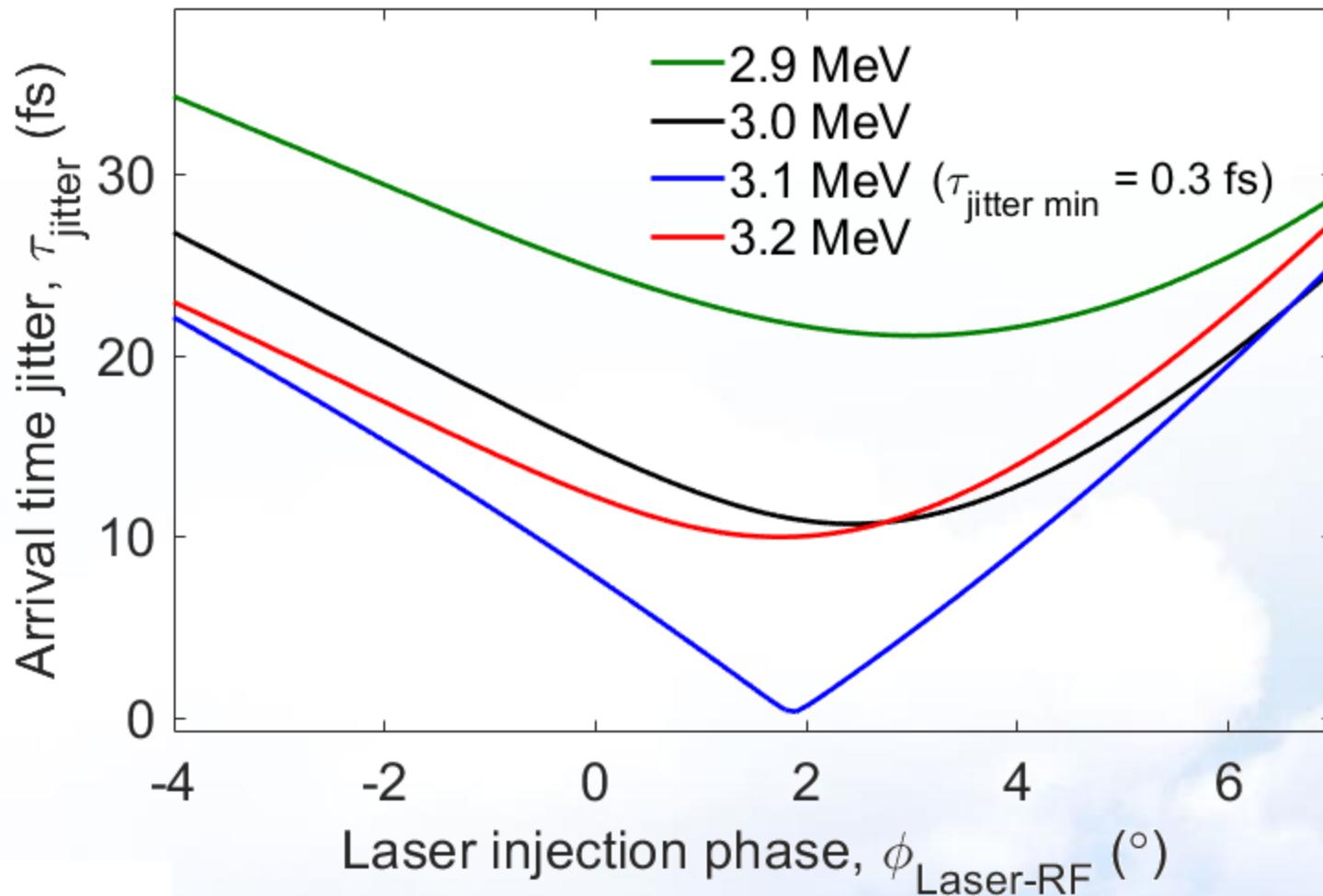




Arrival time jitter due to RF amplitude & phase

$$\Delta E/E = 0.07\%$$

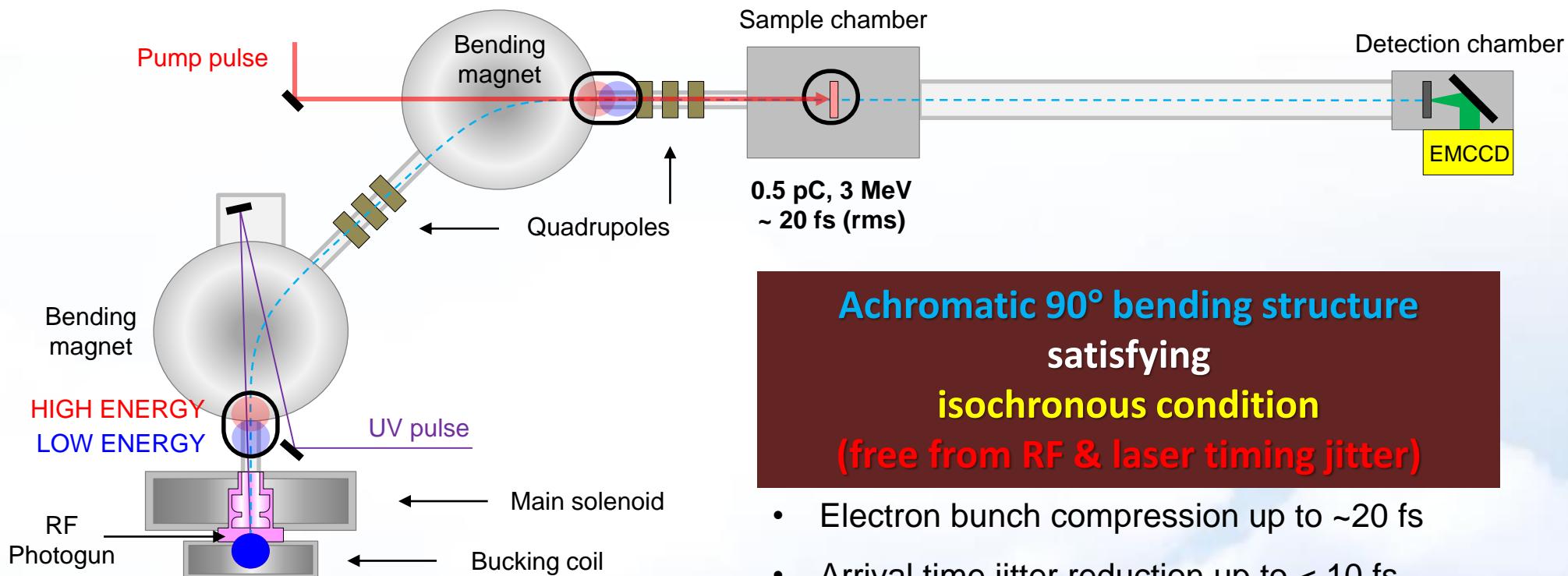
$$\Delta \phi_{\text{Laser-RF}} = 40 \text{ fs}$$





Toward the fastest Electron Camera

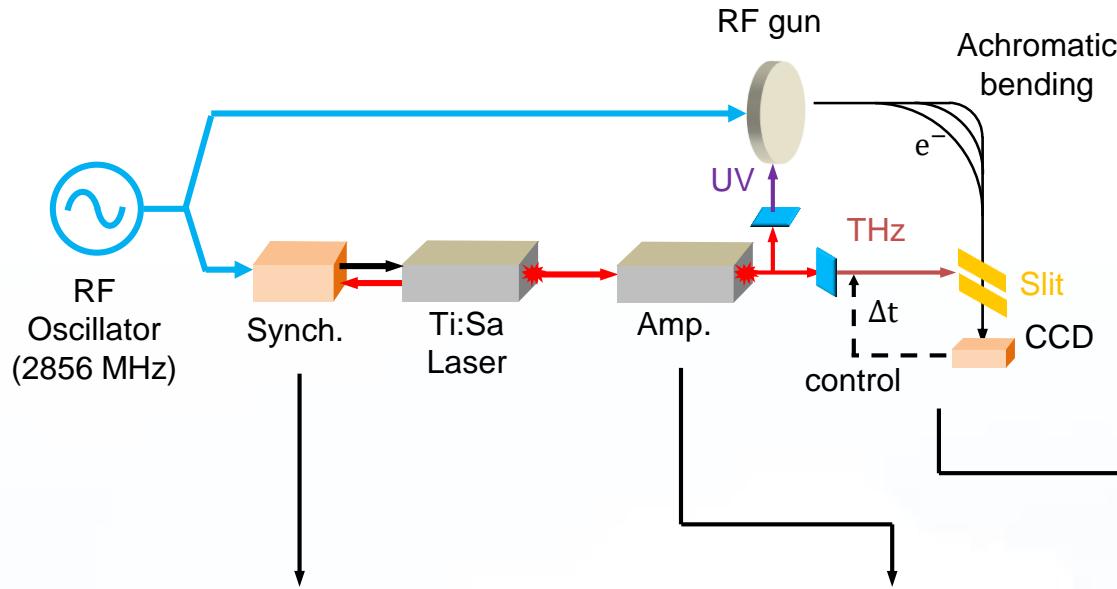
$$\tau_{Inst.\ res.} = \sqrt{\tau_{pump\ laser}^2 + \tau_{e-bunch}^2 + \tau_{jitter}^2 + \tau_{velocity-mismatching}^2}$$



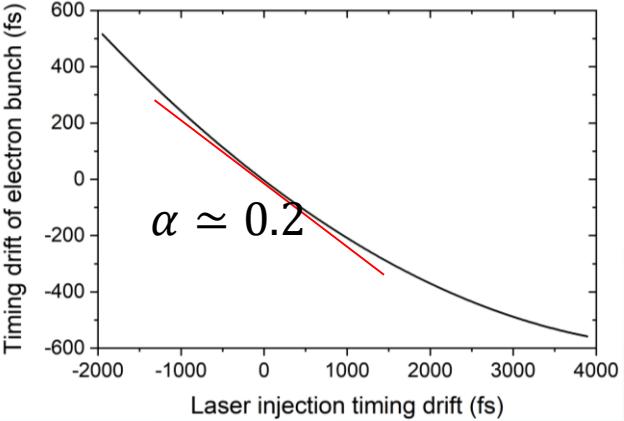
**Achromatic 90° bending structure
satisfying
isochronous condition
(free from RF & laser timing jitter)**

- Electron bunch compression up to ~20 fs
- Arrival time jitter reduction up to < 10 fs
- Velocity mismatching-free scheme
- Multiple beamlines

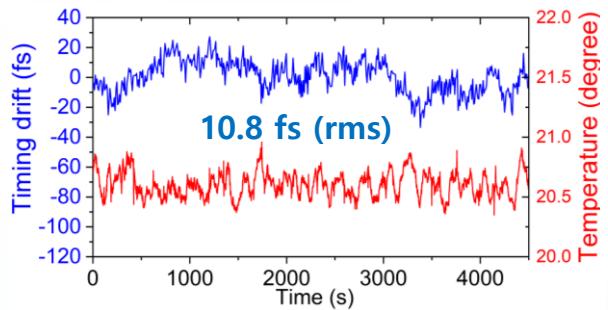
Timing Stabilization between Laser & RF



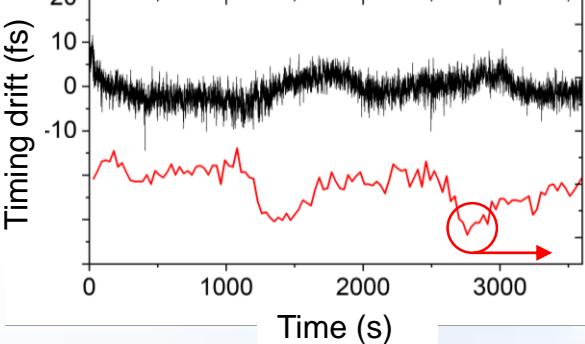
Simulated drift suppression ratio



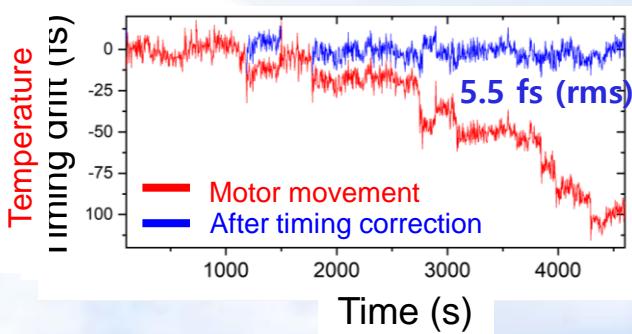
Drift of the RF-to-laser synch.



Drift of the optical amplifier



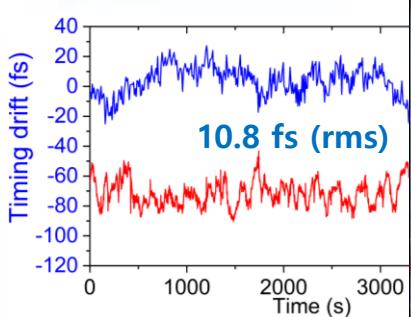
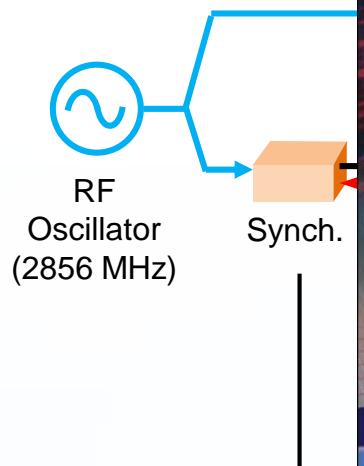
Timing drift of electron beam



Timing St

Vol. 15 | February 2021

www.lpr-journal.org

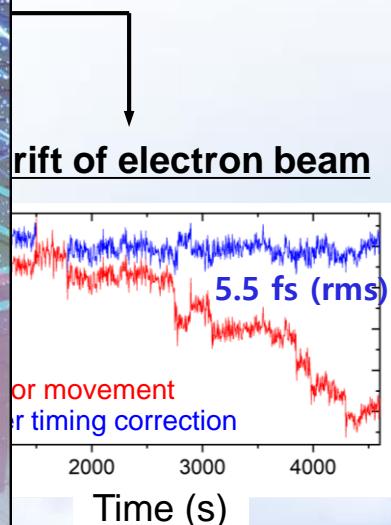
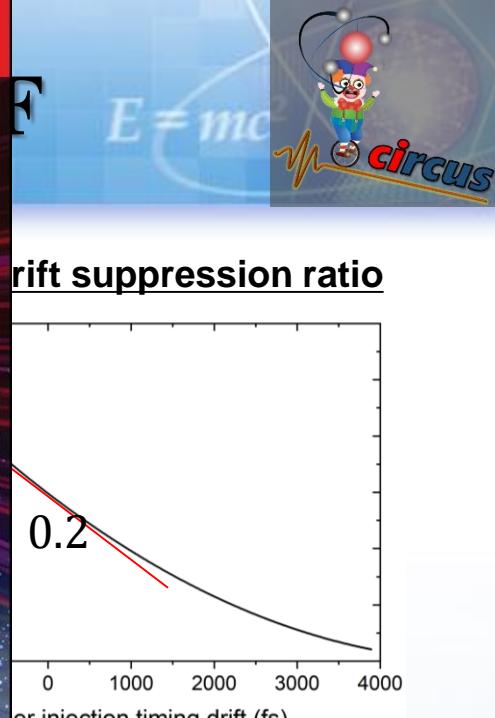


LASER & PHOTONICS REVIEWS

Sub-10-fs Timing for Ultrafast Electron Diffraction with THz-Driven Streak Camera

Junho Shin, Hyun Woo Kim, In Hyung Baek, Sunjeong Park, Hyeon Sang Bark, Key Young Oang, Kyu-Ha Jang, Kitae Lee, Fabian Rotermund, Young Uk Jeong, and Jungwon Kim

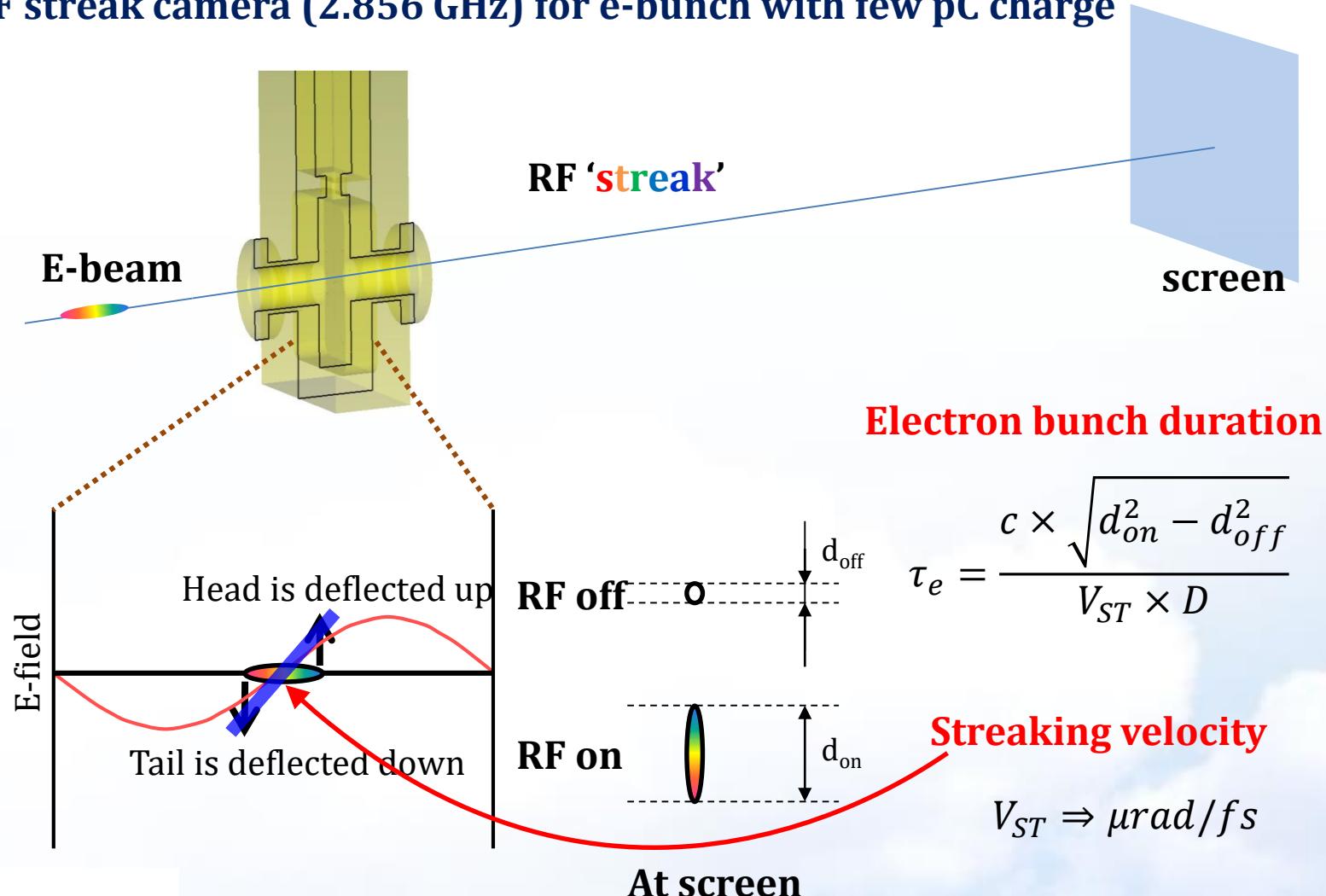
WILEY-VCH





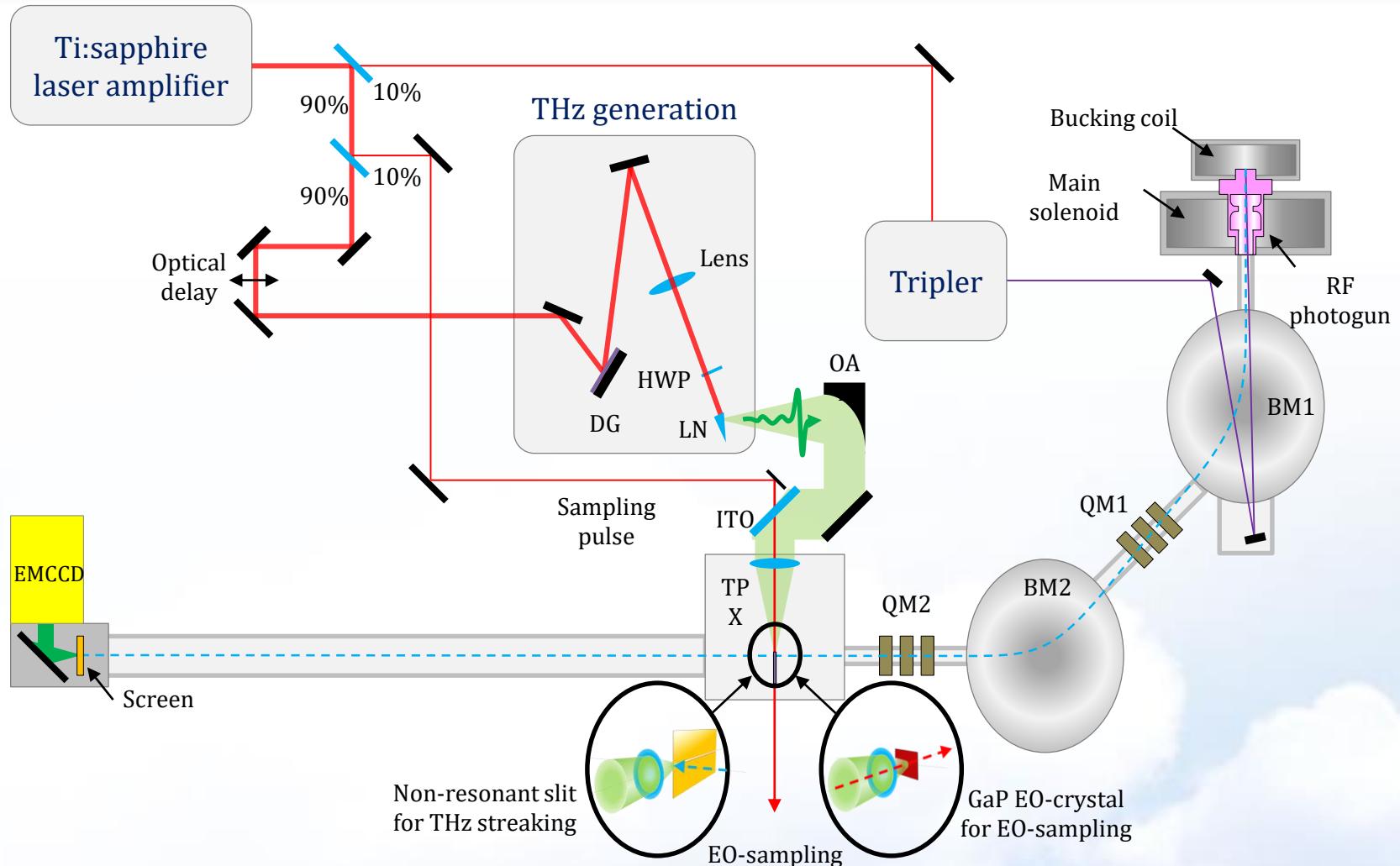
Conventional Characterization of Electron Bunch

RF streak camera (2.856 GHz) for e-bunch with few pC charge

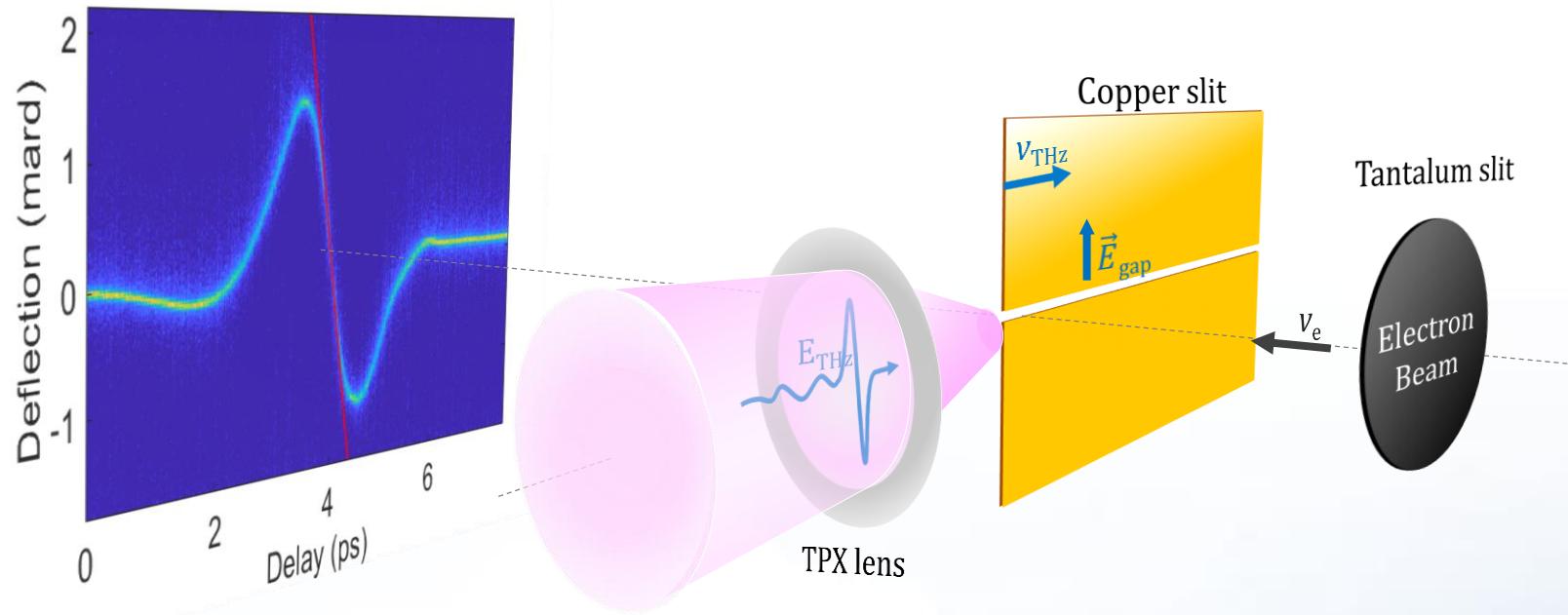




Setup of Terahertz (THz) Streak Camera



THz Streak Camera with Non-resonant Slit

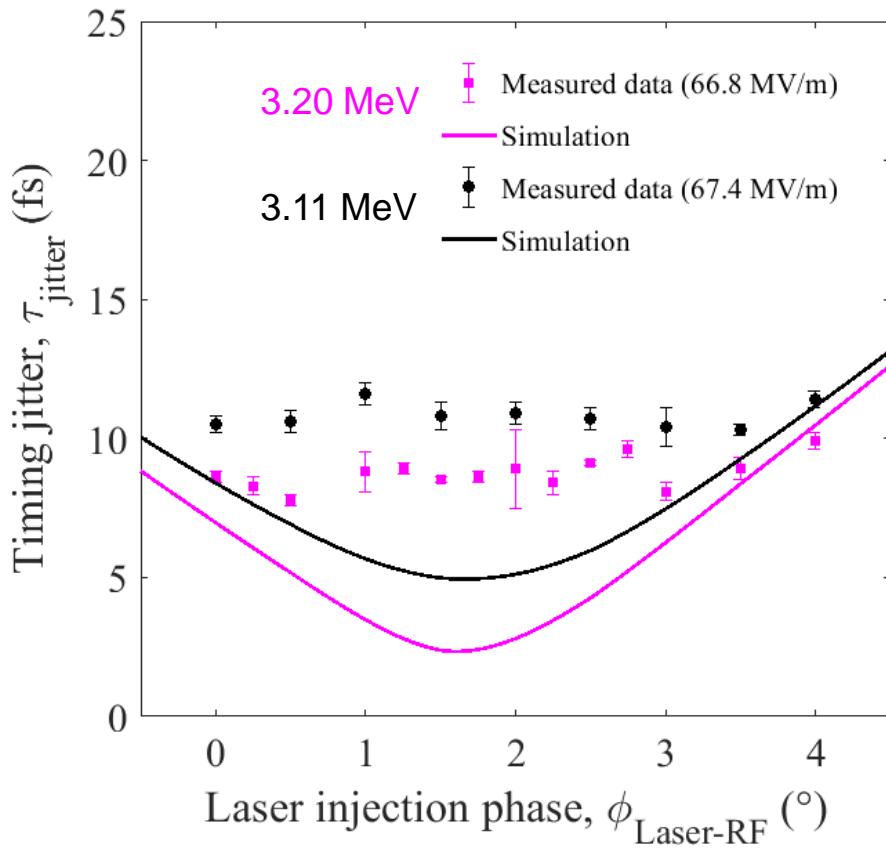
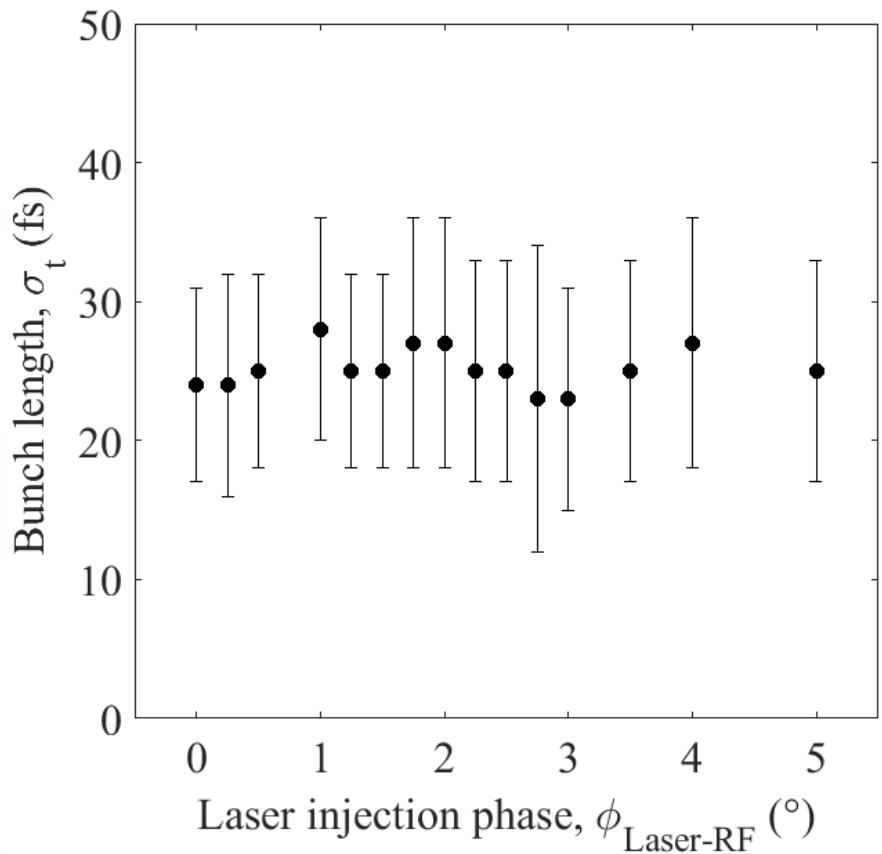


Streaking velocity = 4.8 μrad/fs

30 μm

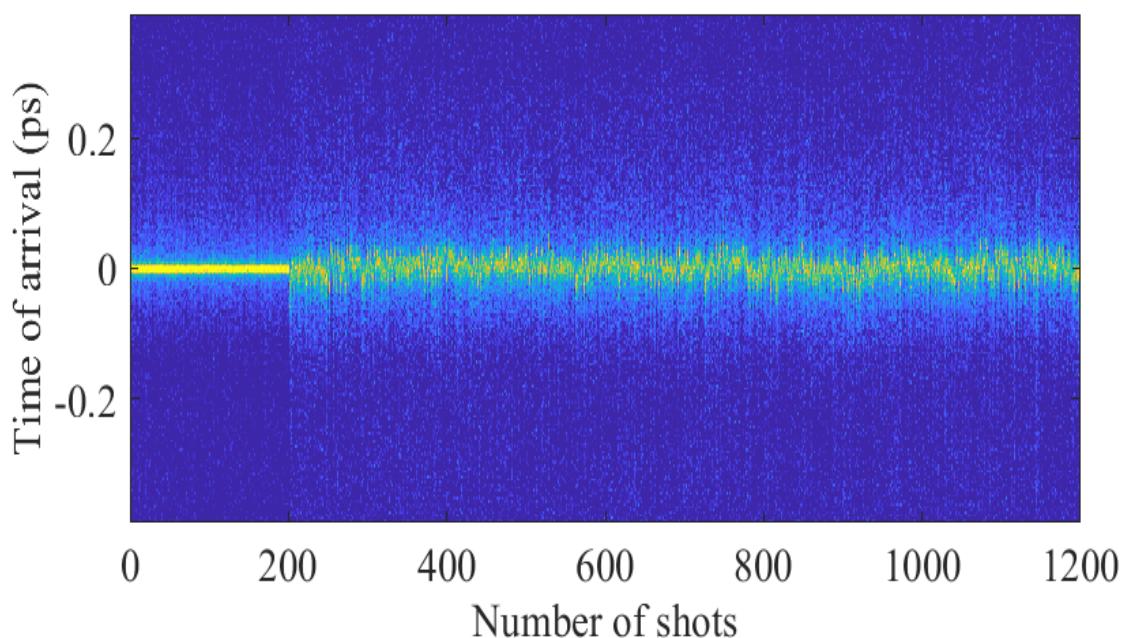
Streaking resolution = 3.8 fs

Experimental Results on THz Streaking





Experimental Results on THz Streaking



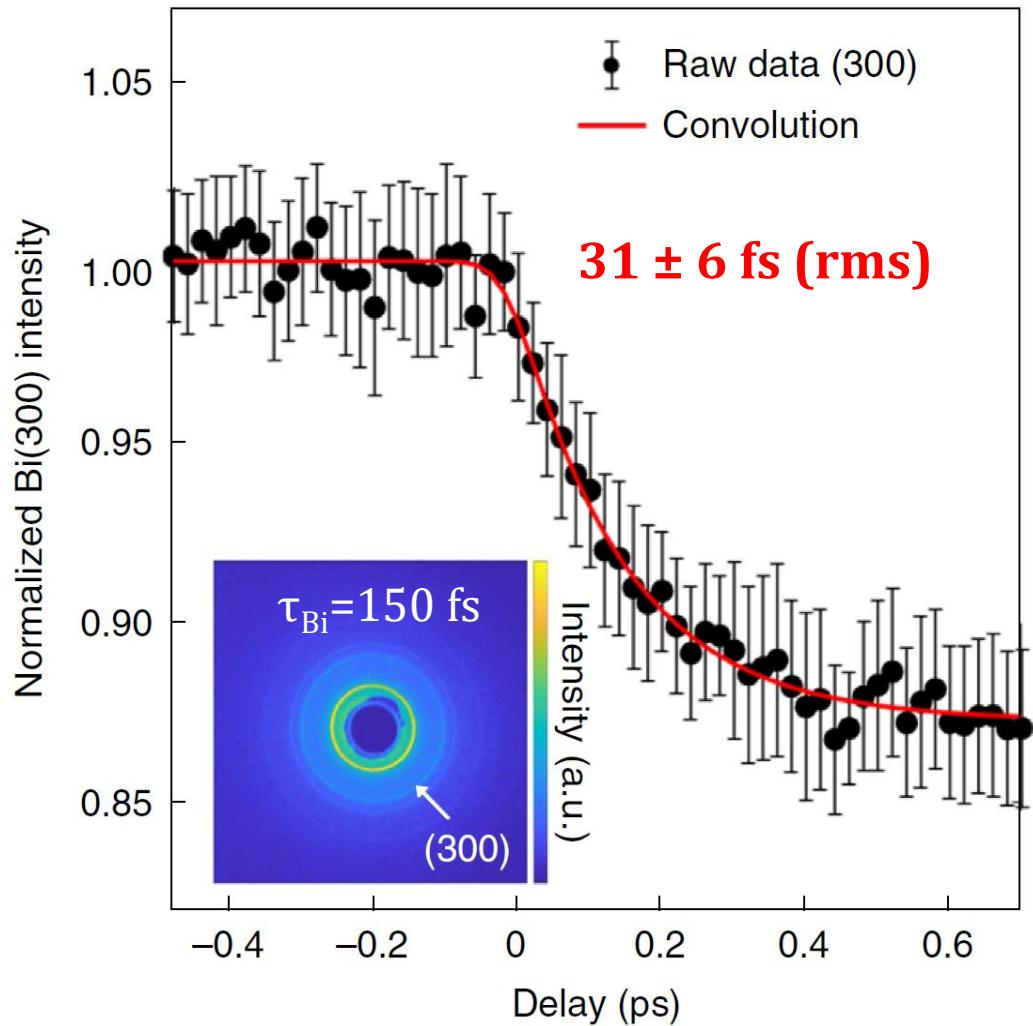
Bunch duration = **25 ± 8 fs (rms)** @ 0.57 pC, 3.11 MeV

Arrival time jitter b/w THz pulse & electron bunch = **8 fs (rms)**

$$\tau_{IRF} = \sqrt{\tau_{pump\ laser}^2 + \tau_{electron}^2 + \tau_{jitter}^2 + \tau_{drift}^2}$$

↓ ↓ ↓ ↓ ↓
 32 fs **19 fs** **25 fs** **8 fs** **0**

Dynamics of Polycrystalline Bismuth Film



$$\tau_{IRF} = \sqrt{\tau_{\text{pump laser}}^2 + \tau_{\text{electron}}^2 + \tau_{\text{jitter}}^2 + \tau_{\text{drift}}^2}$$

32 fs 19 fs 25 fs 8 fs 0

nature
photronics

ARTICLES

<https://doi.org/10.1038/s41566-019-0566-4>

Towards jitter-free ultrafast electron diffraction technology

Hyun Woo Kim^{1,2}, Nikolay A. Vinokurov^{1,3}, In Hyung Baek^{1,2}, Key Young Oang¹, Mi Hye Kim¹, Young Chan Kim^{1,4}, Kyu-Ha Jang^{1,2}, Kitae Lee^{1,2}, Seong Hee Park^{1,5}, Sunjeong Park¹, Junho Shin⁶, Jungwon Kim^{1,6}, Fabian Rotermund⁷, Sunglae Cho⁸, Thomas Feurer⁹ and Young Uk Jeong^{1,2*}



Electron is the most trustful probe of EM-field

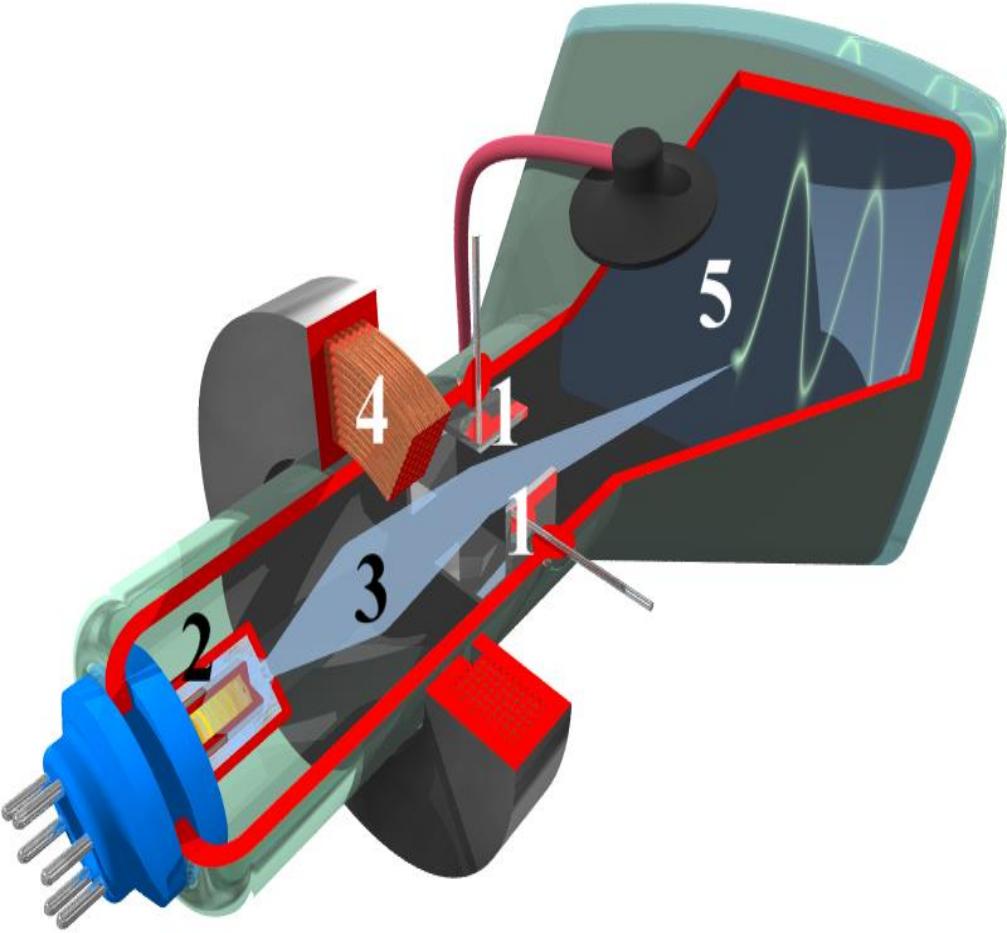
The first cathode-ray oscilloscope (1897)



K. F.
Braun



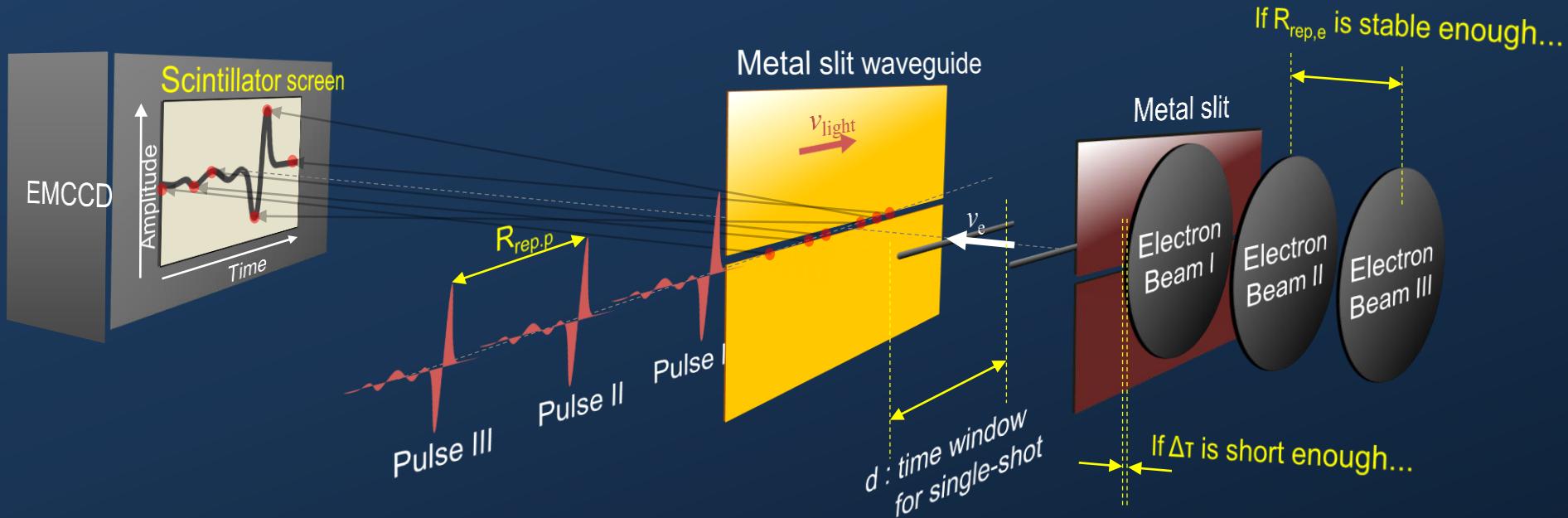
1 GHz at 10 mV analog oscilloscope (1979)



https://upload.wikimedia.org/wikipedia/commons/9/98/CRT_oscilloscope.png



Basic idea; Momentary waveform stamping on e-beam

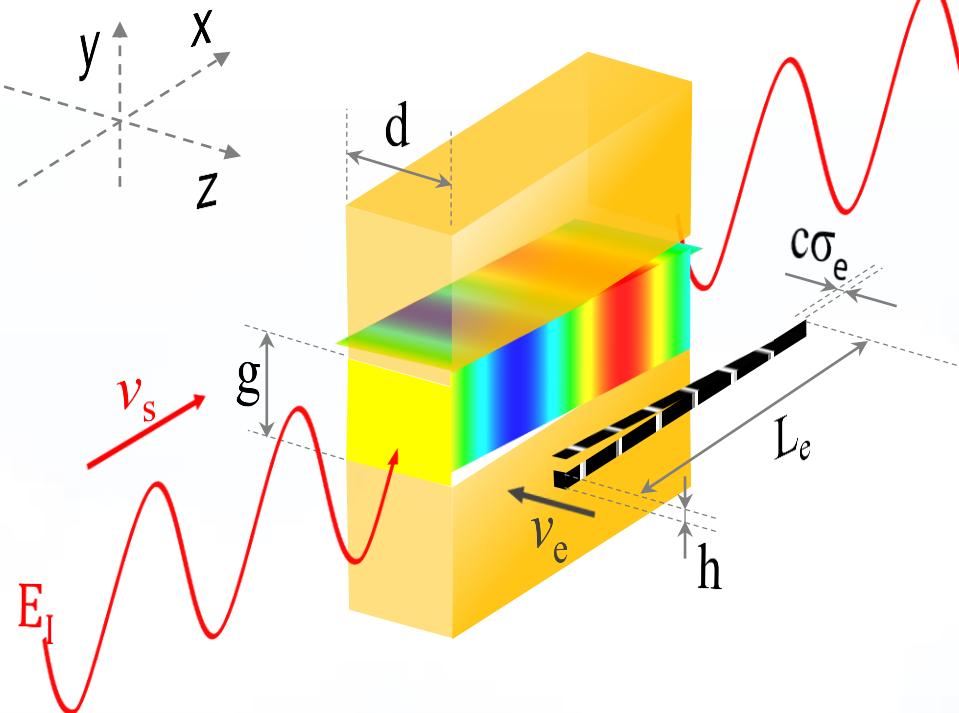


1. In this real-time ultrafast oscilloscope, what determines its bandwidth?
2. Propagating signal inside a slit waveguide is analogous to the incident signal ?

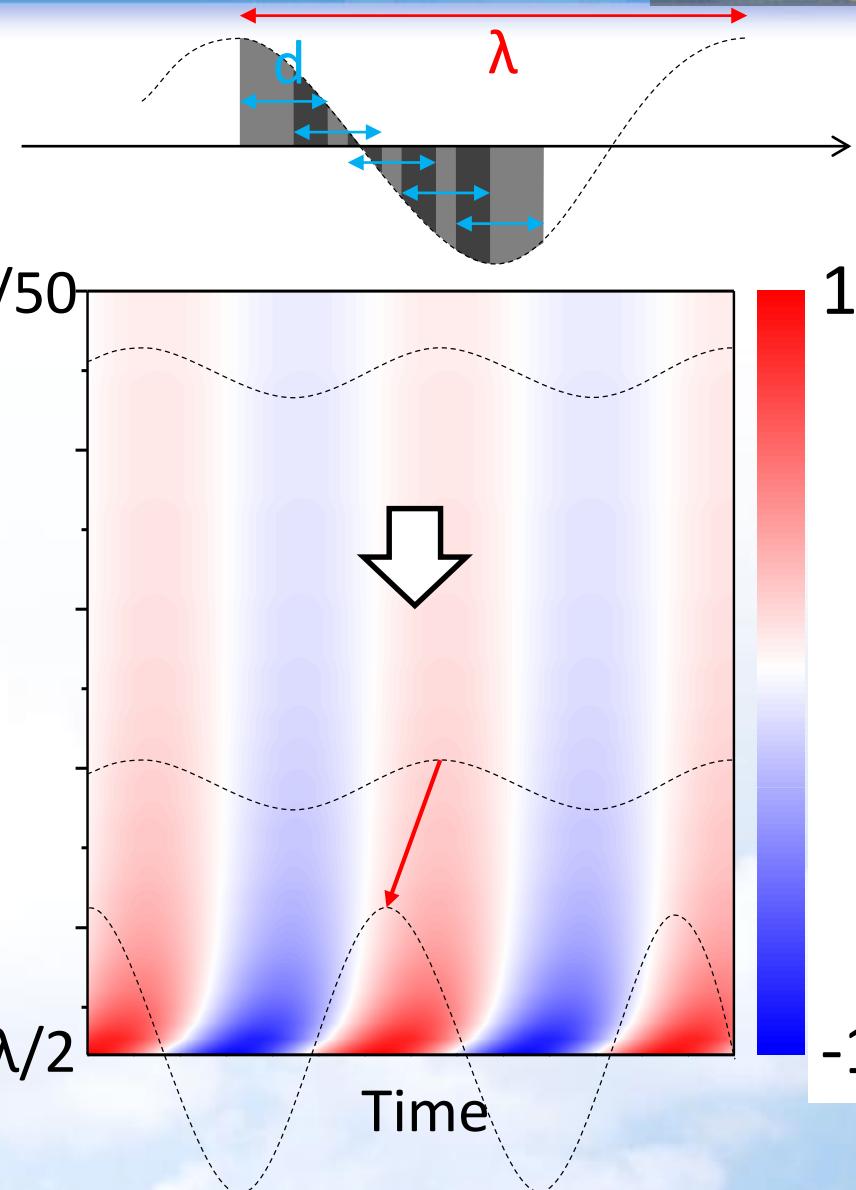


Waveform distortion depending on slit thickness (d)

1D electron array ($d > c\sigma_e$)

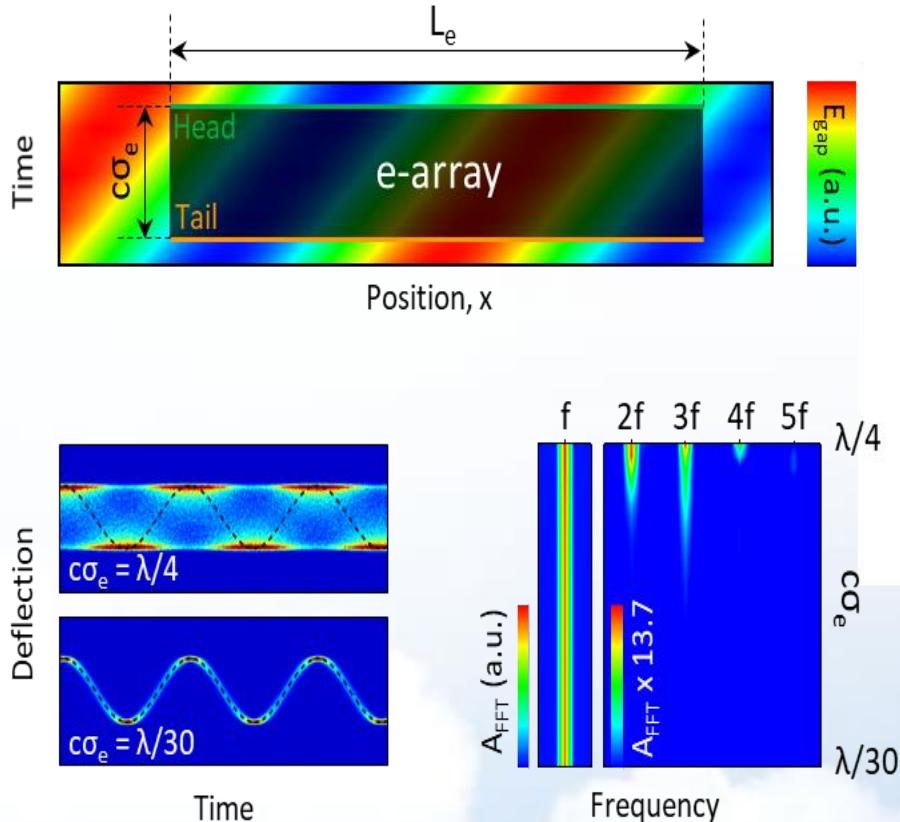
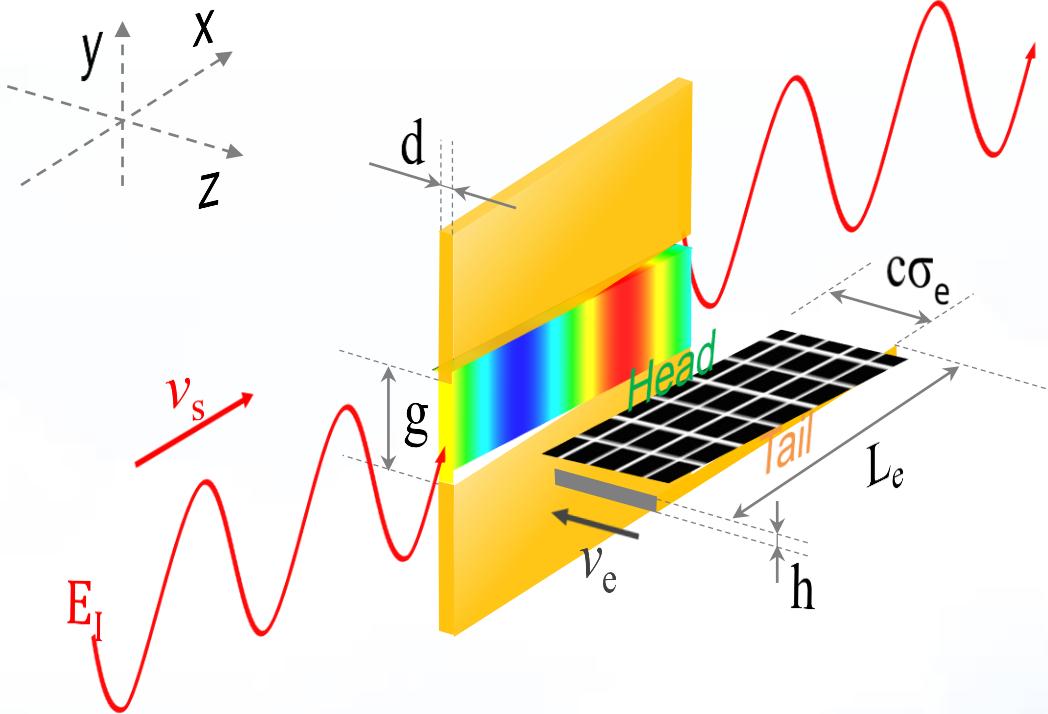


If d is smaller than $\lambda/15$,
there is no distortion of
waveform.



Waveform distortion depending on bunch duration ($c\sigma_e$)

Quasi-1D electron array ($d < c\sigma_e$)

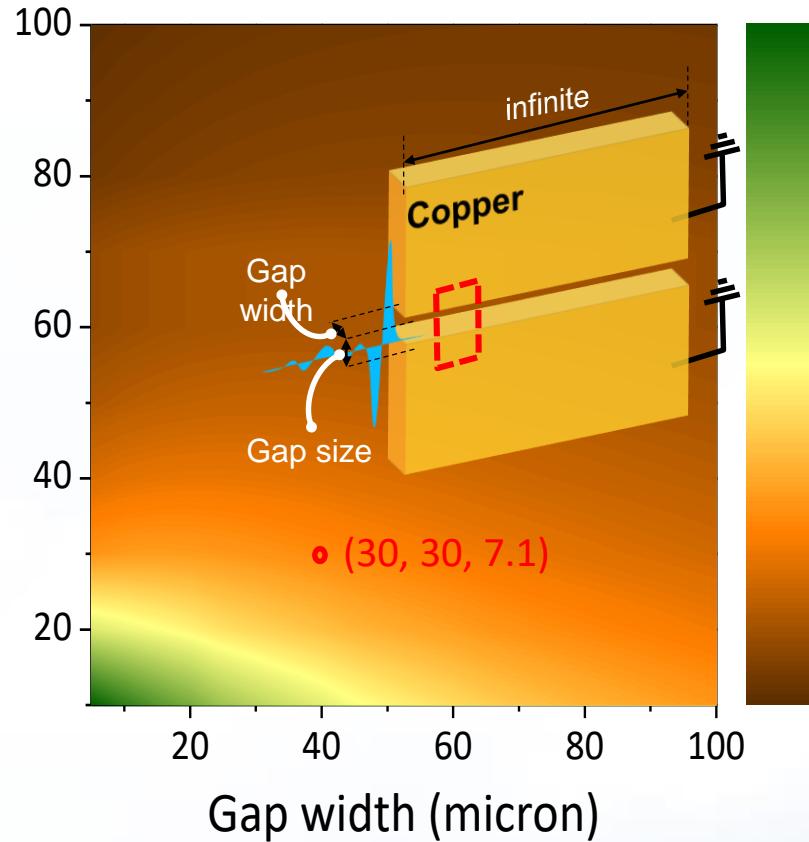


If $c\sigma_e$ is smaller than $\lambda/15$,
there is no distortion of
waveform.

Simulation on E-field propagation inside a Cu slit



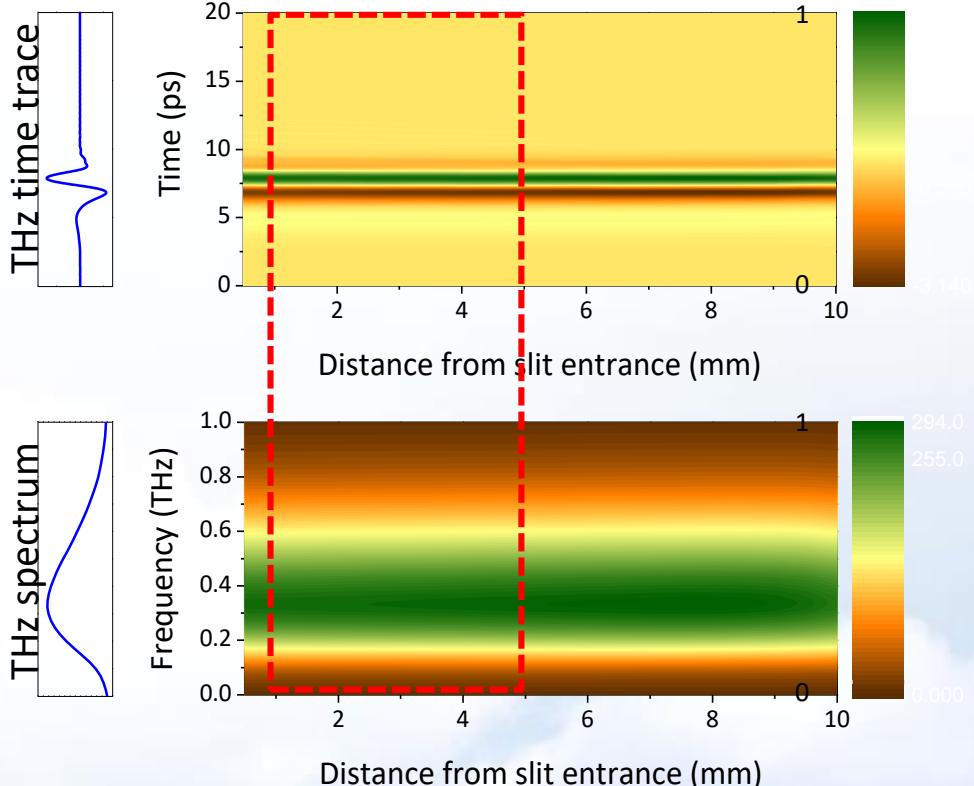
E-field enhancement



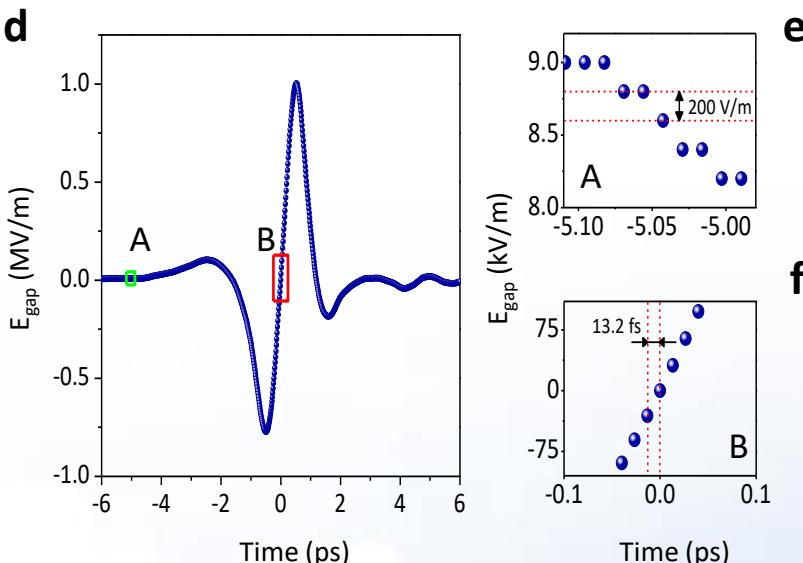
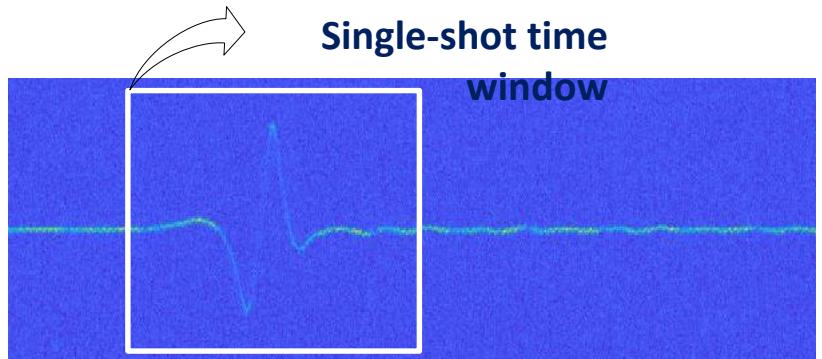
17

3

Waveform conservation @ both 30 microns

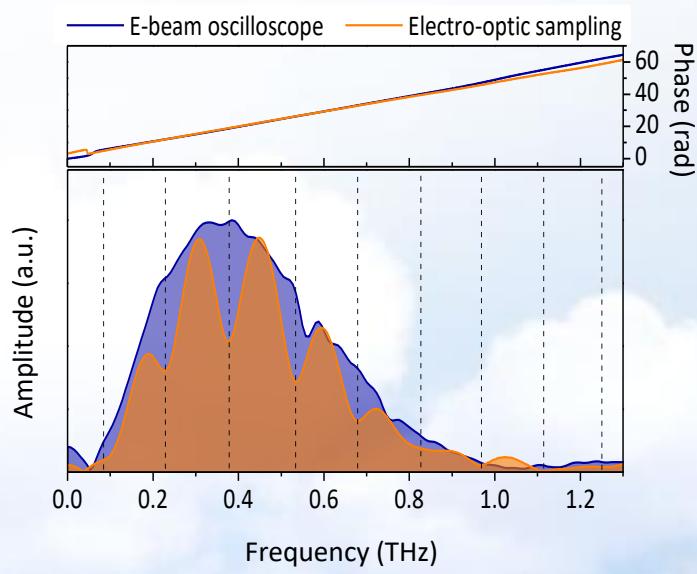
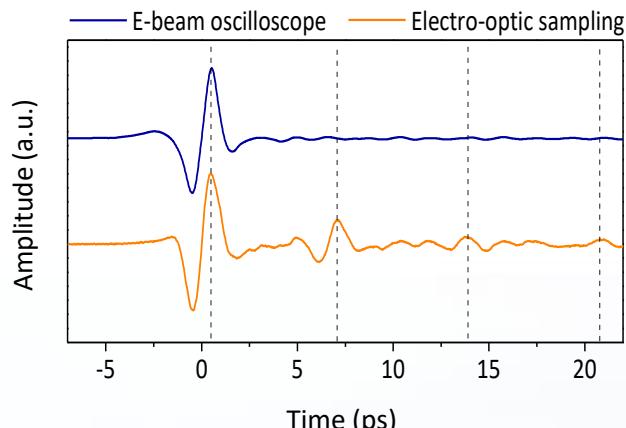
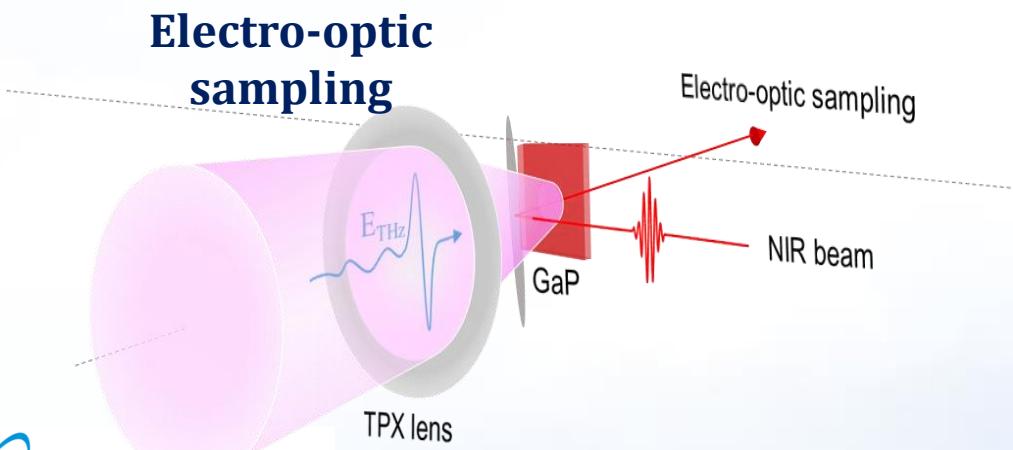
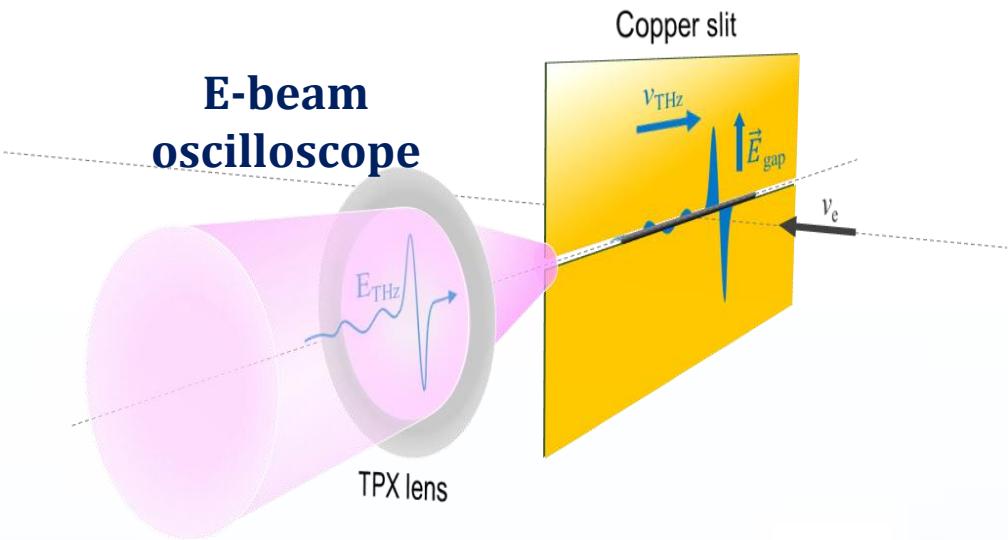


Recorded THz waveform



- Horizontal beam size @ slit = 3.7 mm
- Single-shot time window = 12.3 ps
- ~100 electrons/pixel for single-shot image
- Electron bunch : 0.5 pC, 3.101 MeV @ 50 Hz
- Time resolution per pixel = 13.2 fs
(Sampling rate \sim 75.7 TS/s)
- Resolution of E-field amplitude = 200 V/m

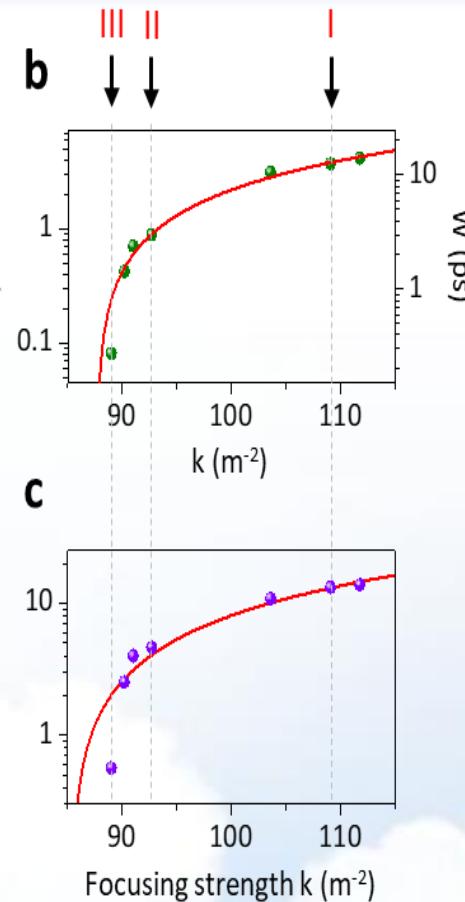
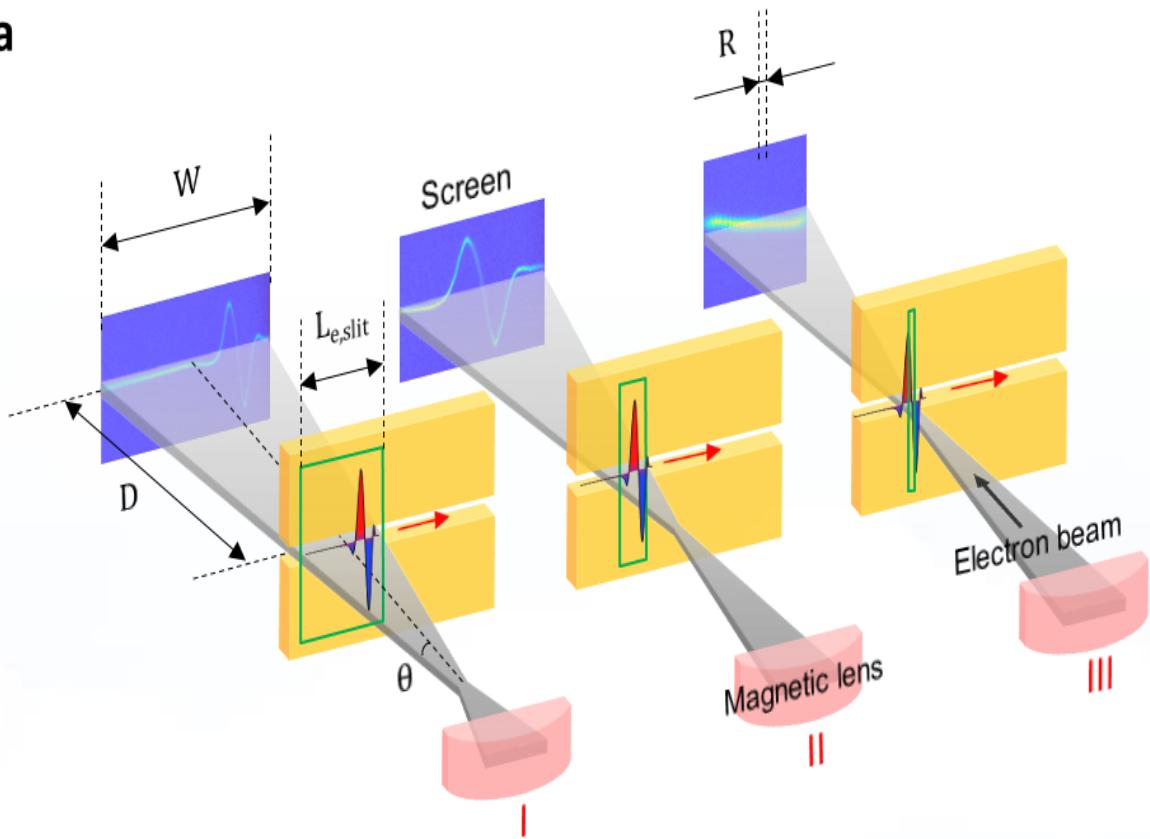
Signal integrity



Feasibility of real-time PHz oscilloscope



a



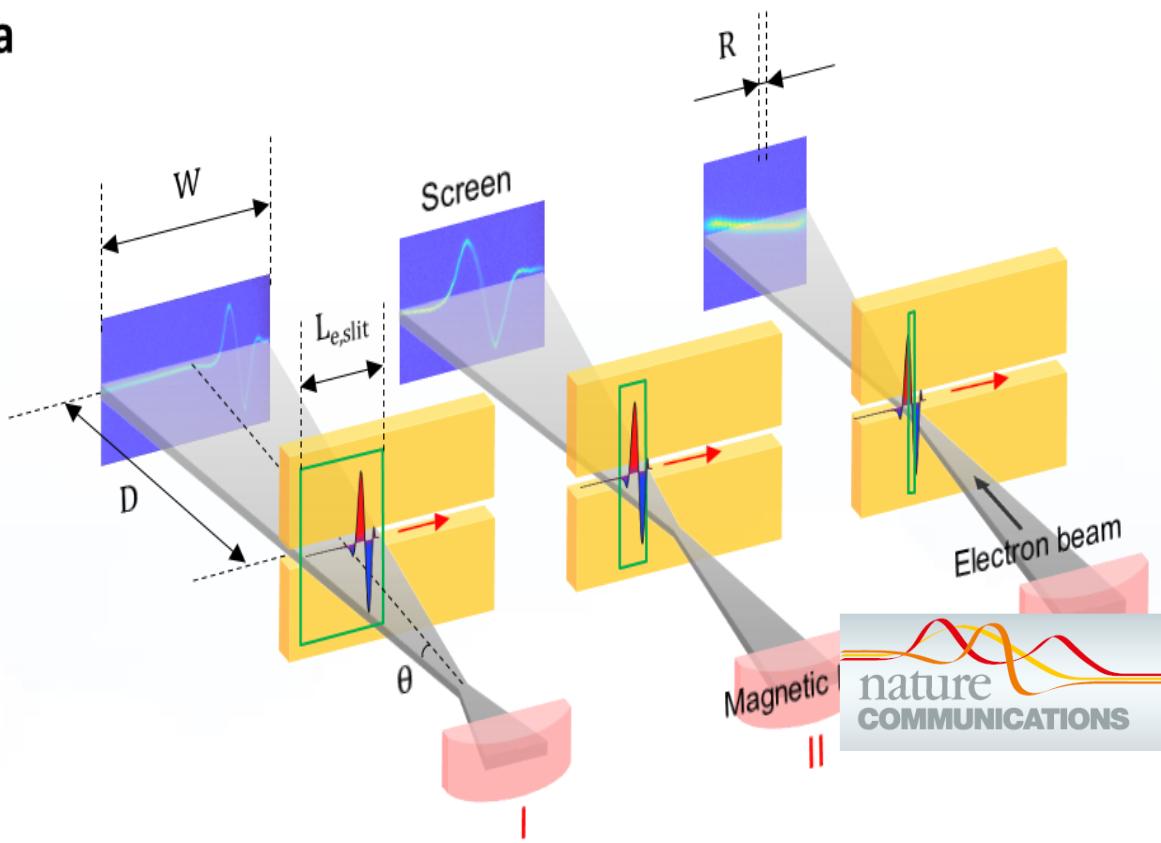
For 800 nm pulse visualization,

1. Electron pulse duration should be 170 as.
2. Thickness of metal slit should be 53 nm.

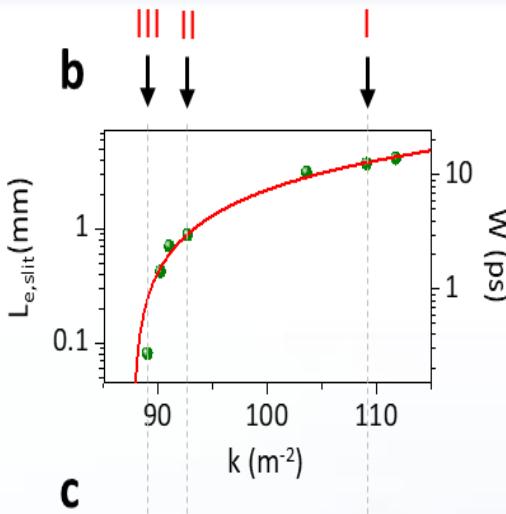


Feasibility of real-time PHz oscilloscope

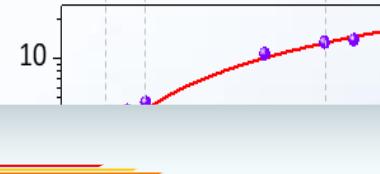
a



b



c



For 800 nm pulse visualization,

1. Electron pulse duration should be
2. Thickness of metal slit should be 5

ARTICLE

<https://doi.org/10.1038/s41467-021-27256-x>

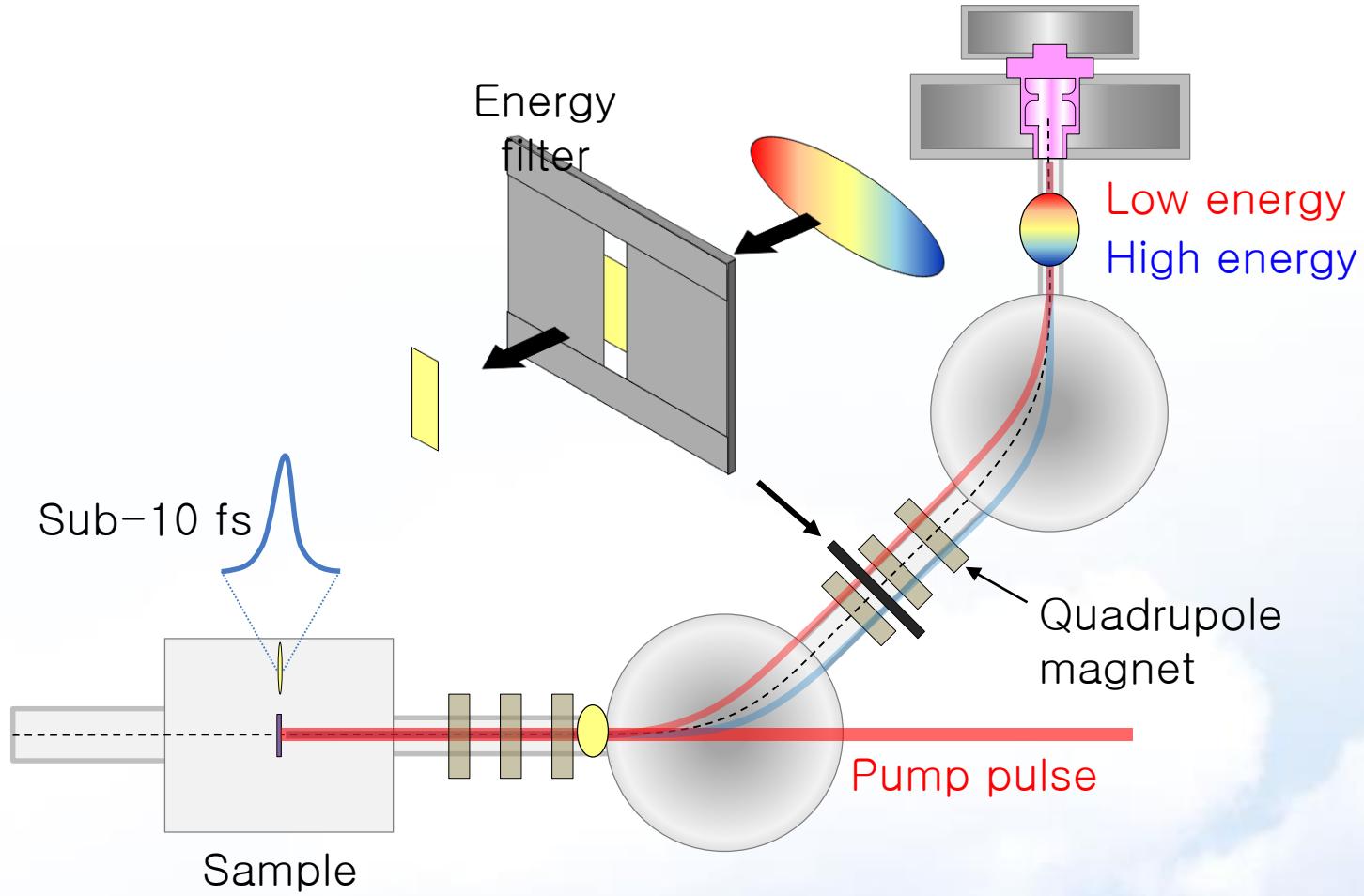
OPEN

Real-time ultrafast oscilloscope with a relativistic electron bunch train

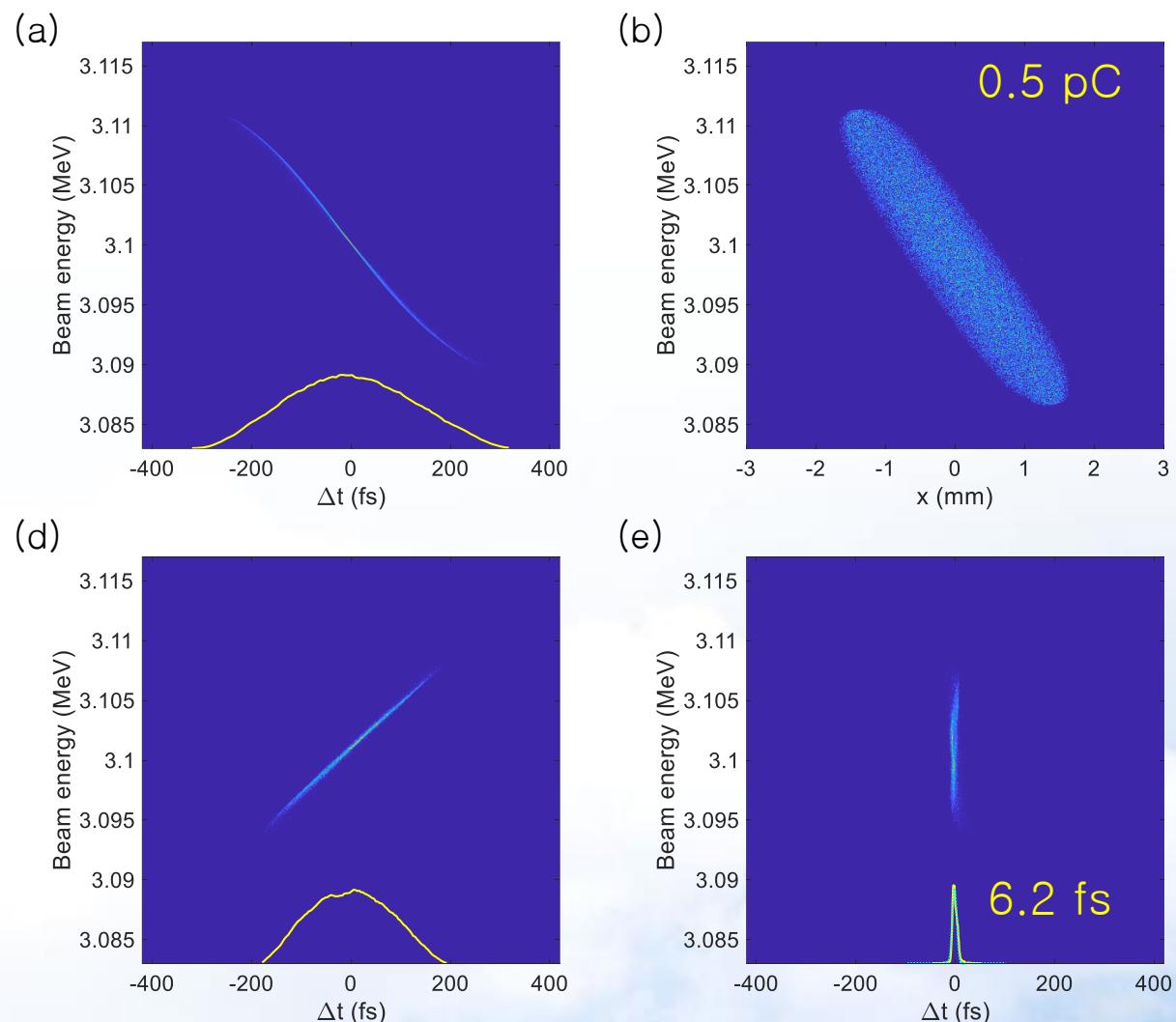
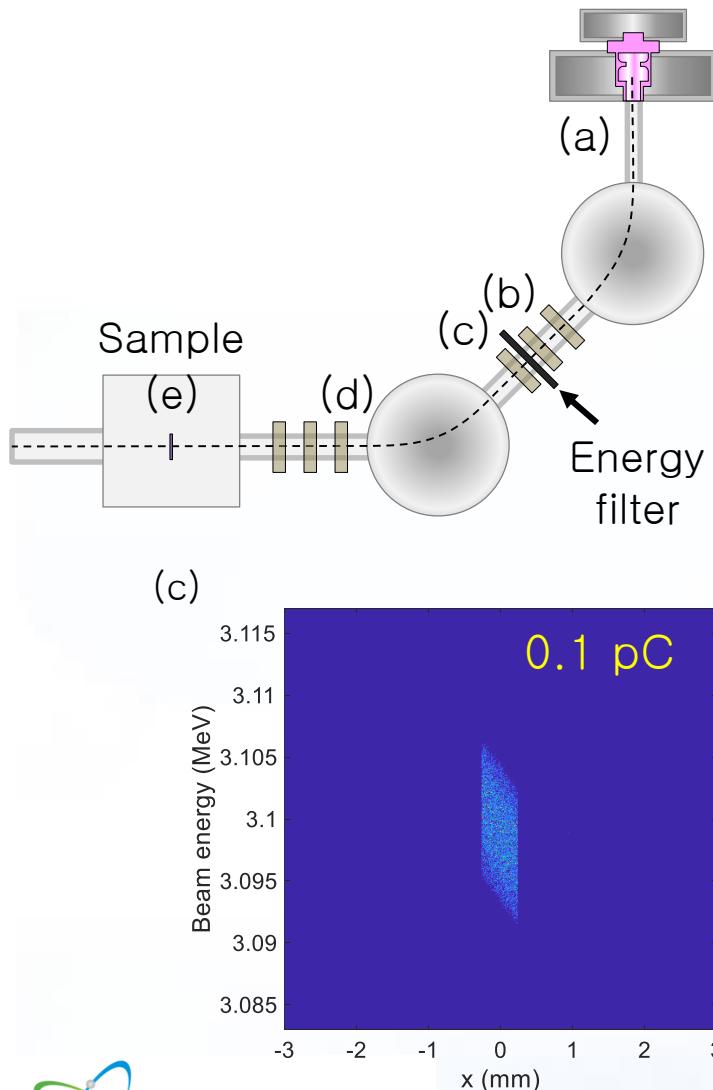
Check for updates

In Hyung Baek^{1,6}, Hyun Woo Kim^{1,6}, Hyeon Sang Bark^{1,6}, Kyu-Ha Jang¹, Sunjeong Park¹, Junho Shin¹, Young Chan Kim¹, Mihye Kim¹, Key Young Oang¹, Kitae Lee^{1,2}, Fabian Rotermund^{1,3}, Nikolay A. Vinokurov^{1,4,5} & Young Uk Jeong^{1,2}✉

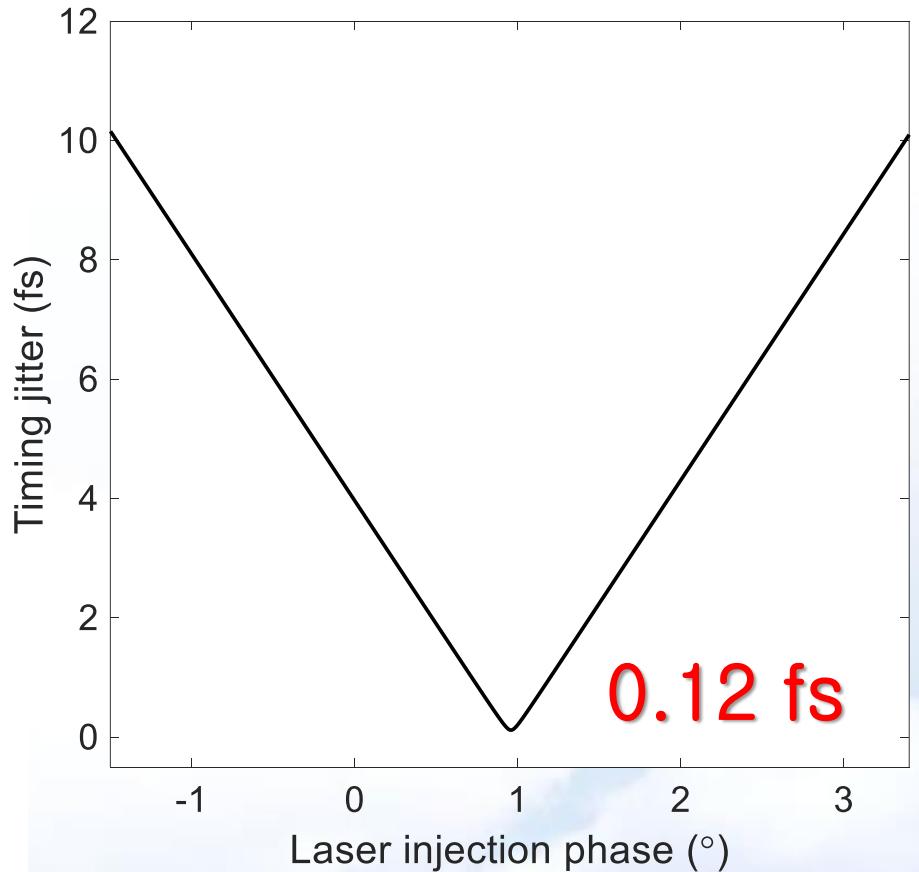
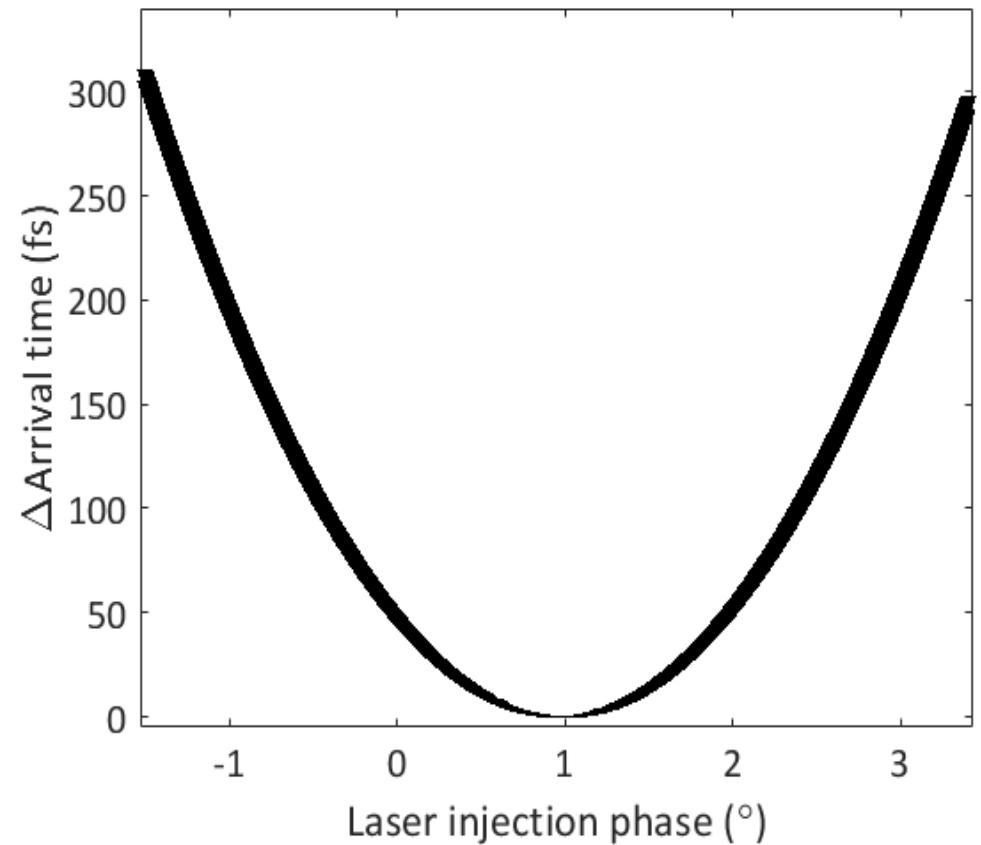
Sub-10 fs UED by using an Energy Filter



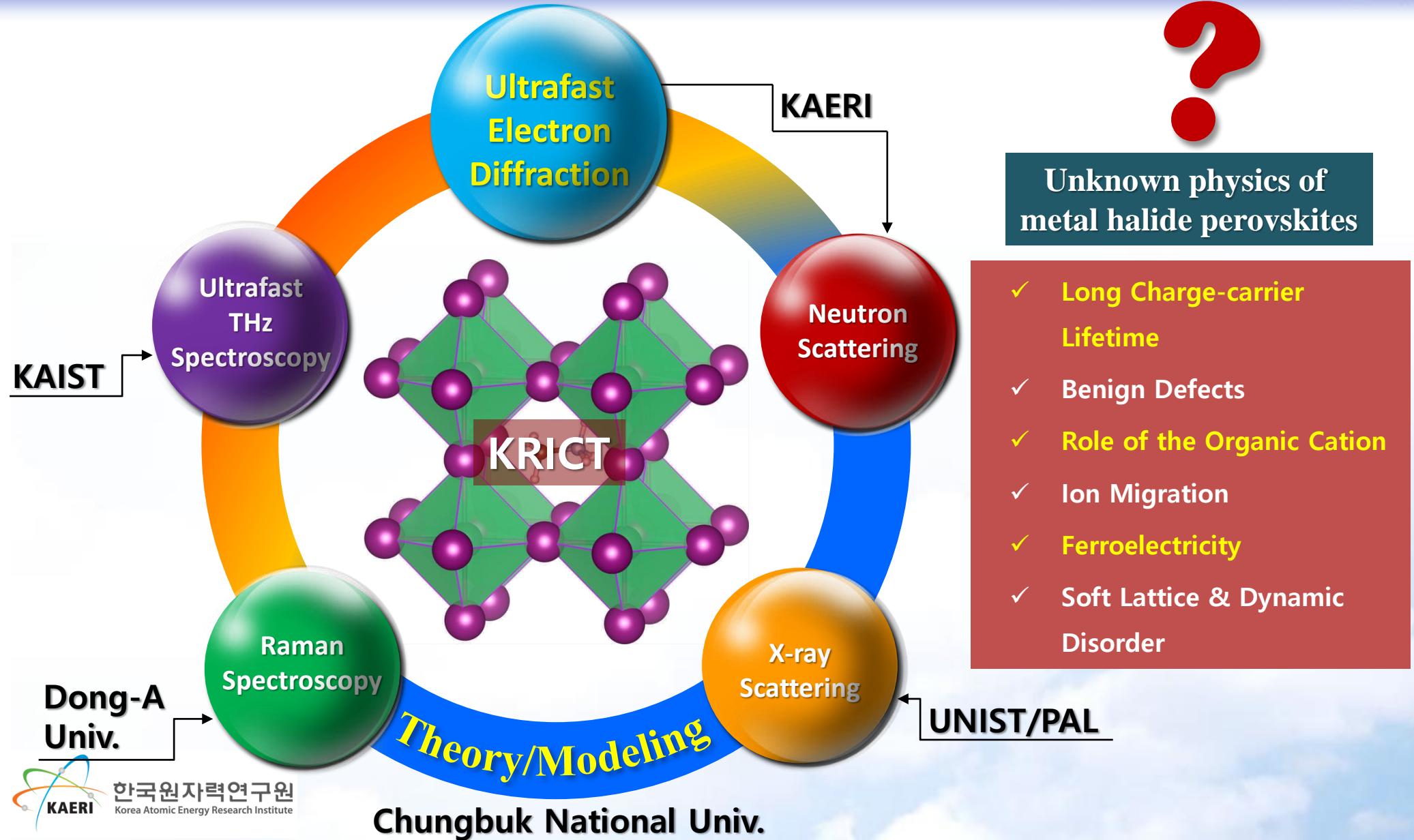
Sub-10 fs UED by using an Energy Filter



Sub-10 fs UED by using an Energy Filter

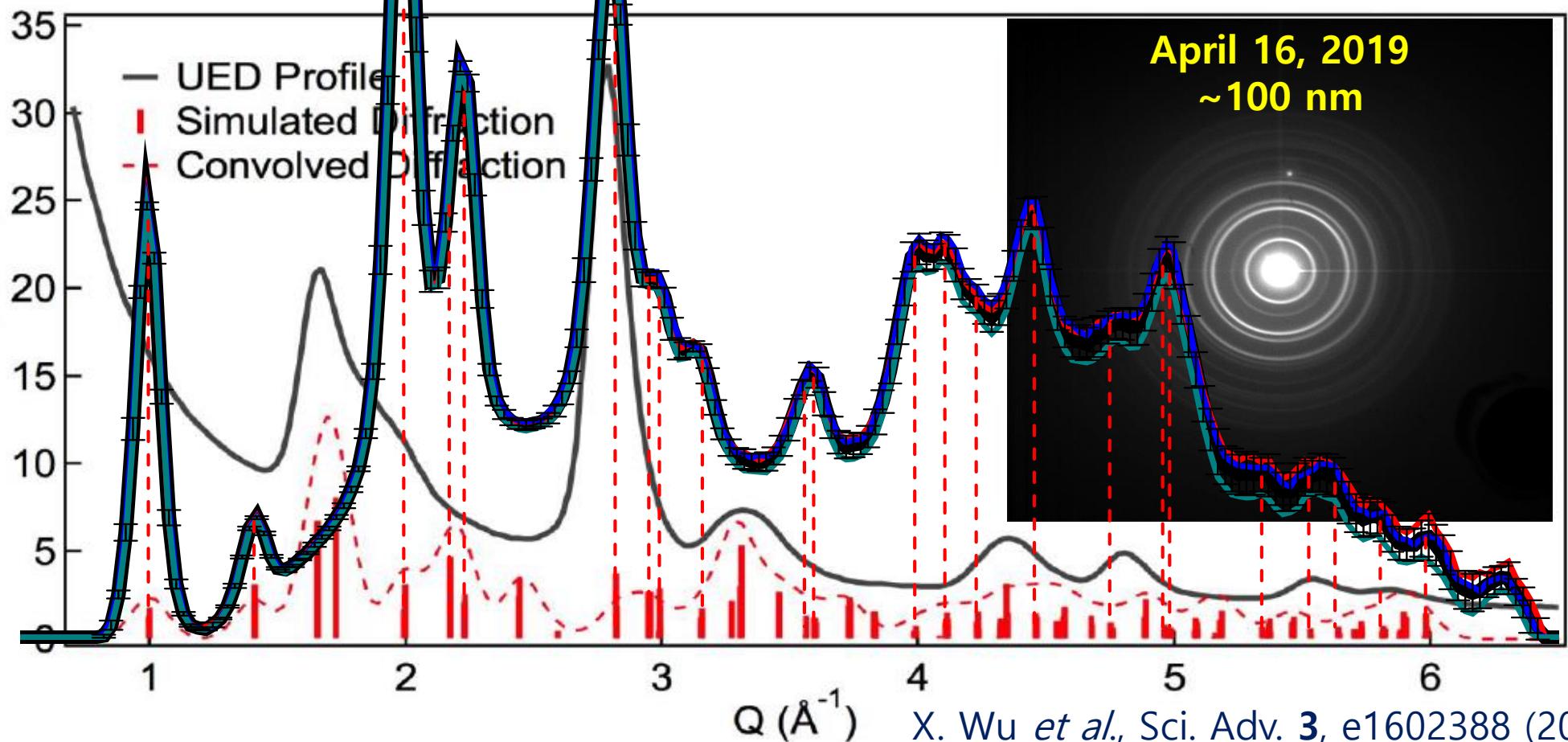


Collaboration for New Understanding





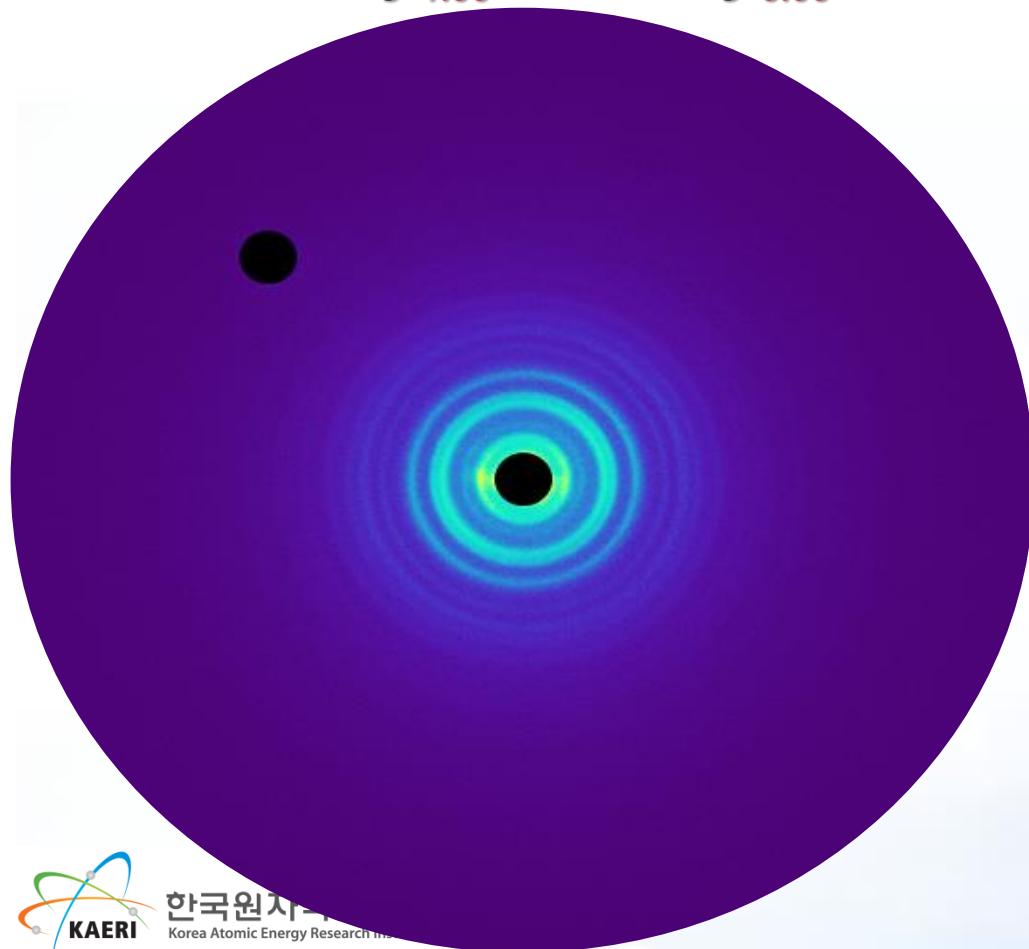
SLAC-UED vs. KAERI-UED



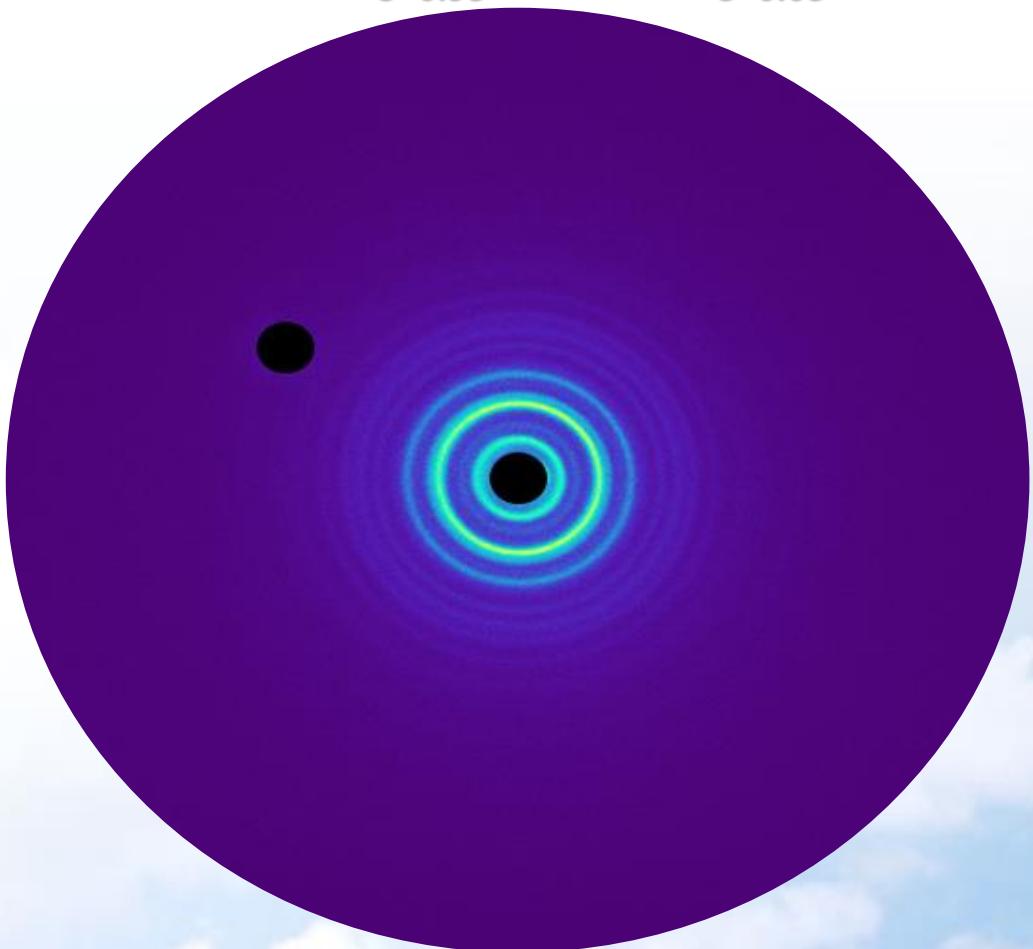


UED Data of $(\text{FAPbI}_3)_x(\text{MAPbBr}_3)_{1-x}$

125-nm-thick
 $(\text{FAPbI}_3)_{1.00}(\text{MAPbBr}_3)_{0.00}$

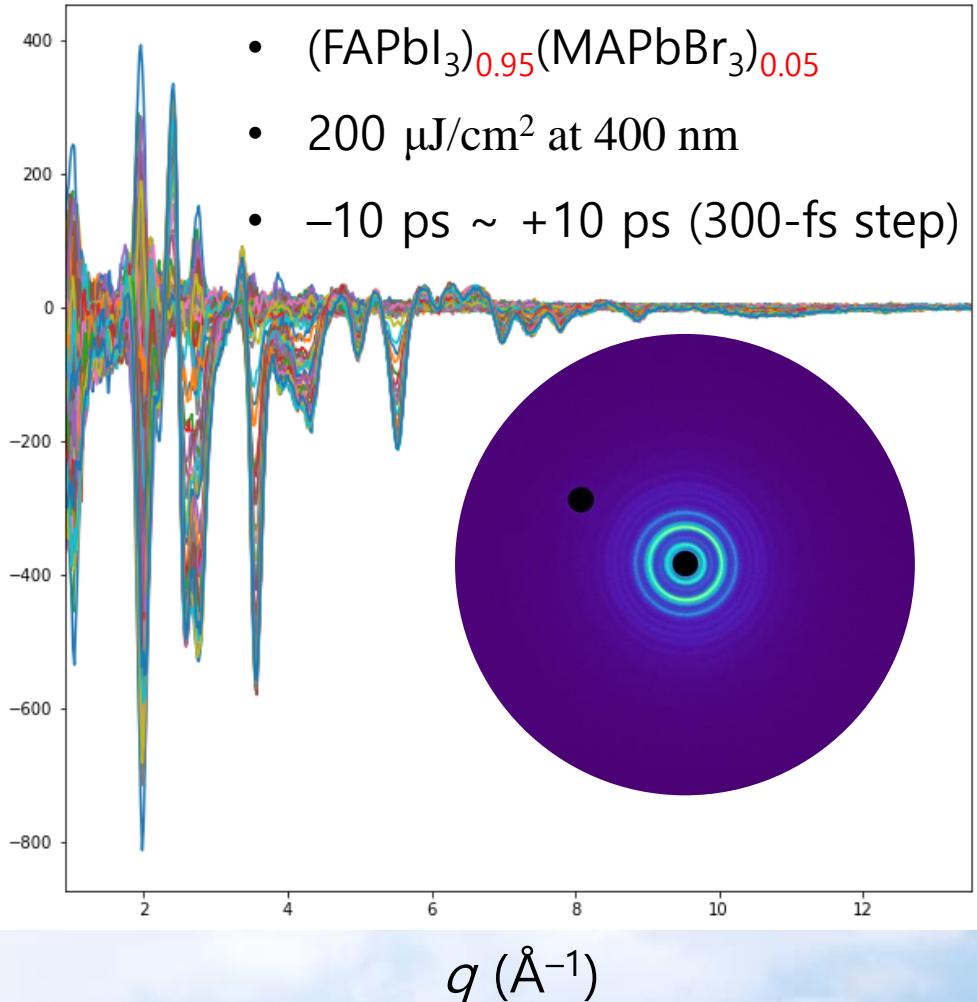
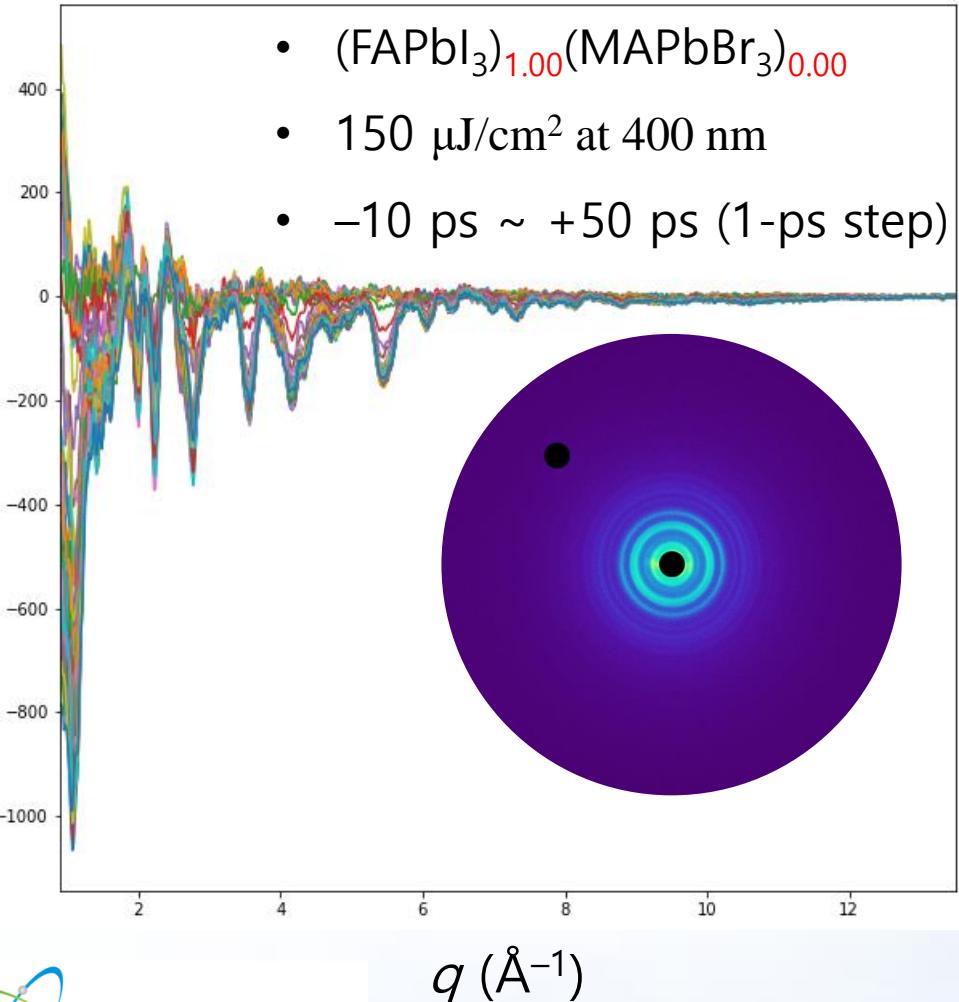


125-nm-thick
 $(\text{FAPbI}_3)_{0.95}(\text{MAPbBr}_3)_{0.05}$





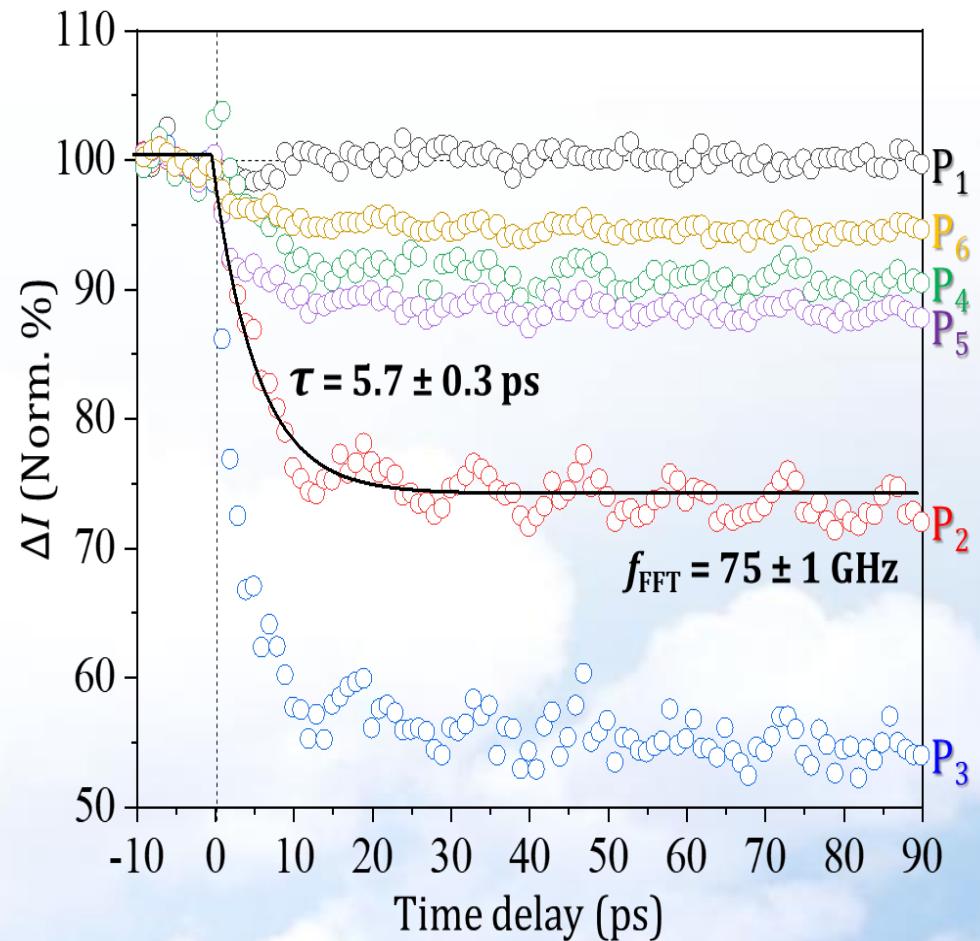
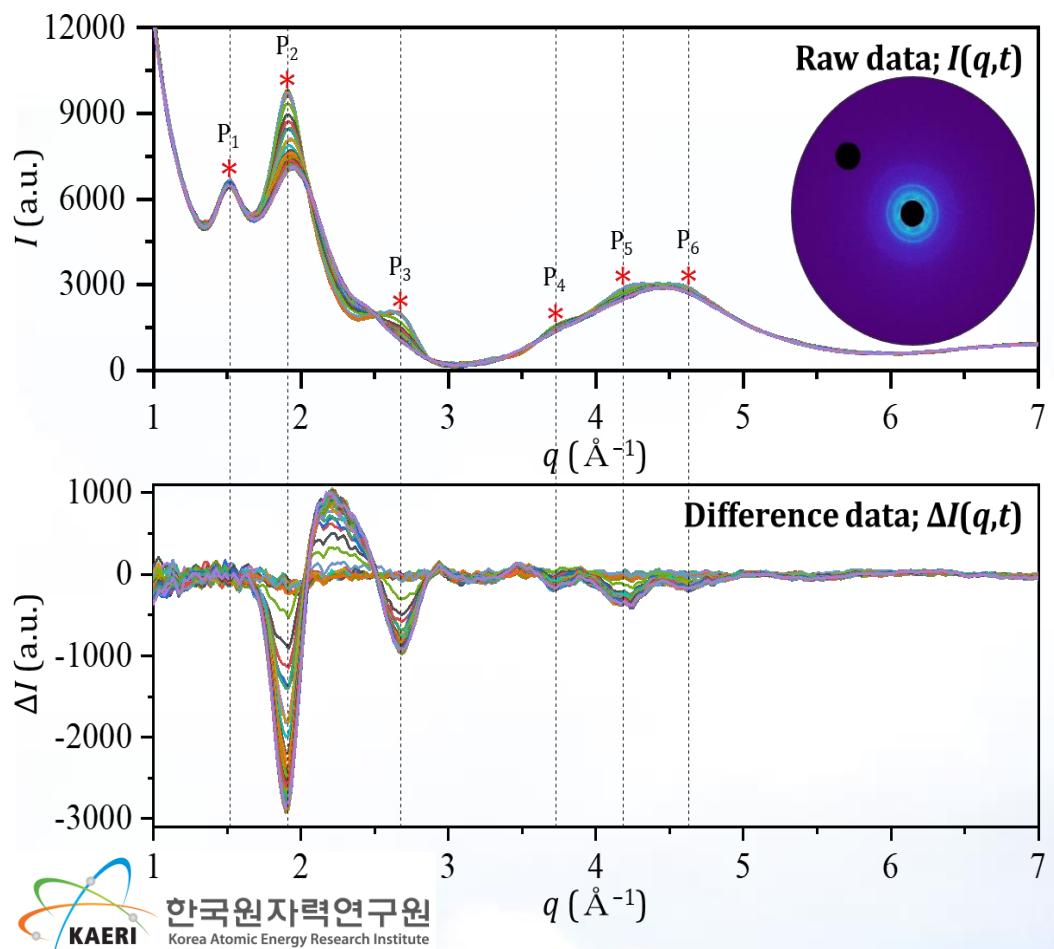
Overall 1D difference curves; $\Delta I(\mathbf{q}, t) = I(\mathbf{q}, t) - I(\mathbf{q}, t_{\text{ref}})$





Bi Photo-excited Dynamics Study

20-nm-thick polycrystalline Bismuth
($700 \mu\text{J}/\text{cm}^2$ at 400 nm; $-10 \text{ ps} \sim +90 \text{ ps}$ with 1-ps step)

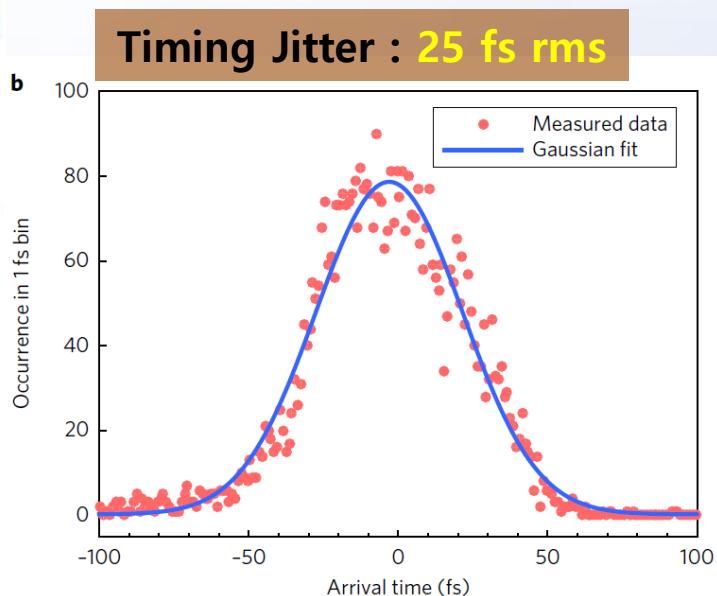
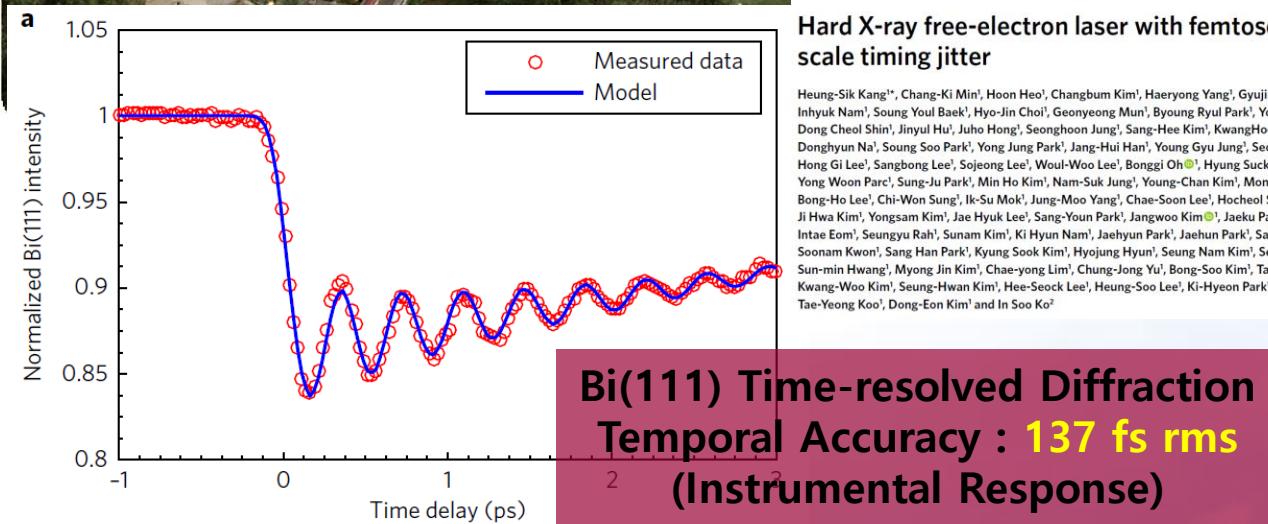


PAL X-FEL



Table 1 | Designed and measured parameters for hard and soft XFELs

Parameter	Designed value (hard/soft)	Hard	Soft
FEL radiation wavelength (nm)	0.1/1.0	0.104	1.52
Electron energy (GeV)	10/3.15	9.47	3.0
Slice emittance (mm mrad)	0.5	0.55	0.55
Beam charge (nC)	0.2	0.14	0.14
Peak current at undulator (kA)	3.0/2.5	2.5	2.2
Pulse repetition rate (Hz)	60	30	30
FEL gain length (m)	3.6/1.8	3.61	2.08
Photons per pulse (10^{11})	2.6/10	1.8	10.0





X-FEL v.s. UED

엑스선과 전자 비교

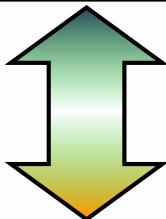
X-FEL (PAL X-FEL)

Big molecules of bio & nano-bio complex

X-ray

Low scattering power

Long penetration



Complementary Tools

Electron

Strong scattering power

Short penetration

Sparse materials like 2-D, gas and liquid

UED (KAERI)

UED for Future



$E = mc^2$

circus

Nature | Vol 596 | 26 August 2021 | 531

Article

Direct observation of ultrafast hydrogen bond strengthening in liquid water

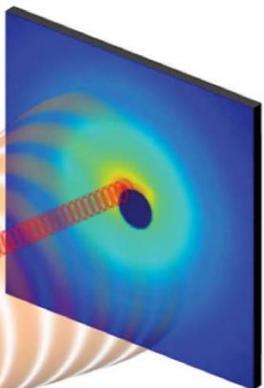
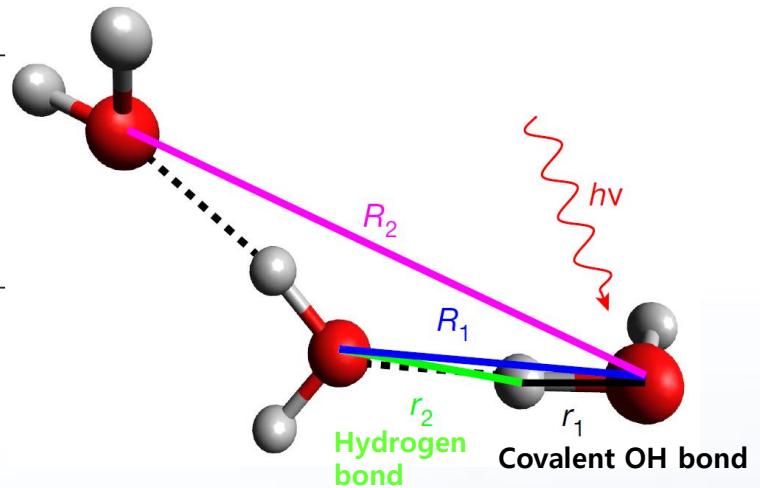
<https://doi.org/10.1038/s41586-021-03793-9>

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Jie Yang^{1,2,11}✉, Riccardo Dettori¹, J. Pedro F. Nunes⁴, Nanna H. List^{1,2,5}, Elisa Blasini^{1,2}, Martin Centurion⁴, Zhijiang Chen¹, Amy A. Cordones², Daniel P. Deponte¹, Tony F. Heinz^{2,6}, Michael E. Kozina^{1,2}, Kathryn Ledbetter^{2,7}, Ming-Fu Lin¹, Aaron M. Lindenberg^{2,8,9}, Mianzhen Mo¹, Anders Nilsson¹⁰, Xiaozhe Shen¹, Thomas J. A. Wolf^{1,2}, Davide Donadio³✉, Kelly J. Gaffney²✉, Todd J. Martinez^{1,2,5}✉ & Xijie Wang¹✉



RESEARCH

Science 368, 885–889 (2020)

CHEMICAL PHYSICS

Simultaneous observation of nuclear and electronic dynamics by ultrafast electron diffraction

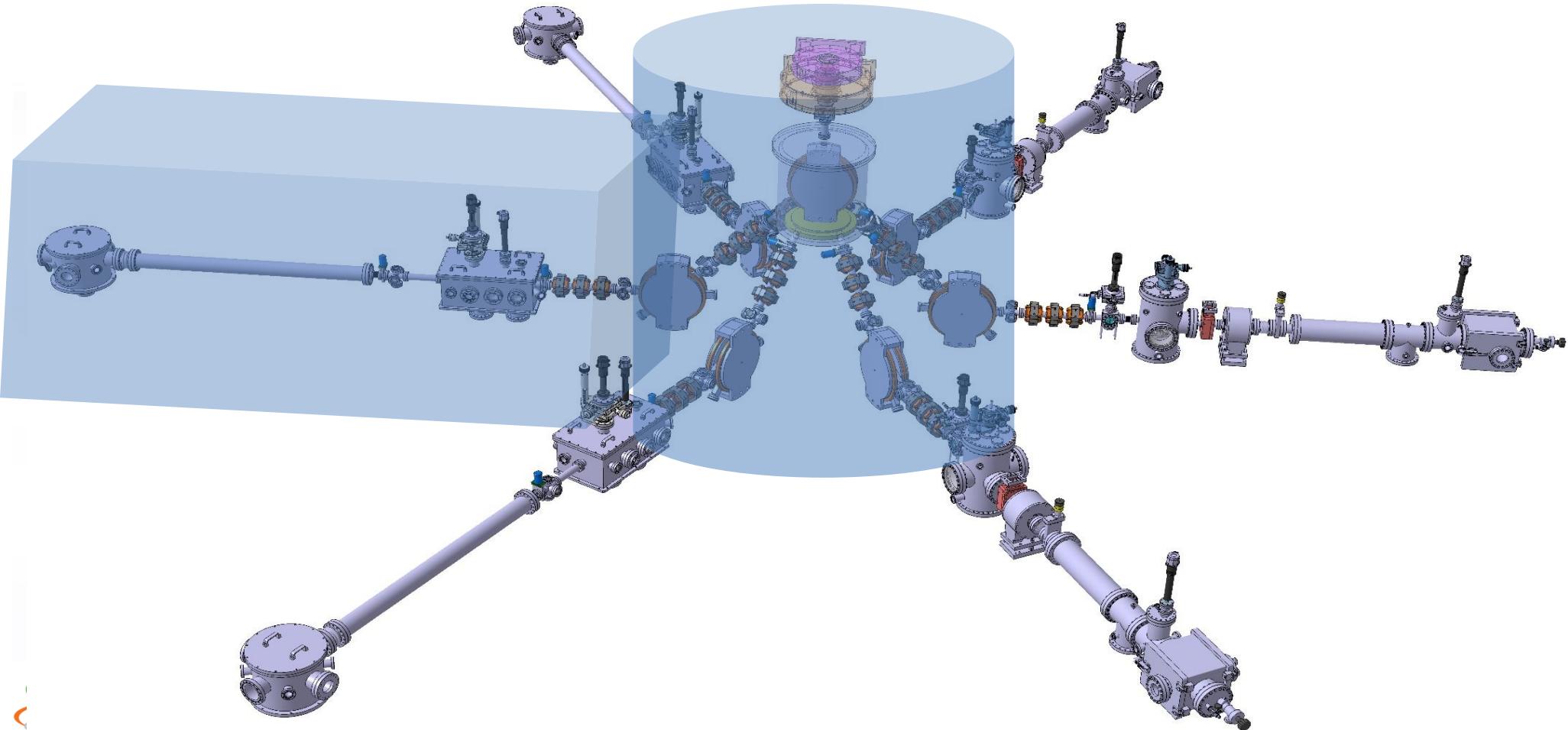
Jie Yang^{1,2,*†}, Xiaolei Zhu^{1,2,3†}, J. Pedro F. Nunes⁴, Jimmy K. Yu^{2,3,5}, Robert M. Parrish^{1,2,3}, Thomas J. A. Wolf^{1,2}, Martin Centurion⁴, Markus Gühr⁶, Renkai Li^{1‡}, Yusong Liu⁷, Bryan Moore⁴, Mario Niebuhr⁶, Suji Park^{1§}, Xiaozhe Shen¹, Stephen Weathersby¹, Thomas Weinacht⁷, Todd J. Martinez^{1,2,3*}, Xijie Wang^{1*}

UED User Facility



90도 휠구조를 3차원으로 배치하면 6~8 빔라인 구축

5대권역 설치시 차세대 방사광의 1/10 예산으로 4세대급 방사선 30개 빔라인 구축



Acknowledgements



Development & characterization of UED Apparatus

Dr. Hyun Woo Kim, Dr. In Hyung Baek, Ms. Mi Hye Kim, Mr. Young Chan Kim, Dr. Sunjeong Park, Dr. MoonSik Chae, Dr. Key Young Oang, Dr. Junho Shin, Mr. Sangyoon Bae, Dr. Jungho Moon, Dr. Kyu-Ha Jang, Dr. Kitae Lee, Dr. Boris Gudkov, Dr. Sergey Miginsky



RF-laser synchronization

Prof. Jungwon Kim



System configuration

Prof. Nikolay A. Vinokurov



RF deflector

Prof. Seong Hee Park



Split ring resonator

Dr. Zoltan Ollmann,
Ms. Mozhgan Hayati,
Prof. Thomas Feurer

RF gun design

Dr. Jang-Hee Han



Sample preparation

Prof. Sunglae Cho

감사합니다!!



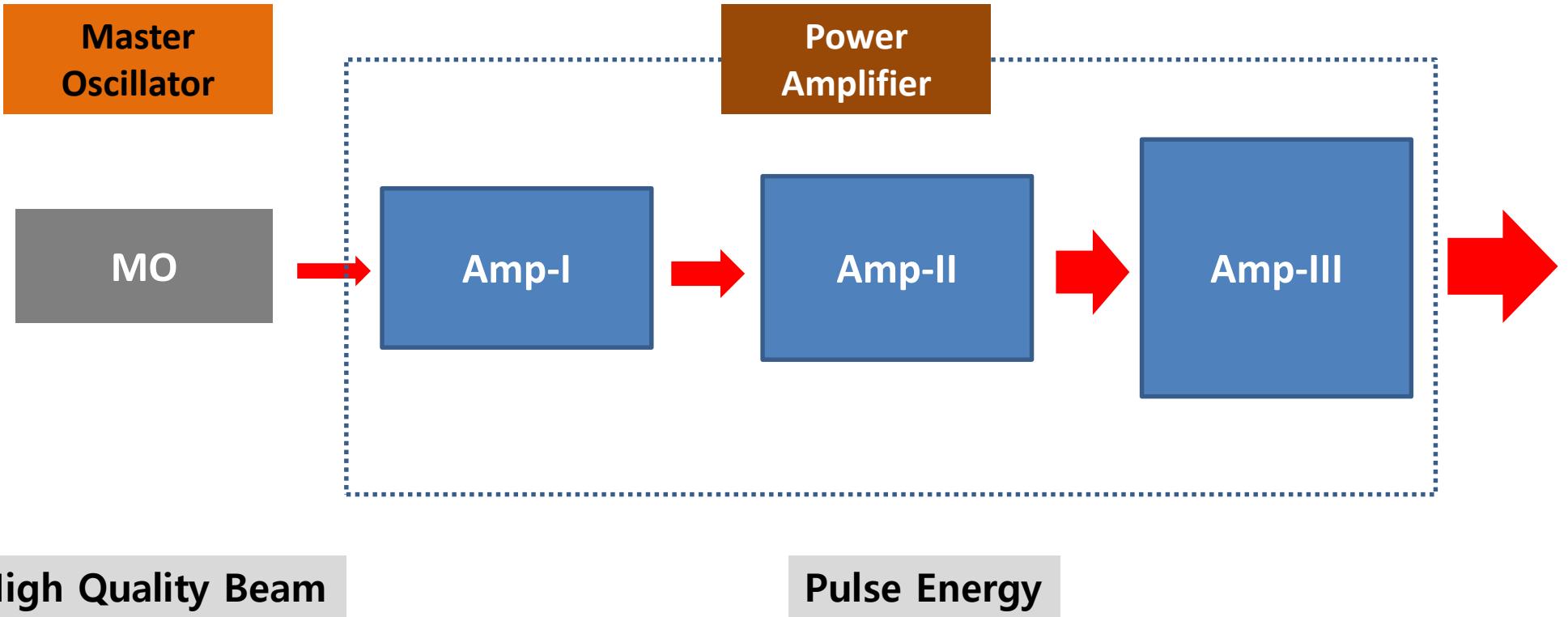
EUV Source for Lithography



2022. 7. 13

Young UK JEONG

Master Oscillator & Power Amplifier



Laser-produced plasma (LPP) Source

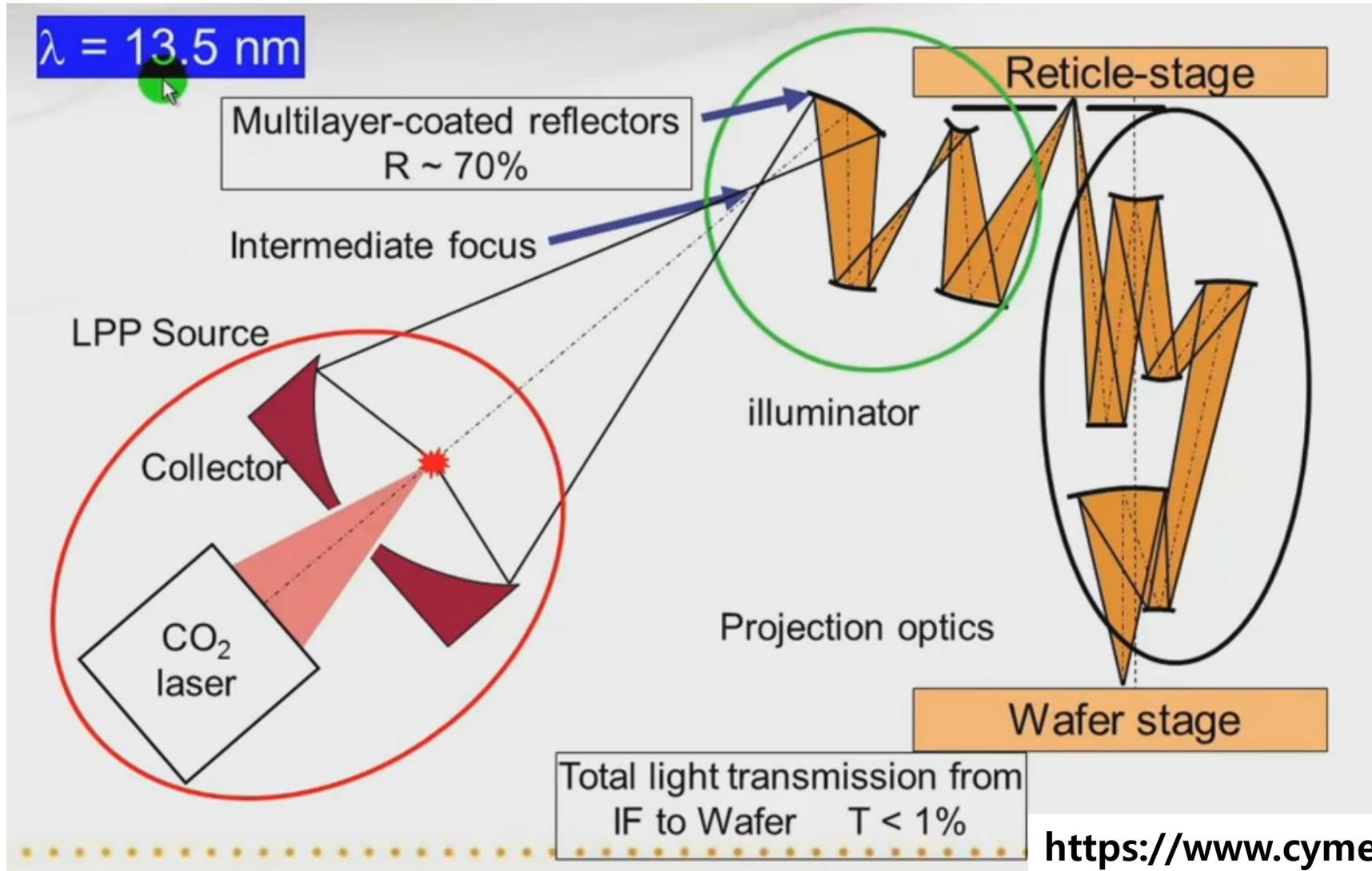


- Pulsed Laser + Laser-produced plasma
(CO₂ pulsed laser + Sn plasma)

- Requirements for EUV source, ASML
 - ※ > 100 wph (@ photo-register sensitivity 15 mJ/cm²)
 - Wavelength : 13.5 nm (7 nm node, R: 60-70%)
 - Power : 250 W (@ IF, bandwidth 2%)

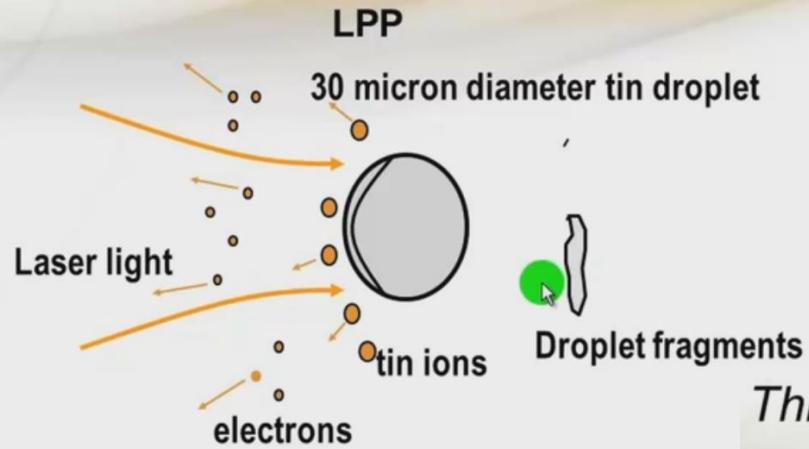


Laser-produced plasma (LPP) Source



<https://www.cymer.com/>

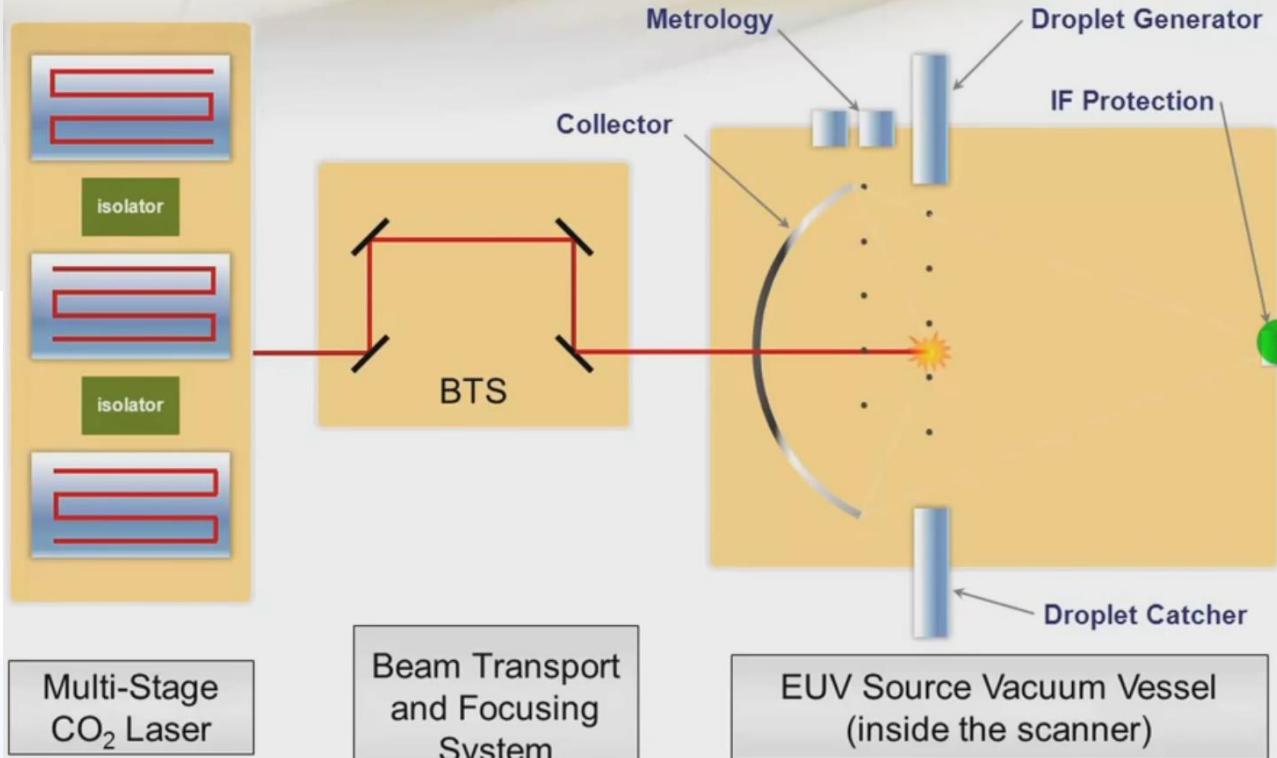
Laser-produced plasma (LPP) Source



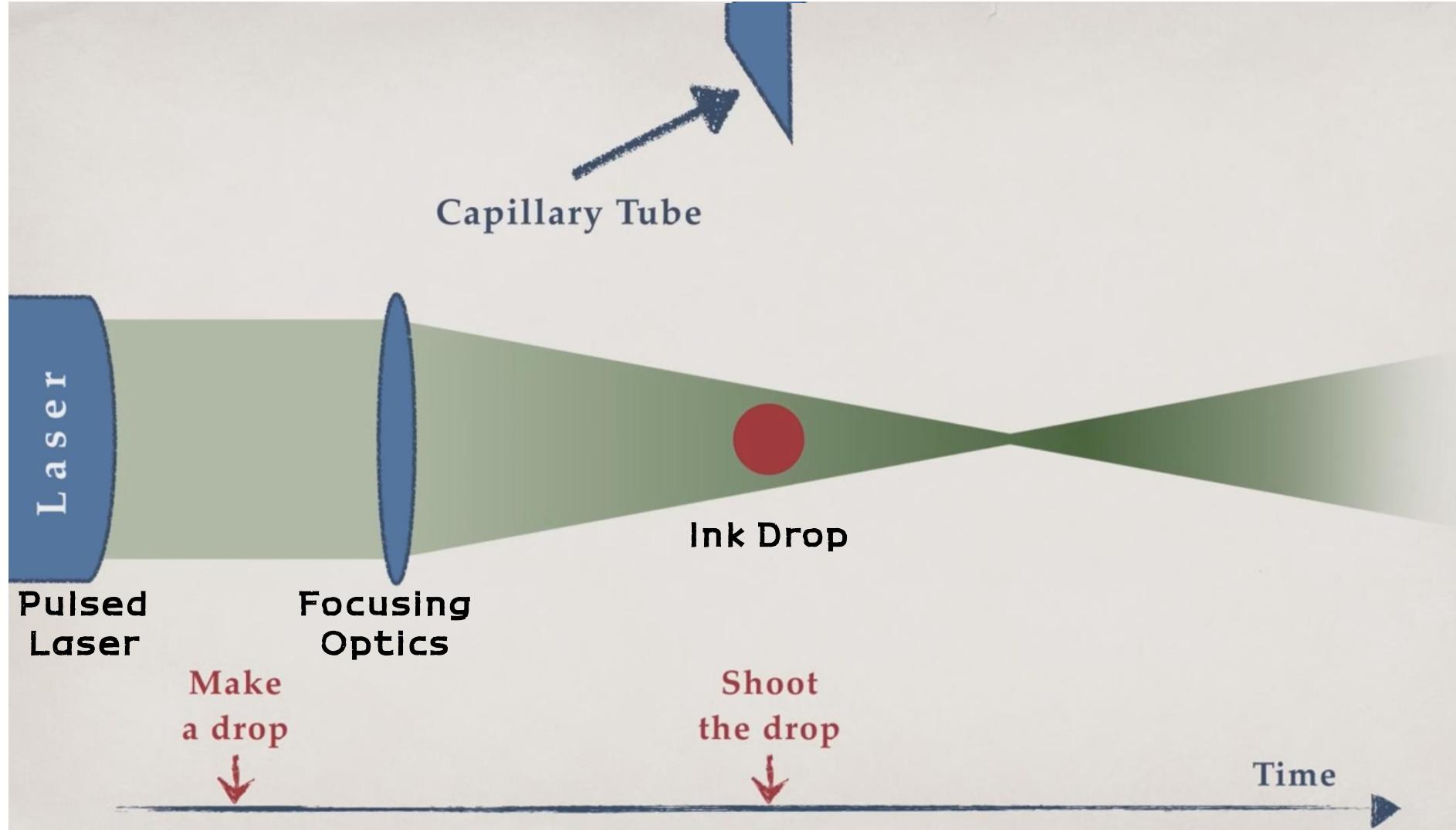
<https://www.cymer.com/>

- A high power laser evaporates a tin droplet, then heats the vapor to critical temperature where electrons are shed, leaving behind ions, which are further heated until they start emitting photons

Three key technologies: laser, droplet generation, collector

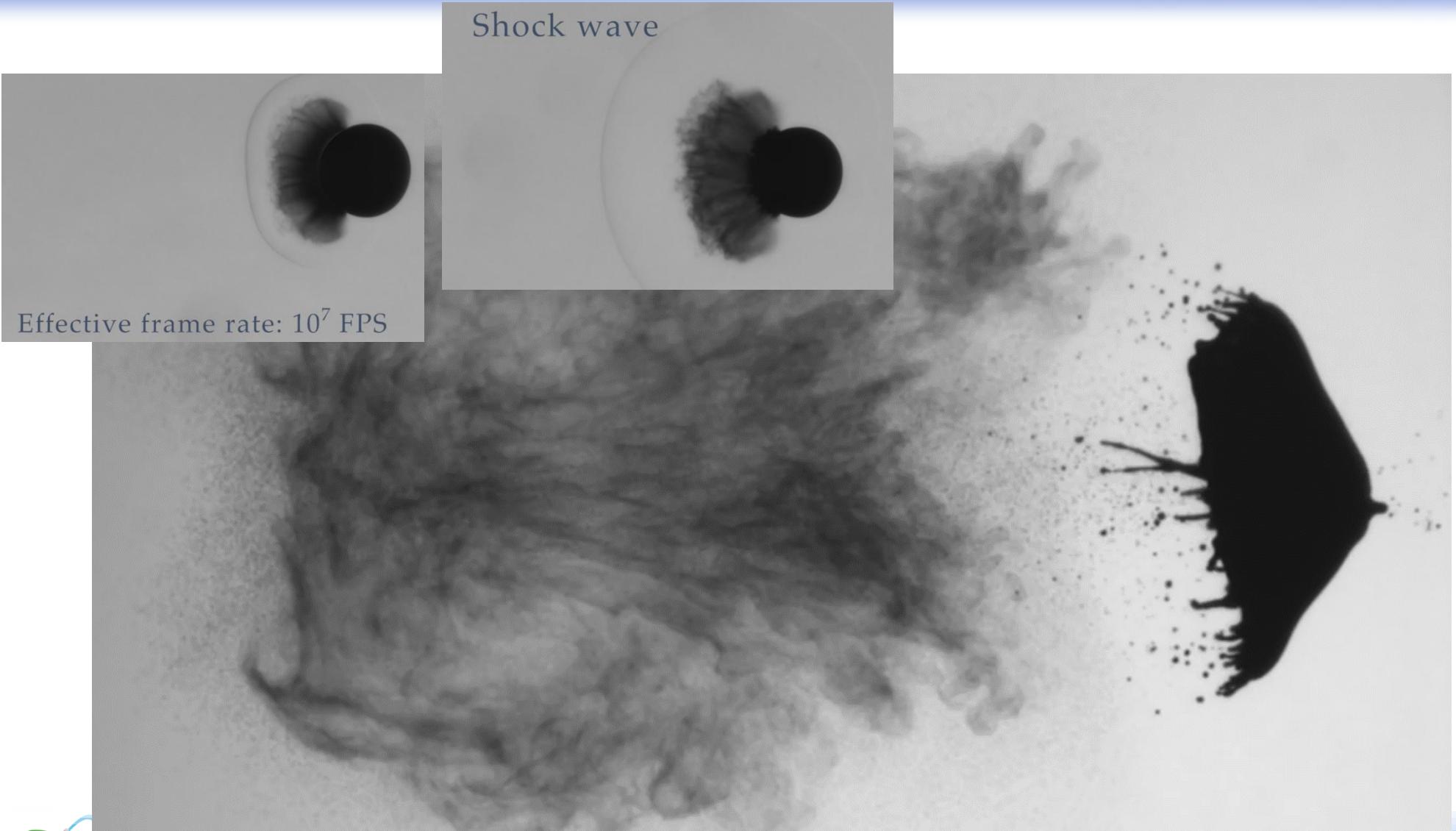


Laser-produced plasma (LPP) Source





Laser-produced plasma (LPP) Source



Laser-produced plasma (LPP) Source



<https://www.youtube.com/watch?v=bRbHDtPbHe0>

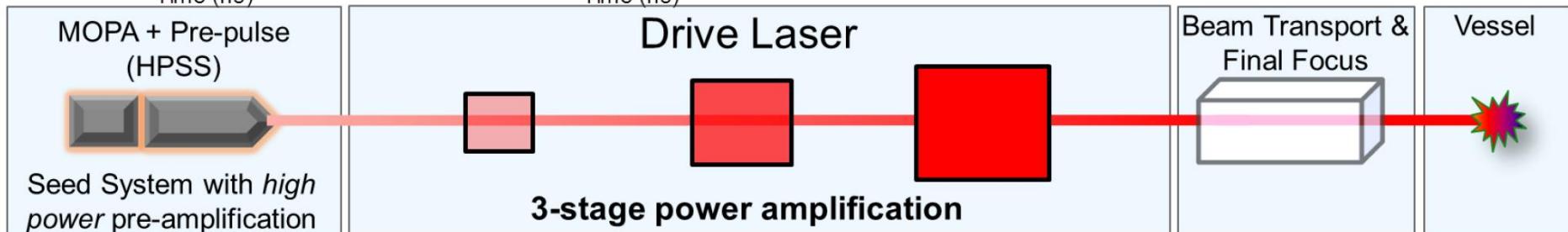
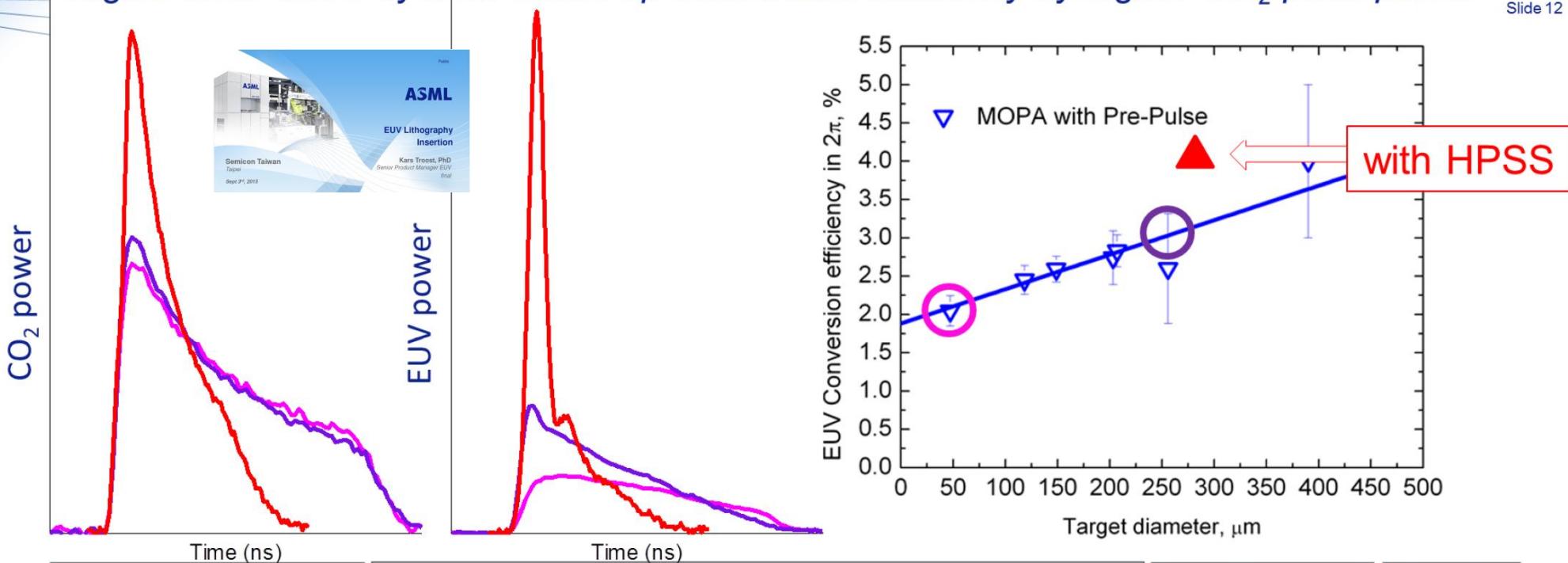
Laser-produced plasma (LPP) Source



EUV power above 100W by improved conversion efficiency
High Power Seed System drives up conversion efficiency by higher CO₂ peak power

ASML

Public
Slide 12

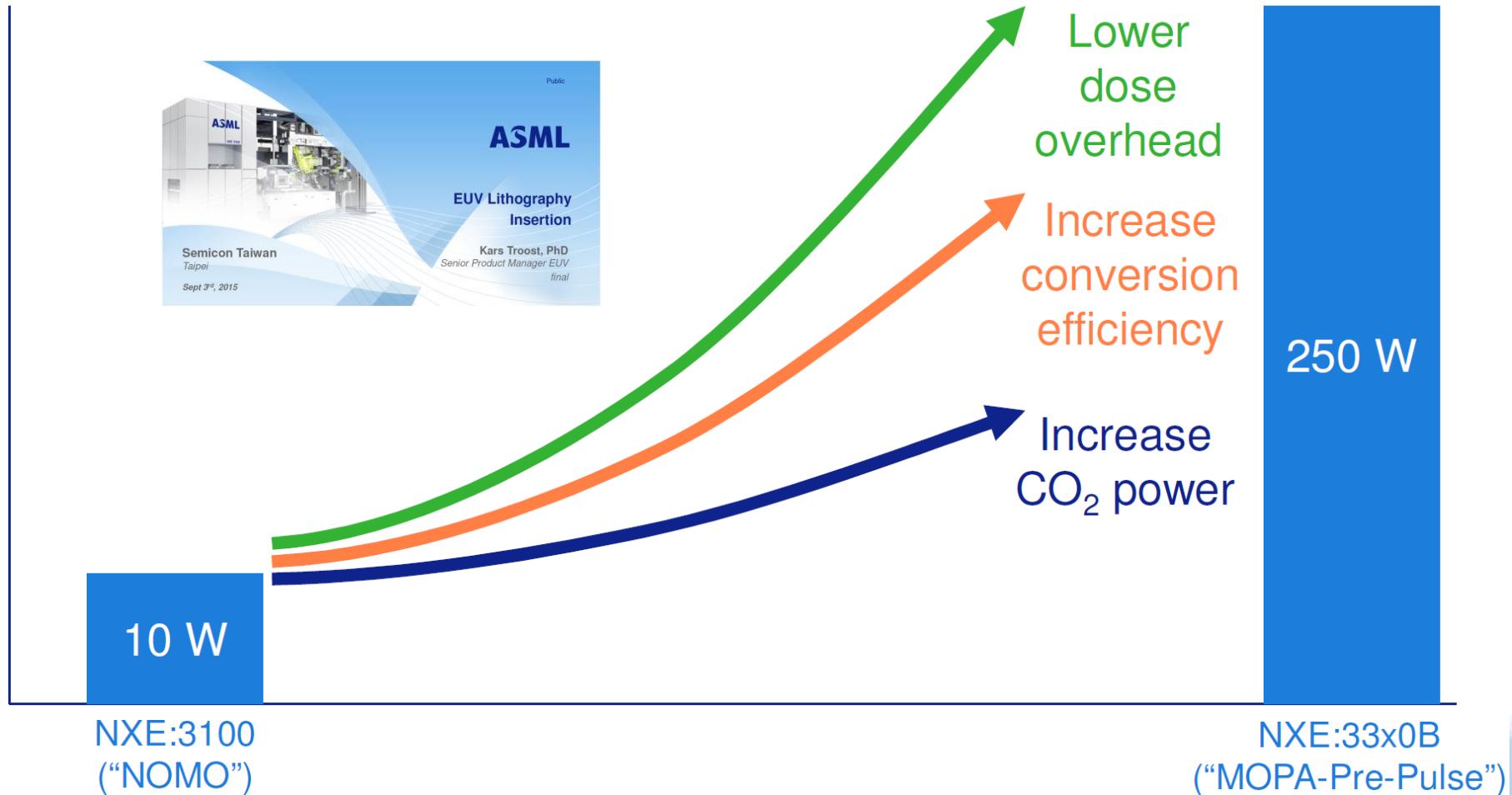




Laser-produced plasma (LPP) Source

EUV power scaling: three levers

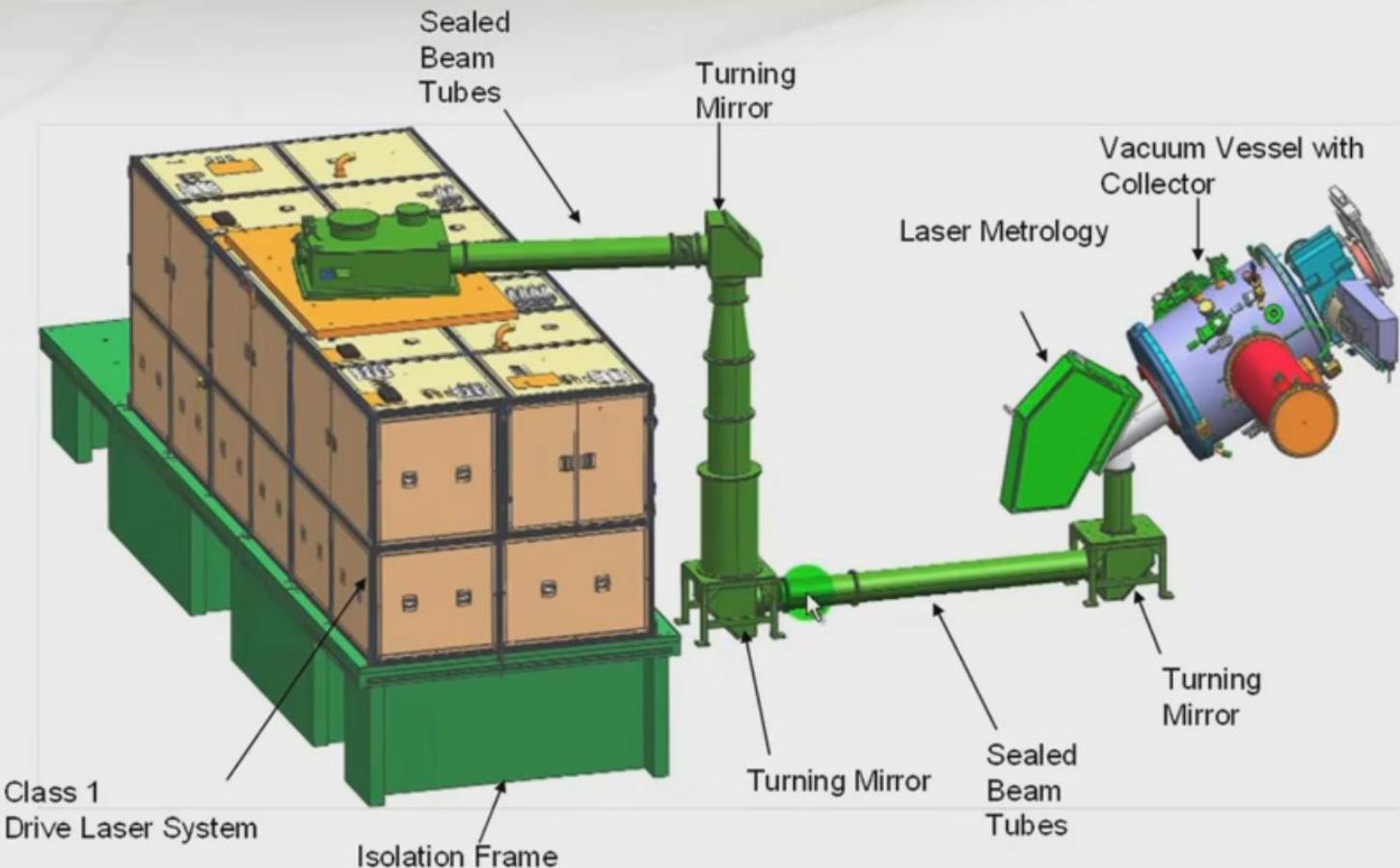
CO_2 power, conversion efficiency, EUV energy available for exposure



Laser-produced plasma (LPP) Source

Cymer LPP EUV source layout

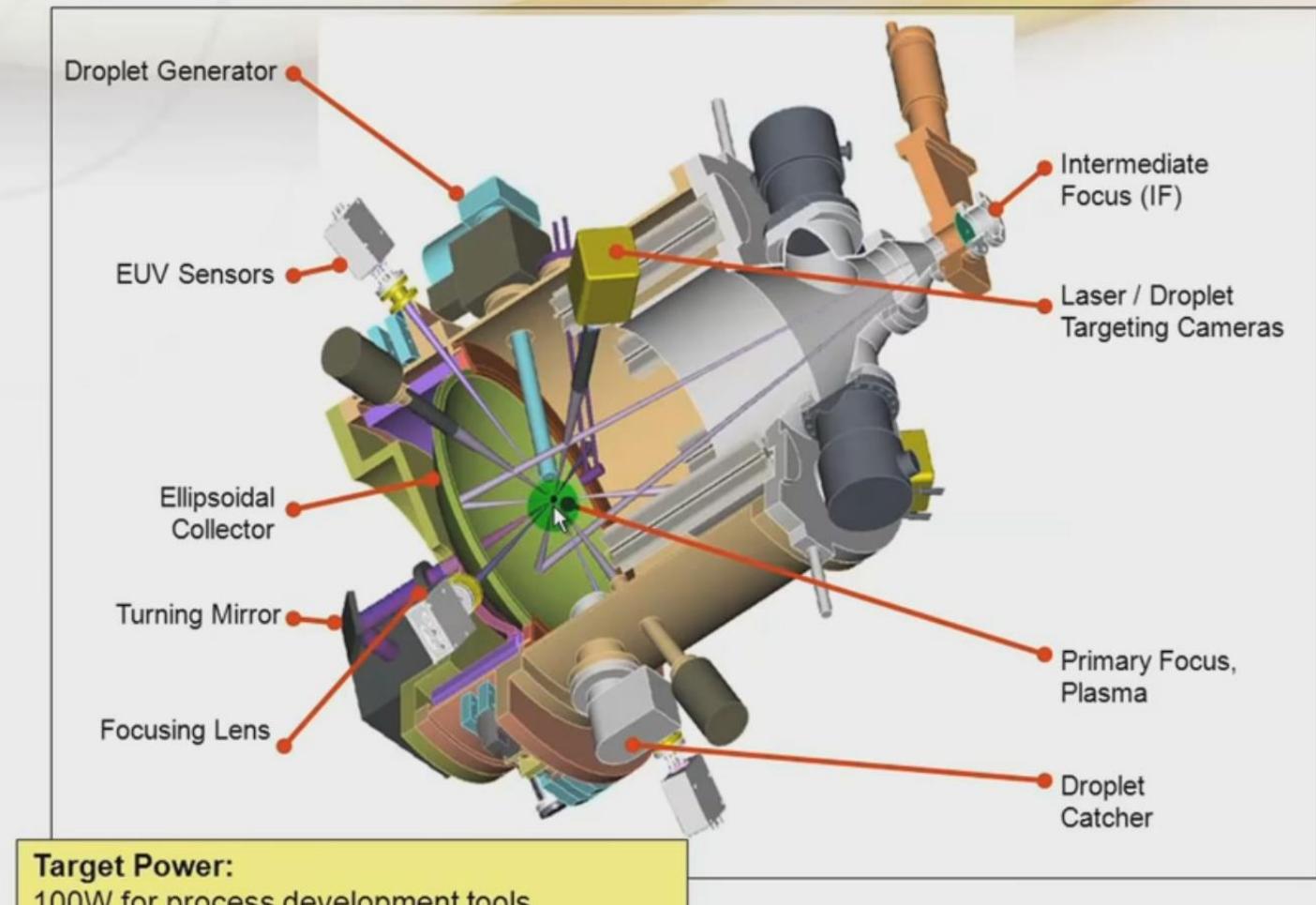
Drive laser system, beam transport system, and source vessel





Laser-produced plasma (LPP) Source

Cymer LPP EUV Source Vessel Architecture



CYMER

<https://www.cymer.com/>



Laser-produced plasma (LPP) Source

EUV Industrialization Roadmap supports 7nm insertion
By >1500 wafers per day in 2016

Timing	Source power [W]	Throughput [Wafers/hr]	Efficiency* [%]	Productivity [Wafers/day]
2014	80	>55	<50%	>500
2015	125	>75	>50%	>1000
2016	250	>125	>55%	>1500

*Efficiency = system availability x customer utilization x customer rate efficiency
Logic typically 55%, for DRAM 70-75% (>2000 WPD)
Illustrative numbers used for WPD model



Laser-produced plasma (LPP) Source

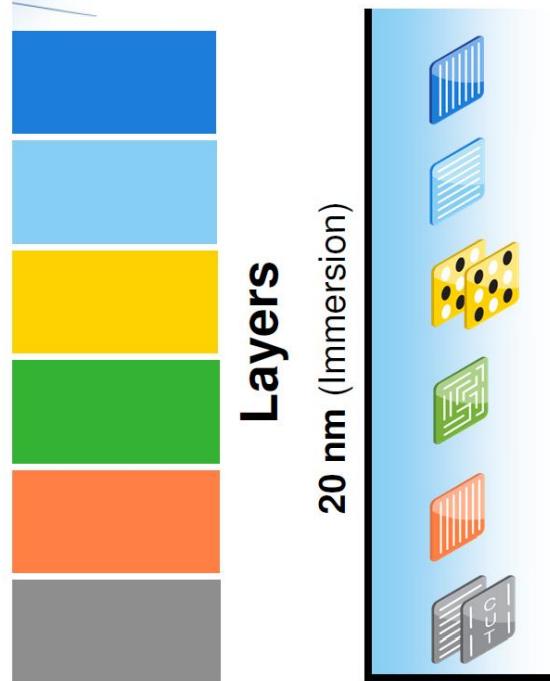


E = mc²

ASML

Public
Slide 6

EUV reduces complexity and thus cycle time



Node

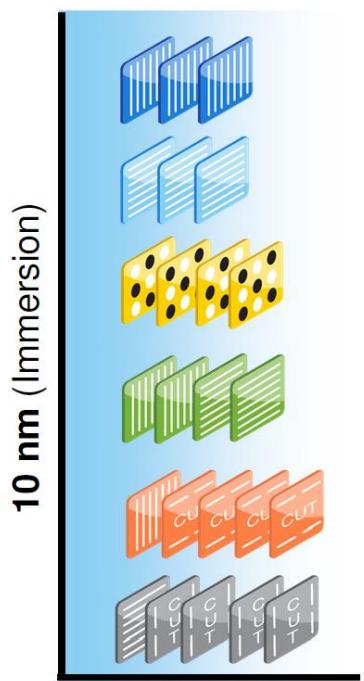
of litho steps

20 nm

8 (Immersion)

9-11

max metrology /
litho steps

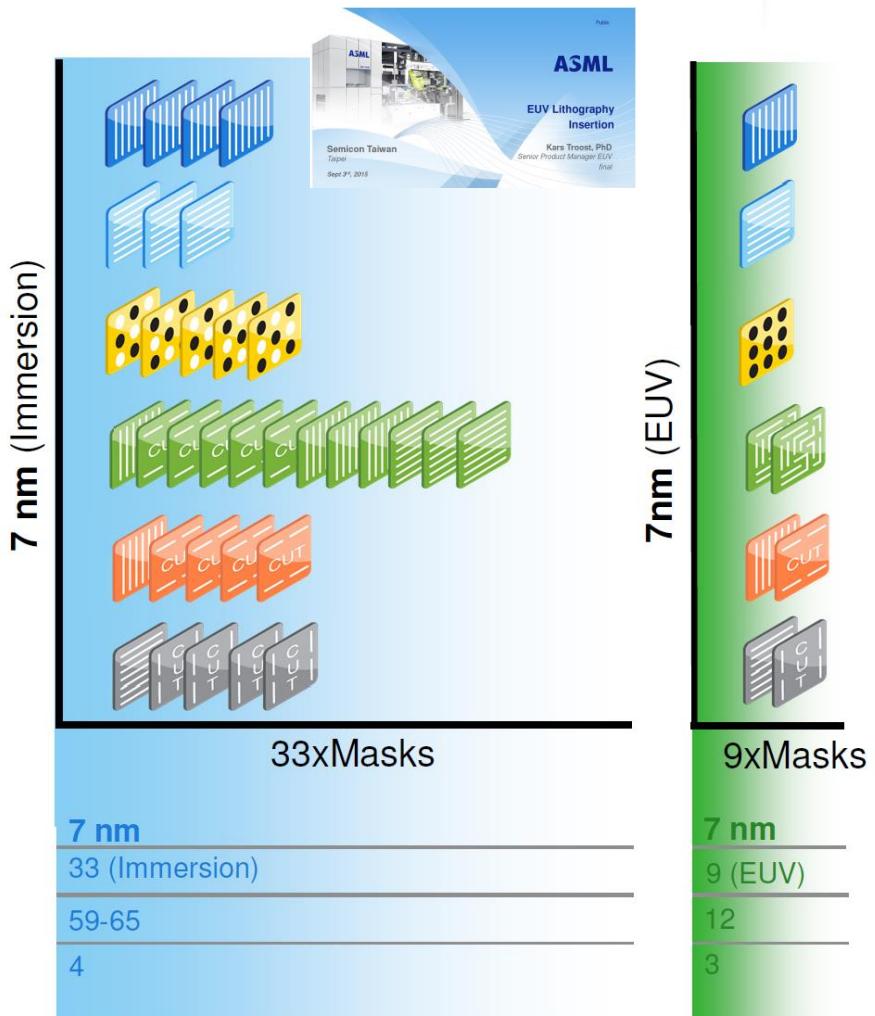


10 nm

23 (Immersion)

36-40

3





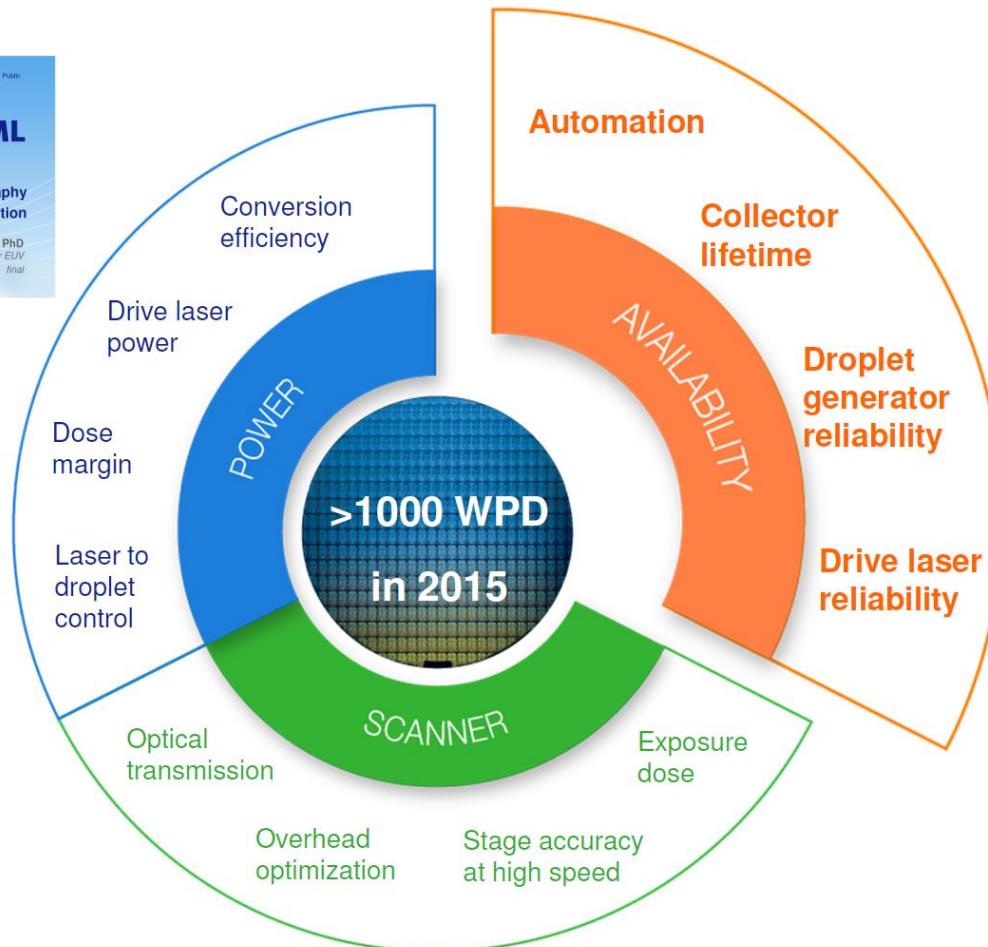
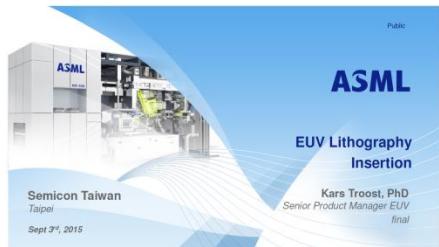
Laser-produced plasma (LPP) Source

Focus 2015: improving source availability

More than 50 improvement items identified, field upgrades throughout 2015

ASML

Public
Slide 14



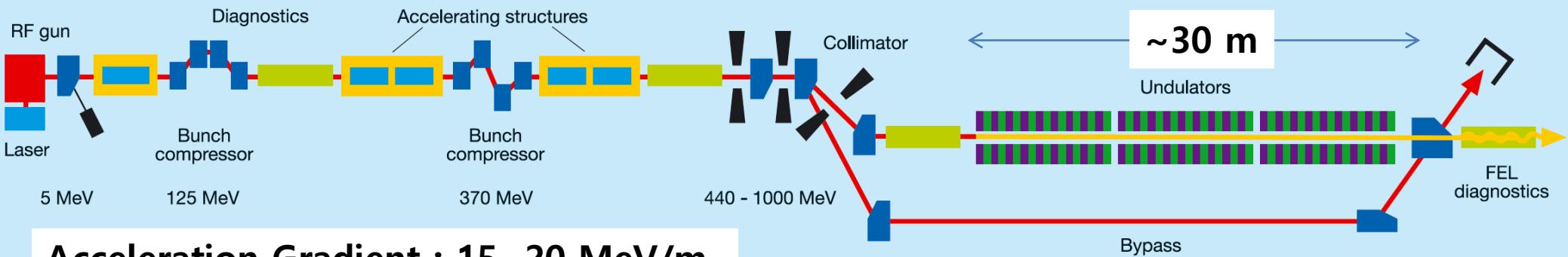
More than 50 availability improvement items have been identified.

Projects are underway to make these improvements available on customer systems throughout this year.

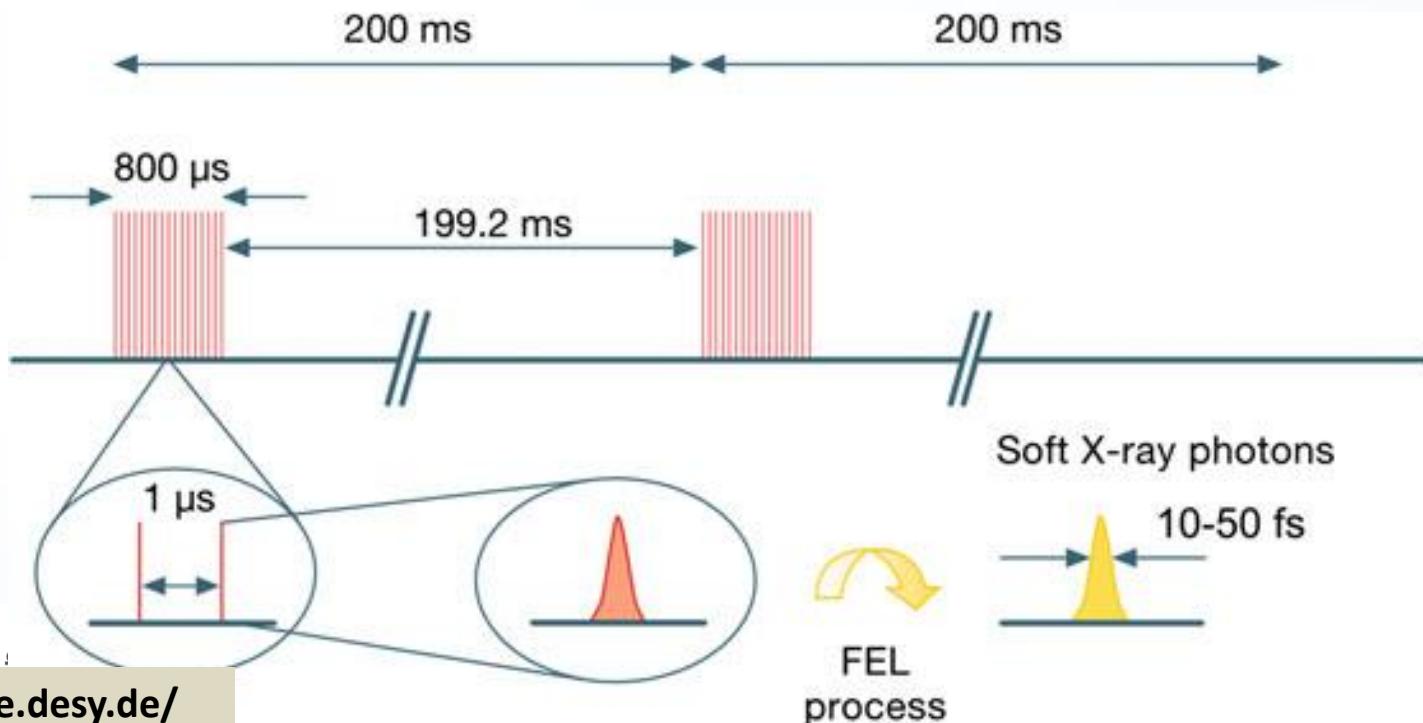


Example of EUV FEL

FLASH, the Free-electron LASer in Hamburg : the first FEL for VUV & soft X-ray from 2005



Acceleration Gradient : 15~20 MeV/m





Example of EUV FEL

FLASH, the Free-electron **LASer** in **Hamburg** : the first FEL for VUV & soft X-ray from 2005

Number of Bunches per second	1 - 8000	
Pulse Repetition Rates (within pulse train)+	40, 50, 100, 200, 250, 500, 1000	kHz
Wavelength	4.2 - 45	nm
Pulse Duration (FWHM)	30 - 300	fs
Average Pulse Energy (single bunch)*	1 - 500	μJ
Average Pulse Energy (pulse trains)*	1 - 200	μJ



EUV FEL for Lithography



Requirements for EUV FEL

- Beam Energy : ~1 GeV
- Wavelength : 13.5 nm
- Average Power : > 1 kW

EUV FEL Specification

- Size : ~100 m
- Cost : ? (>100M\$)^a
- Number of FEL : 2

^aPAL X-FEL : 400M\$ (3 GeV, 0.1 nm)

